



Point Curvature: Large
Aspect Ratio: Small ($\div 1$)

FIG. 1A PRIOR ART



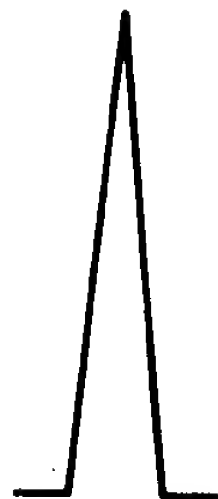
Point Curvature: Little Small
Aspect Ratio: Small ($\div 4.5$)

FIG. 1B PRIOR ART



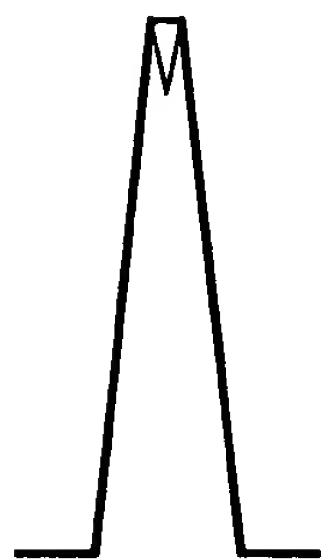
Point Curvature: Little Small
Aspect Ratio: Small ($\div 1$)

FIG. 1C PRIOR ART



Point Curvature: Small (Several nm)
Aspect Ratio: Large (≈ 10)

FIG. 1D PRESENT INVENTION



Point Curvature: Small (Several nm)
Aspect Ratio: Large (≈ 10)

FIG. 1E PRESENT INVENTION

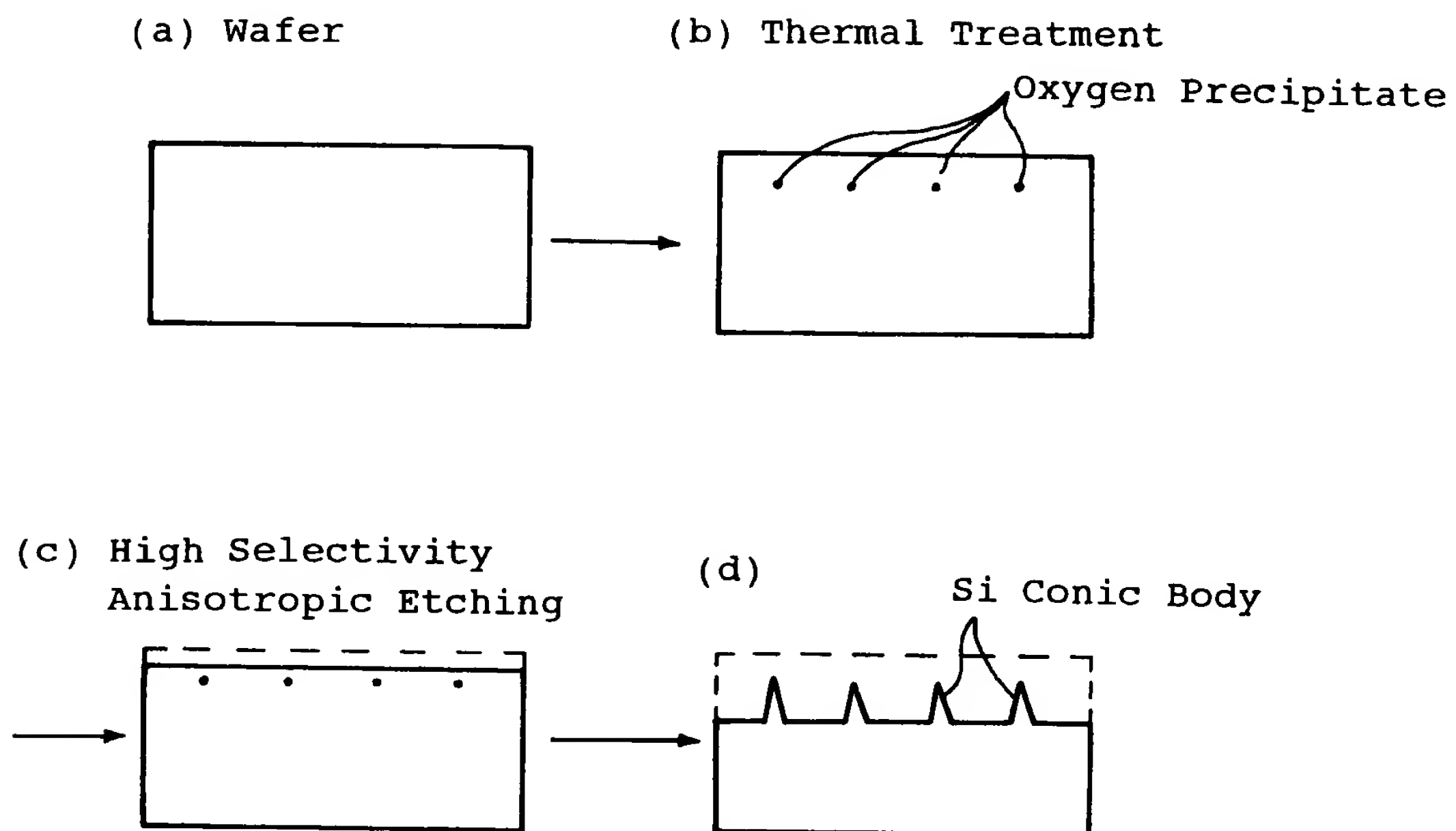
**FIG. 2**

FIG. 3A

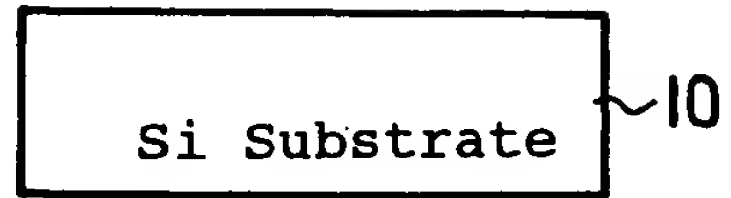


FIG. 3B

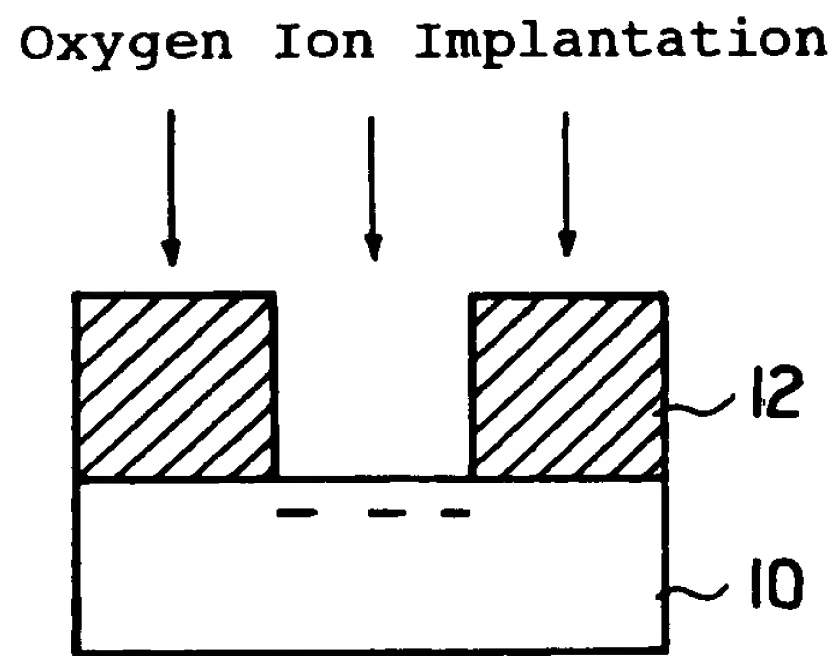


FIG. 3C

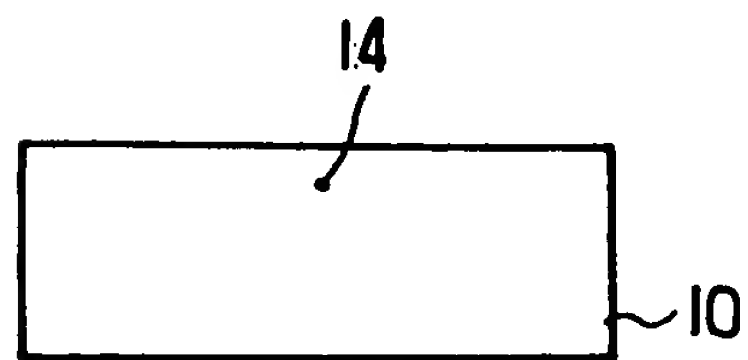
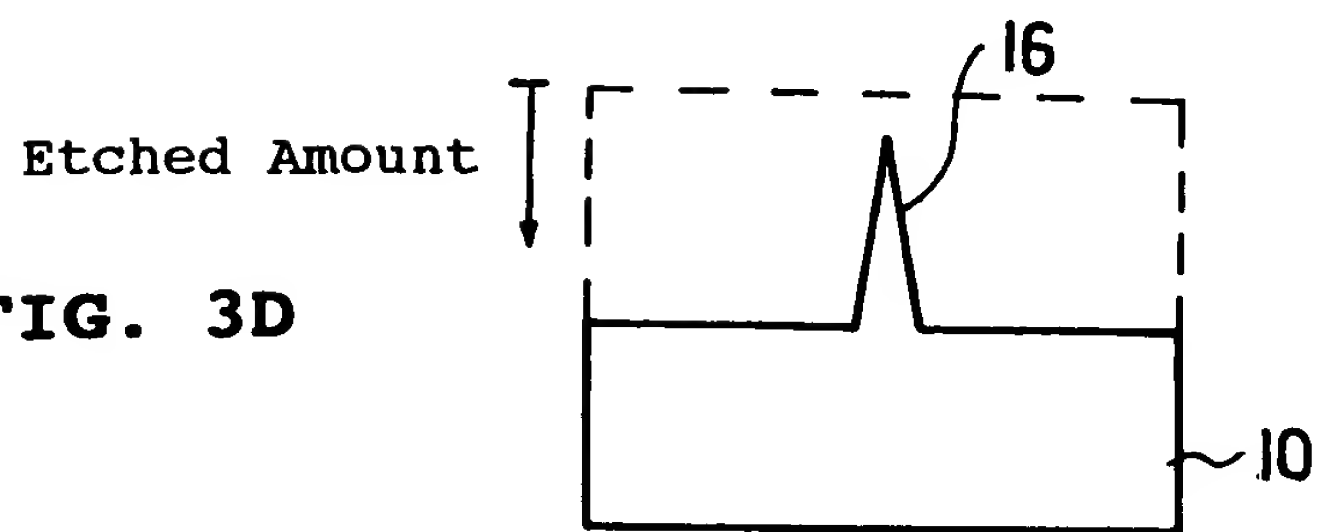


FIG. 3D



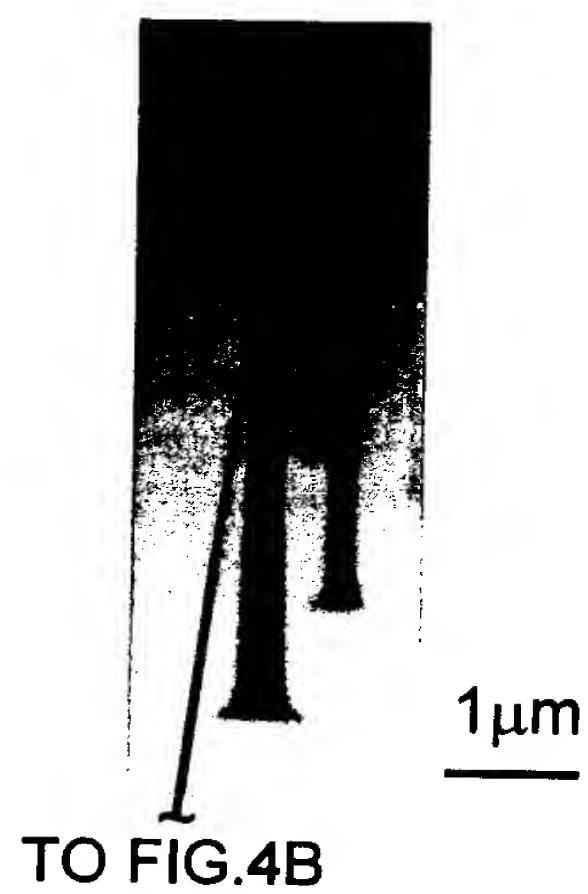


FIG. 4A

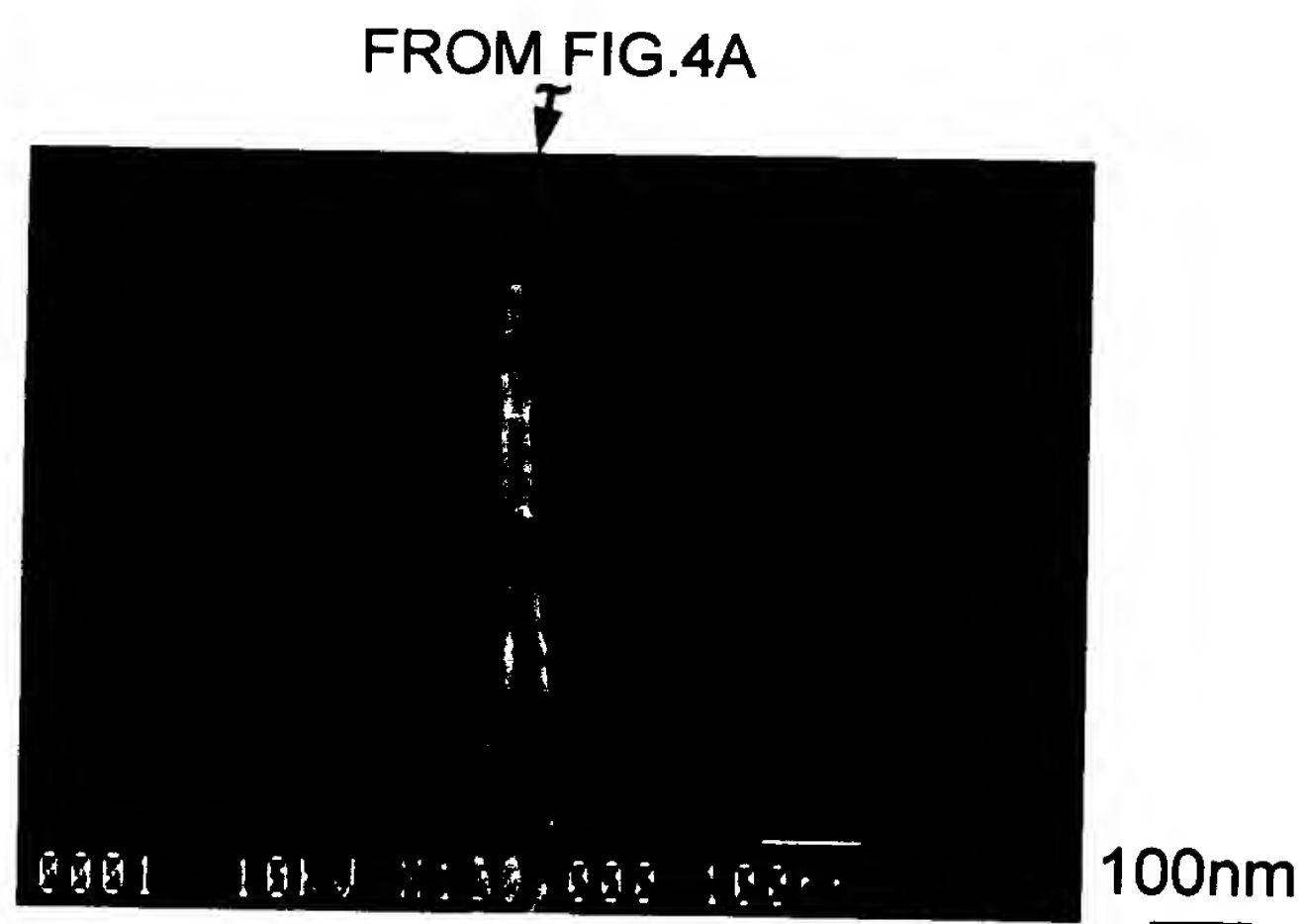
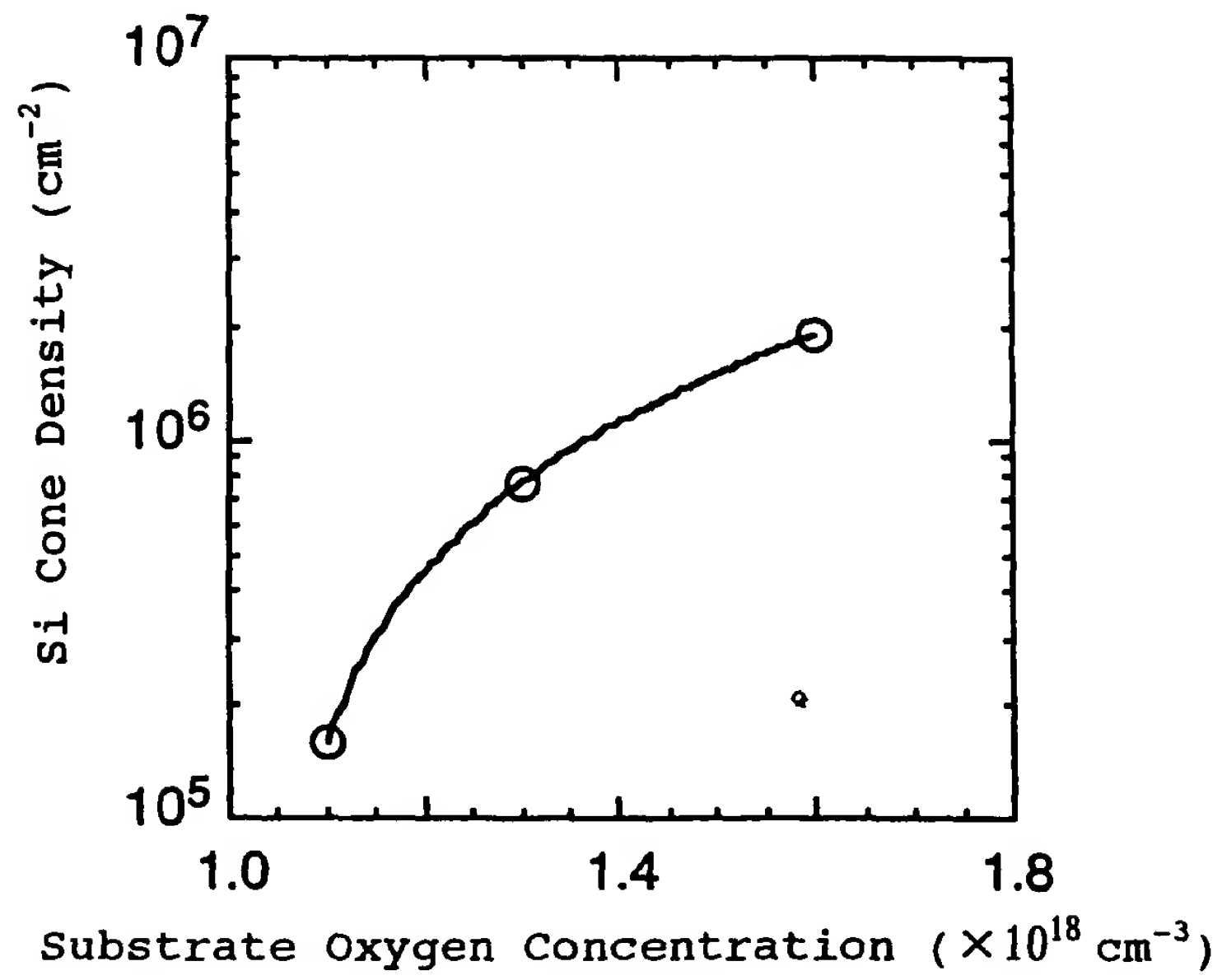
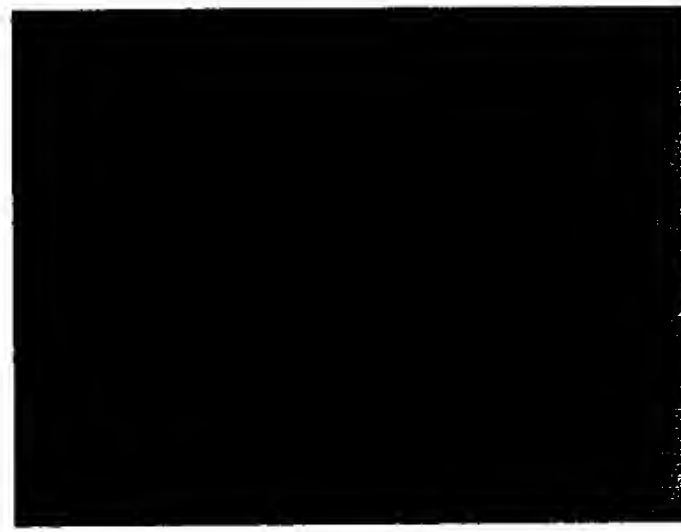


FIG. 4B

**FIG. 5**

B Implantation Amount:

$$7 \times 10^{13} \text{ cm}^{-2}$$



100μm

FIG.6A

B Implantation Amount:

$$1 \times 10^{14} \text{ cm}^{-2}$$



100μm

Black dots
are silicon needle conic bodies.

FIG.6B

FIG. 7A

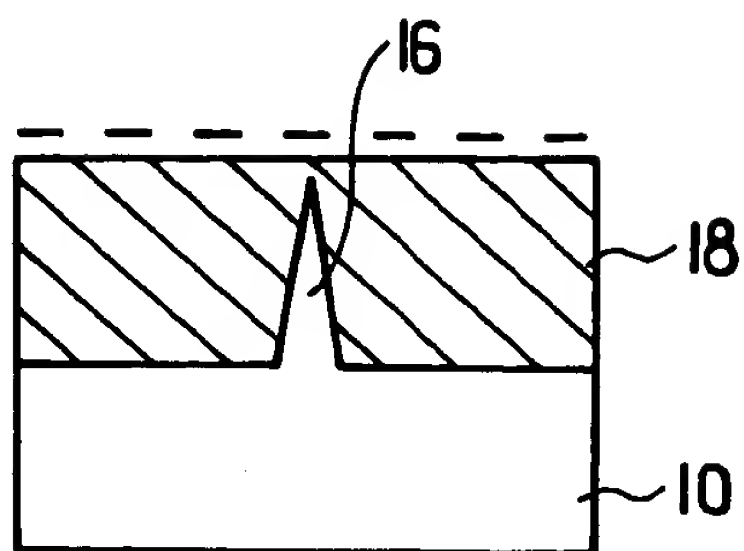


FIG. 7B

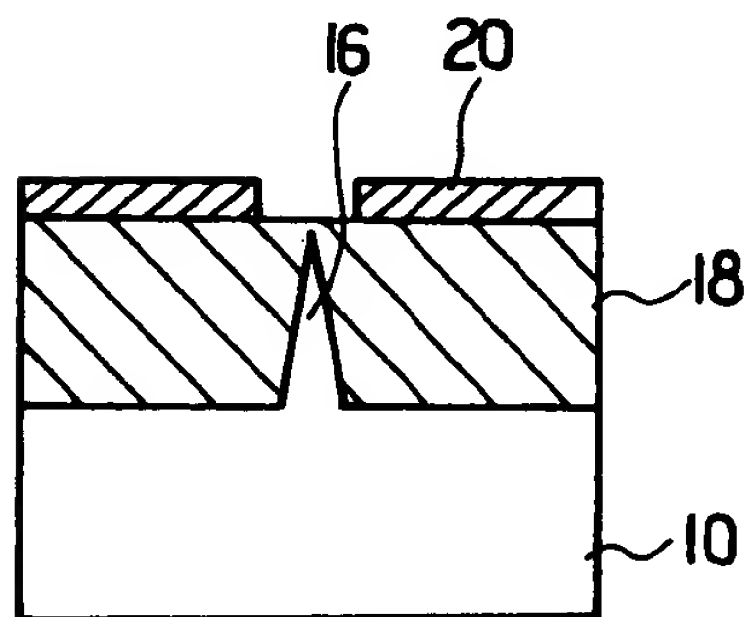
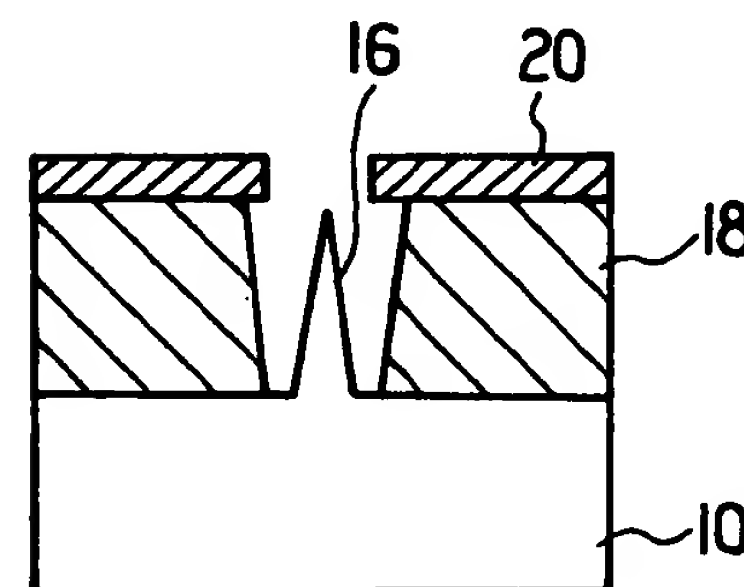


FIG. 7C



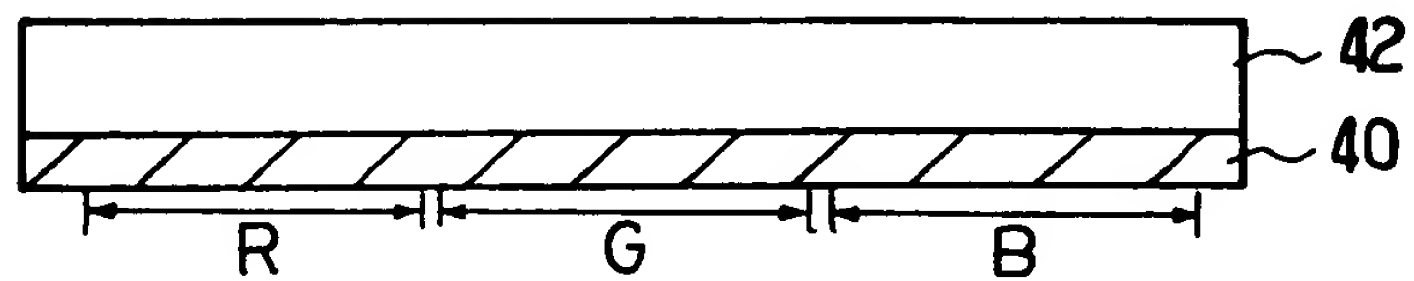


FIG. 8A

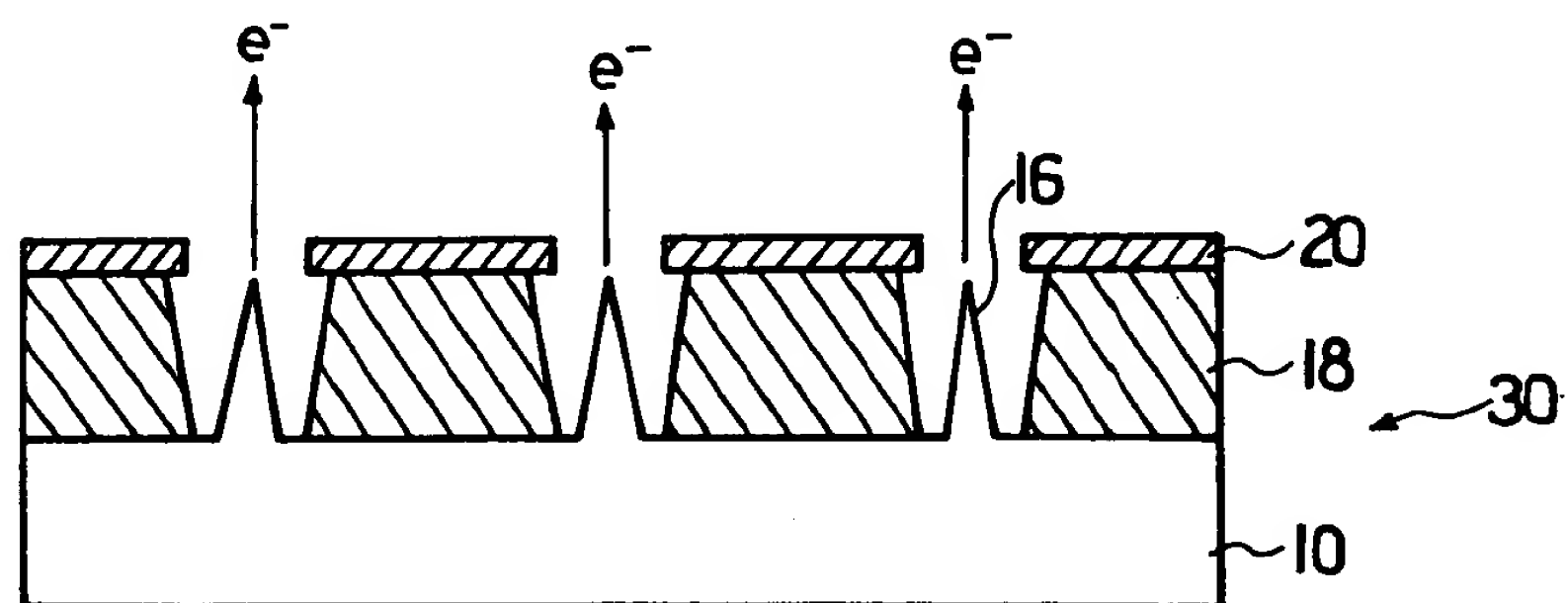
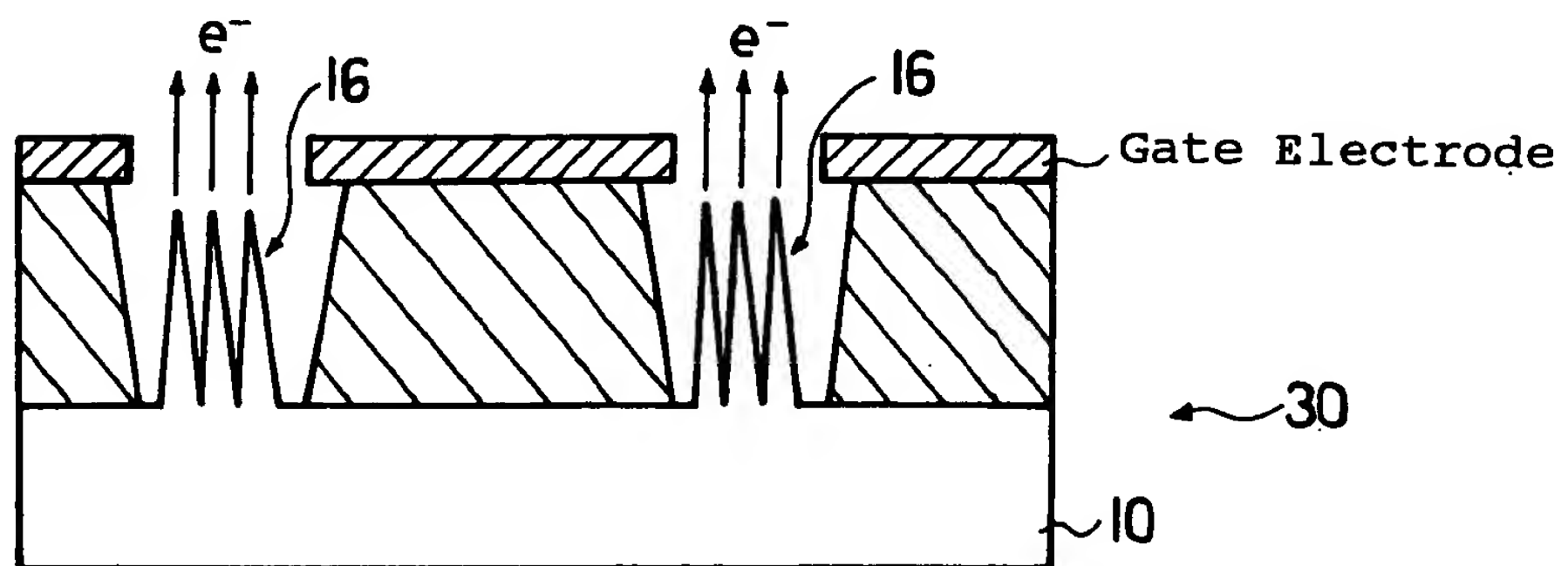


FIG. 8B



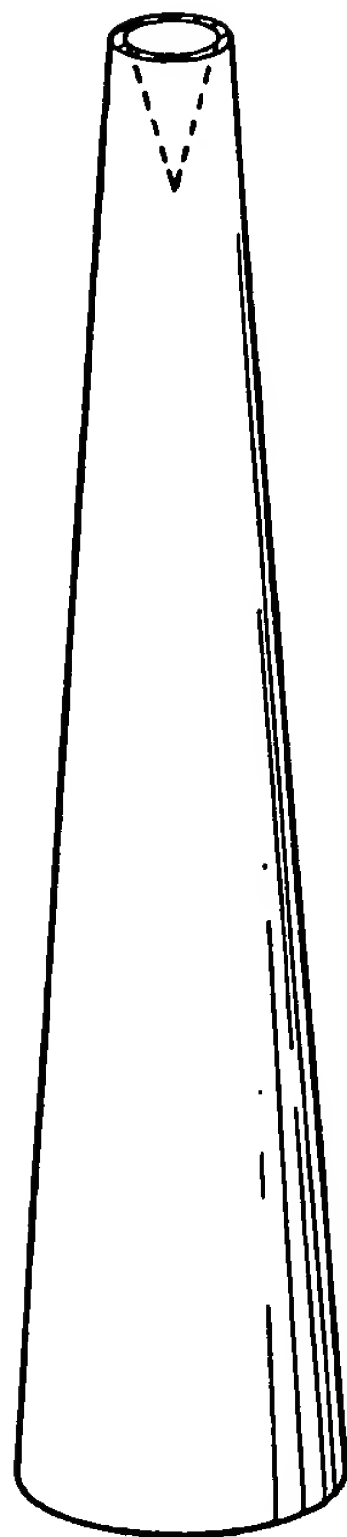


FIG. 9A

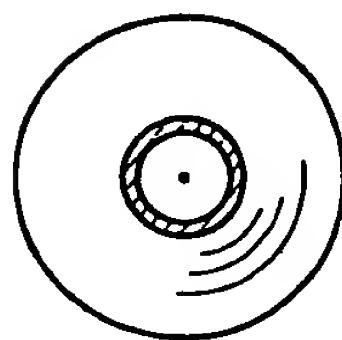
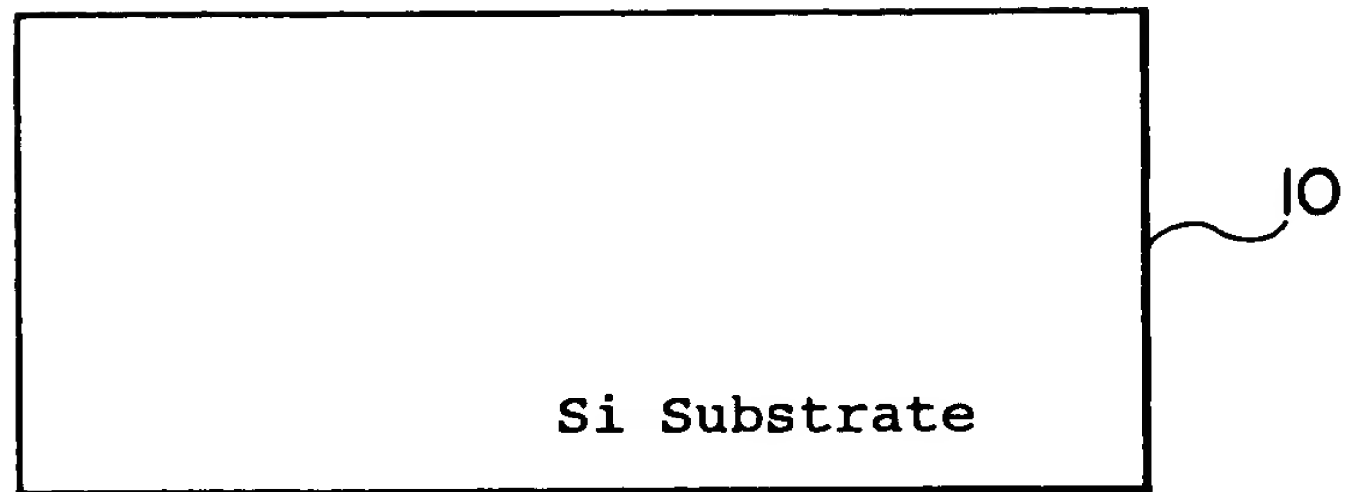


FIG. 9B

FIG. 10A

Oxygen Ion Implantation

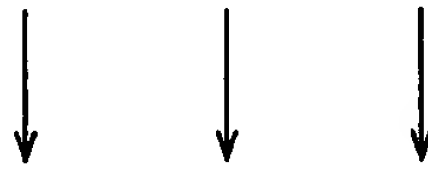
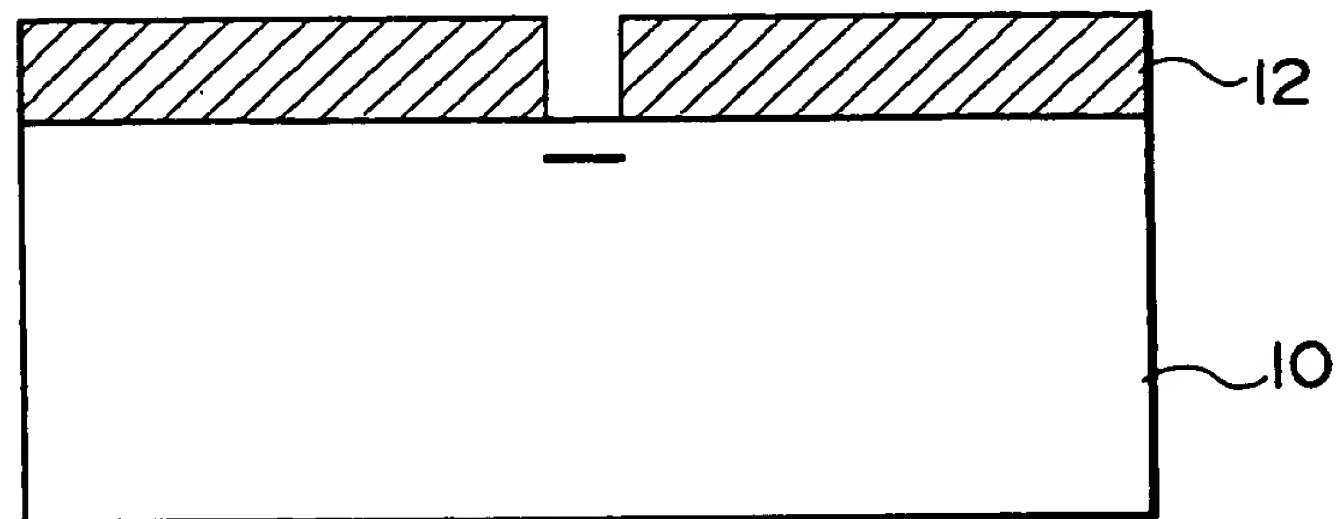
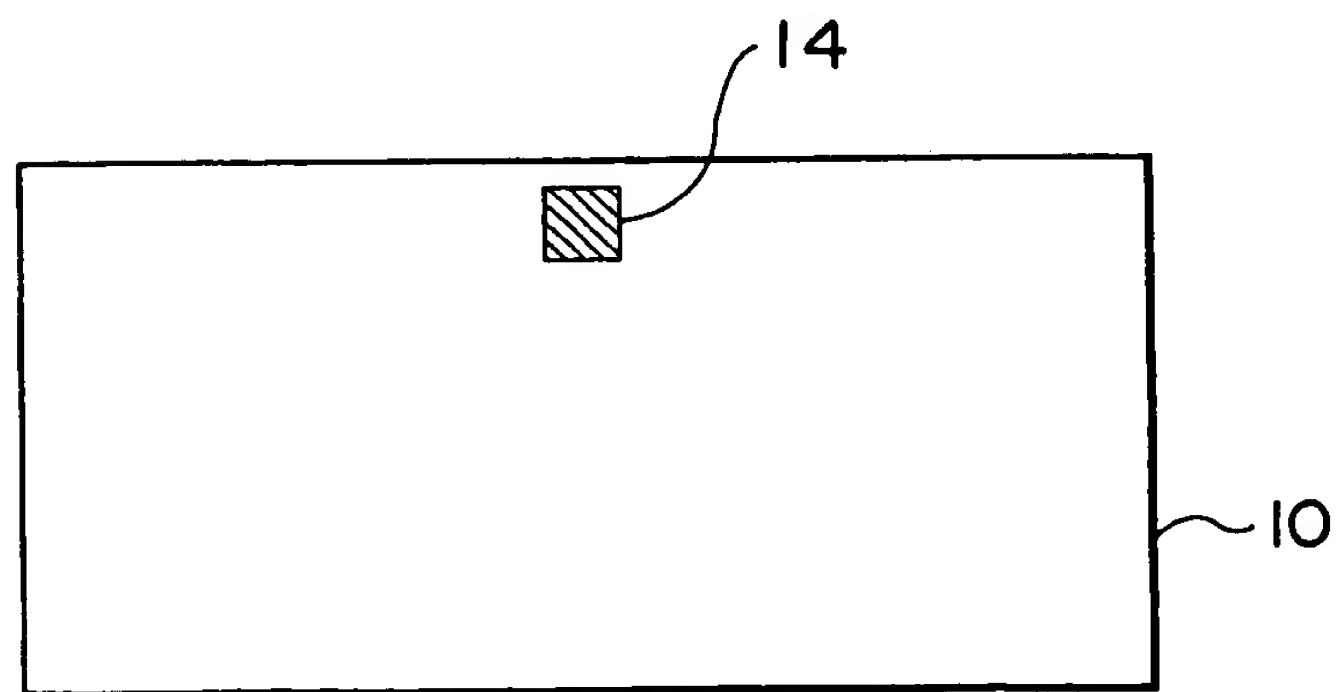
**FIG. 10B****FIG. 10C**

FIG. 10D

Etched Amount

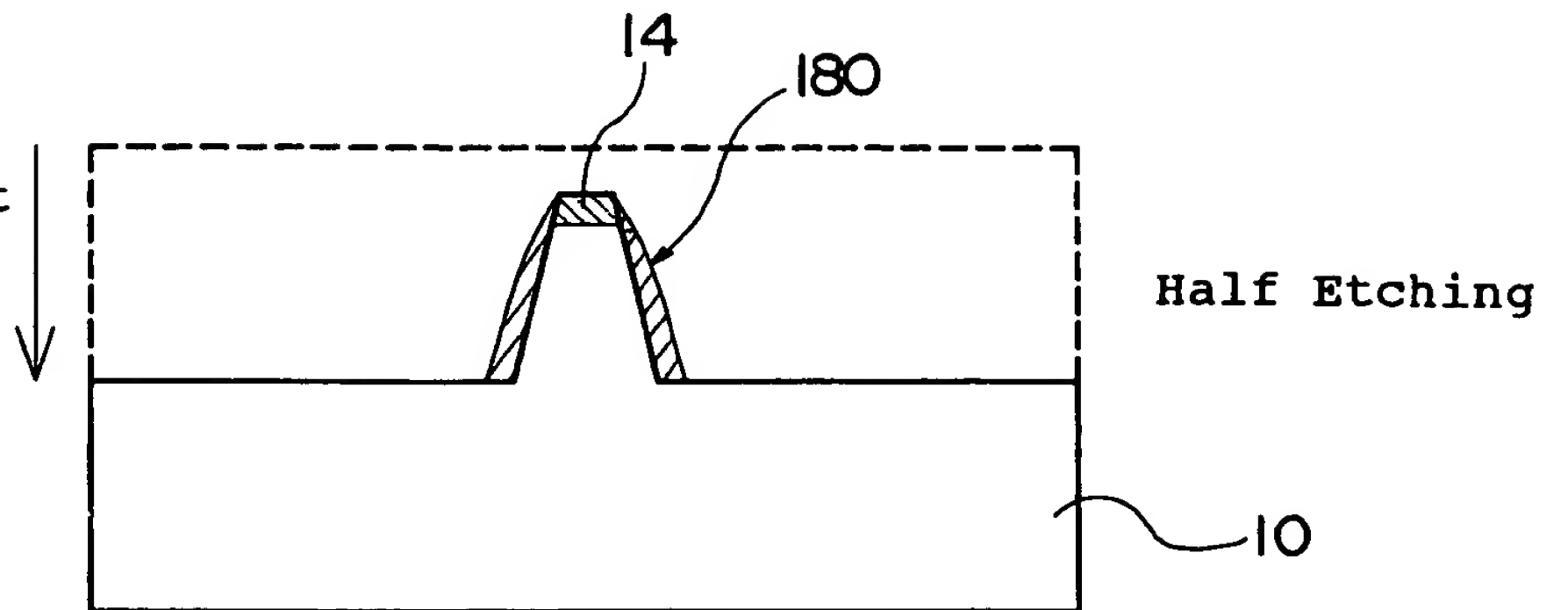


FIG. 10E

Etched Amount

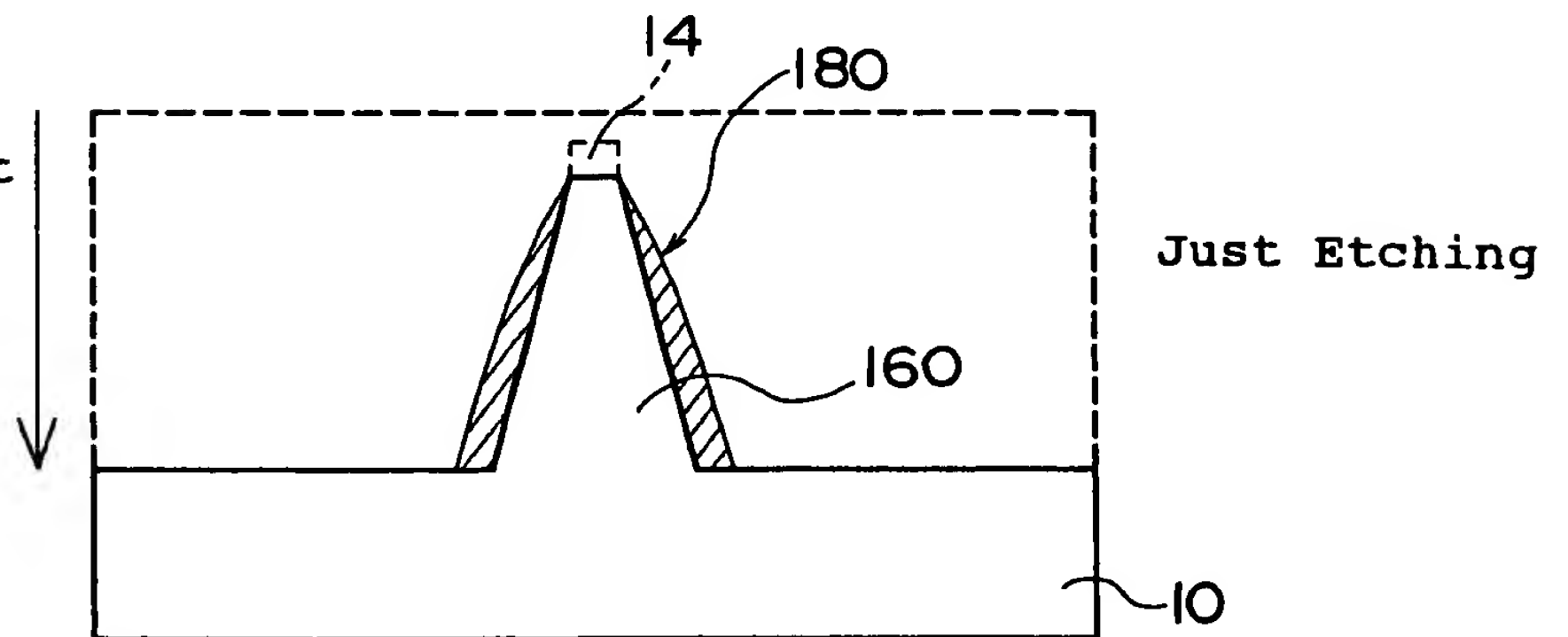
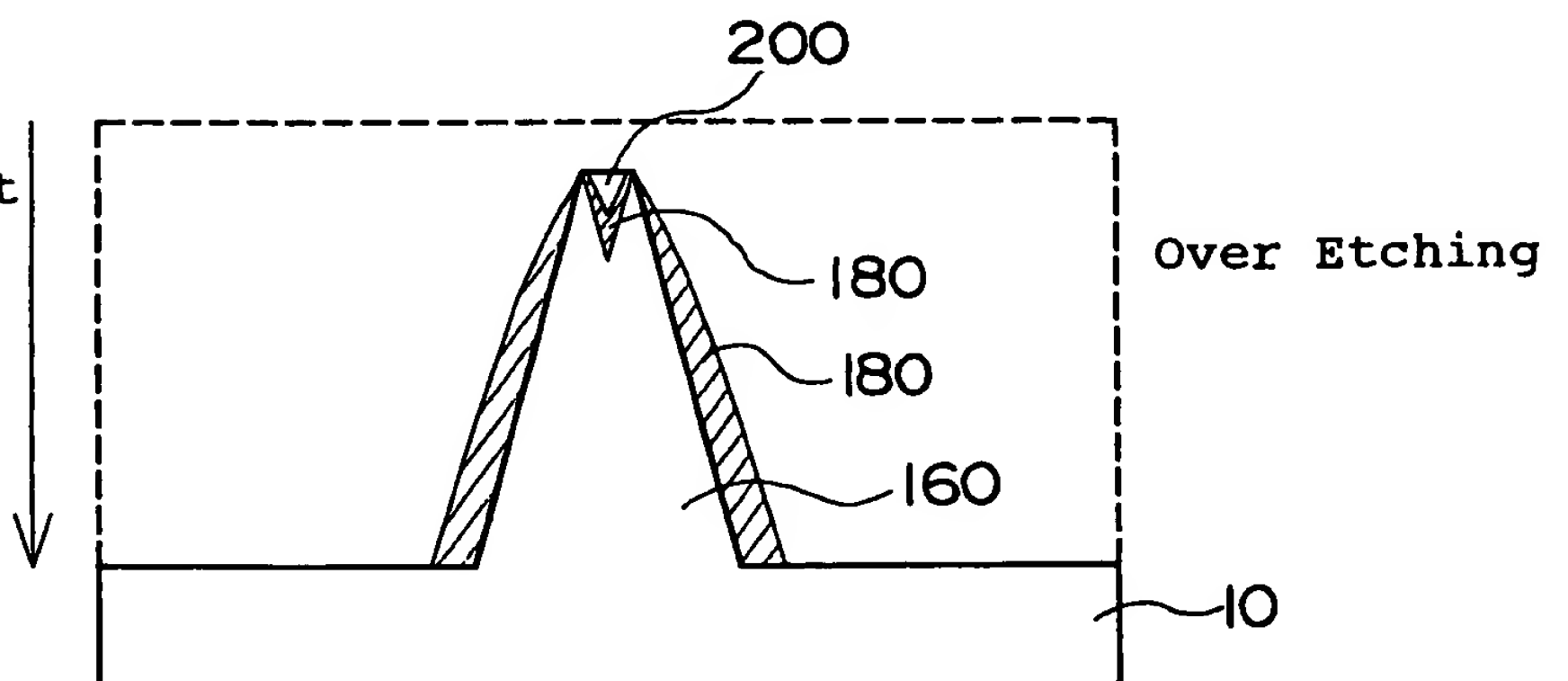


FIG. 10F

Etched Amount



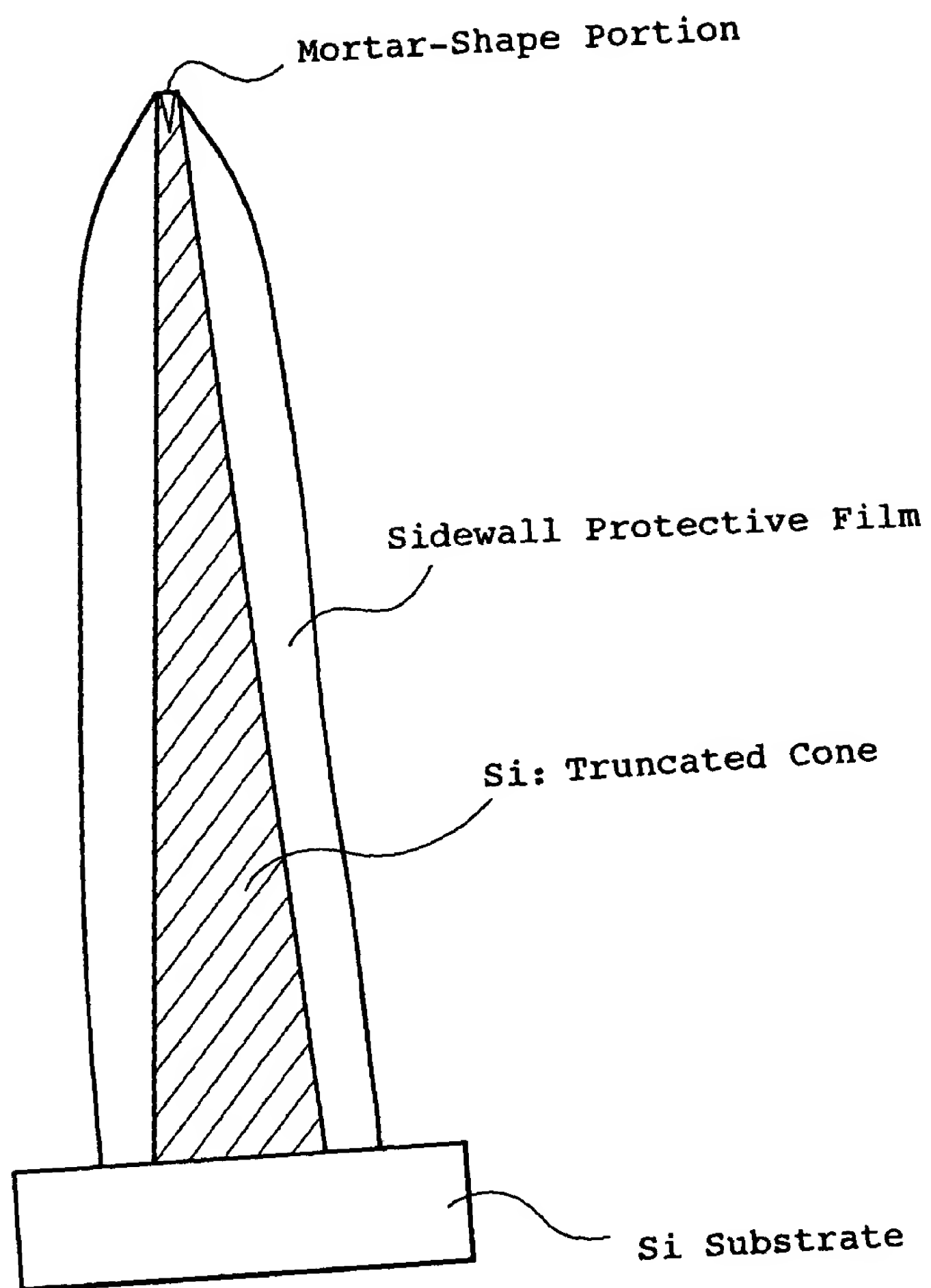


FIG. 11

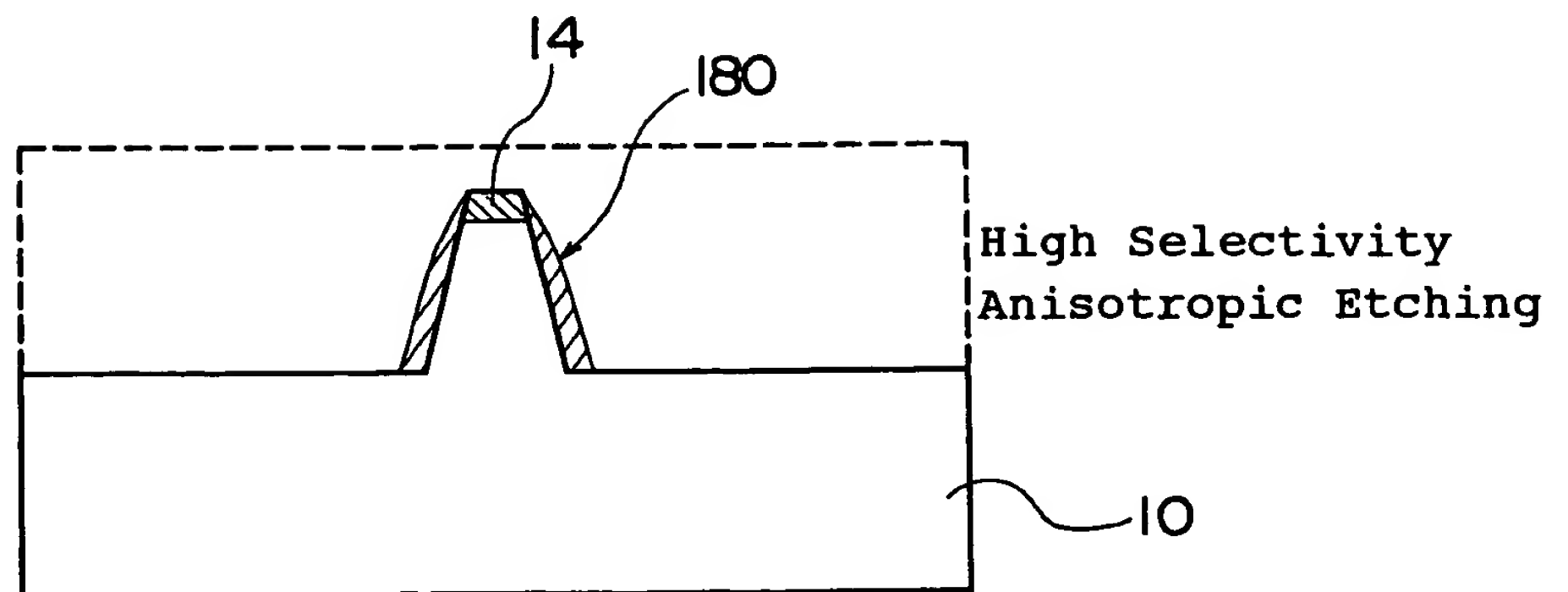
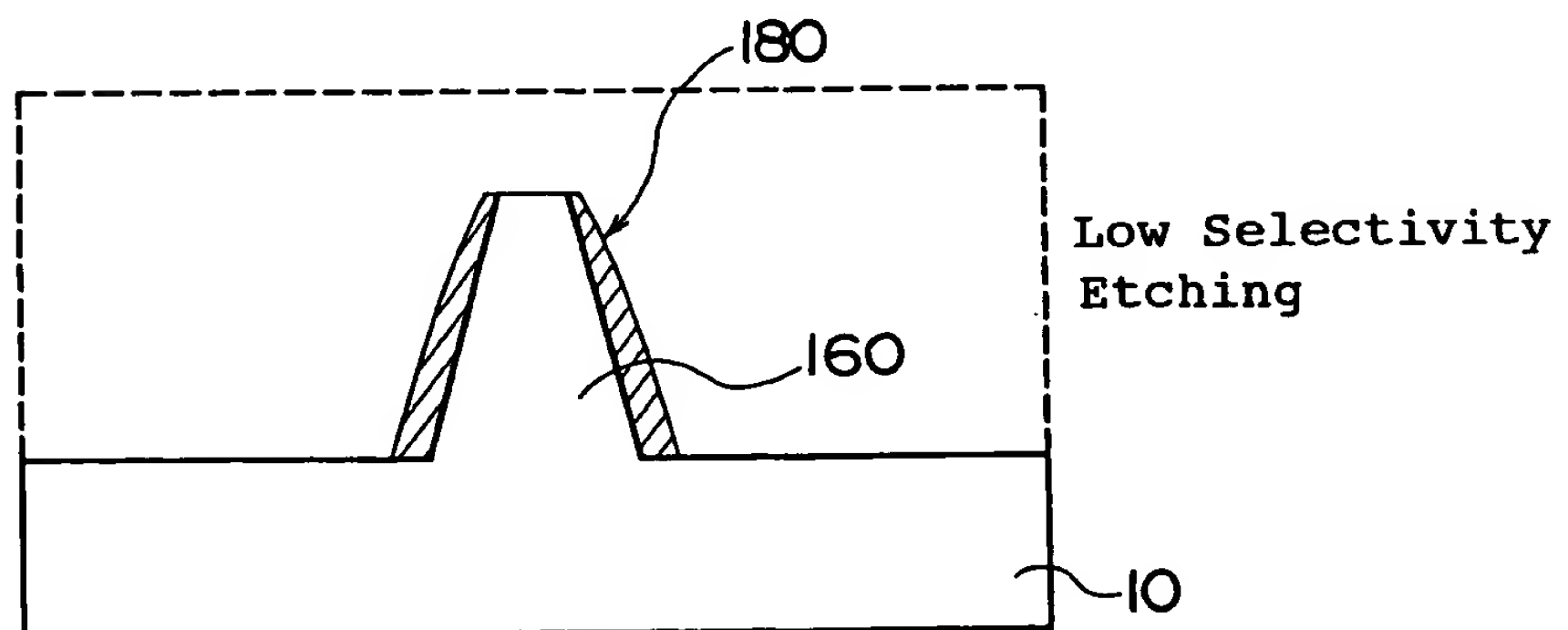
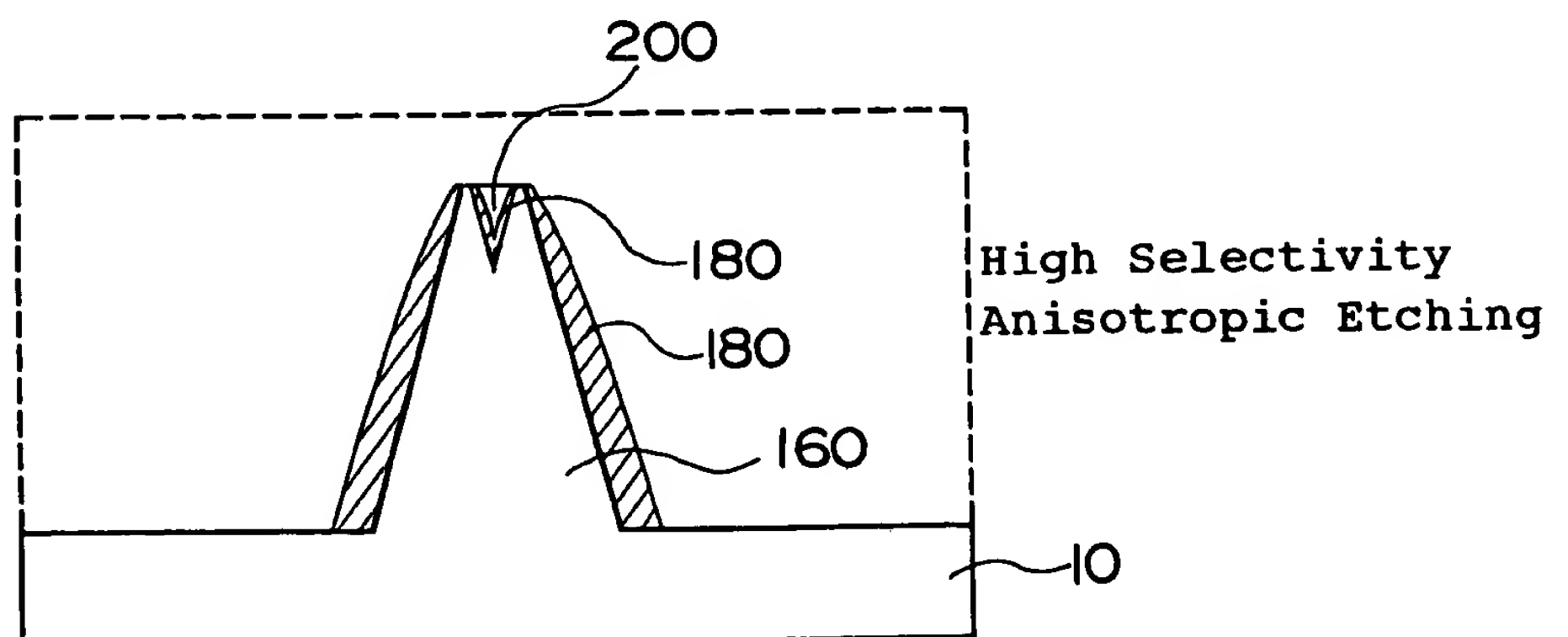
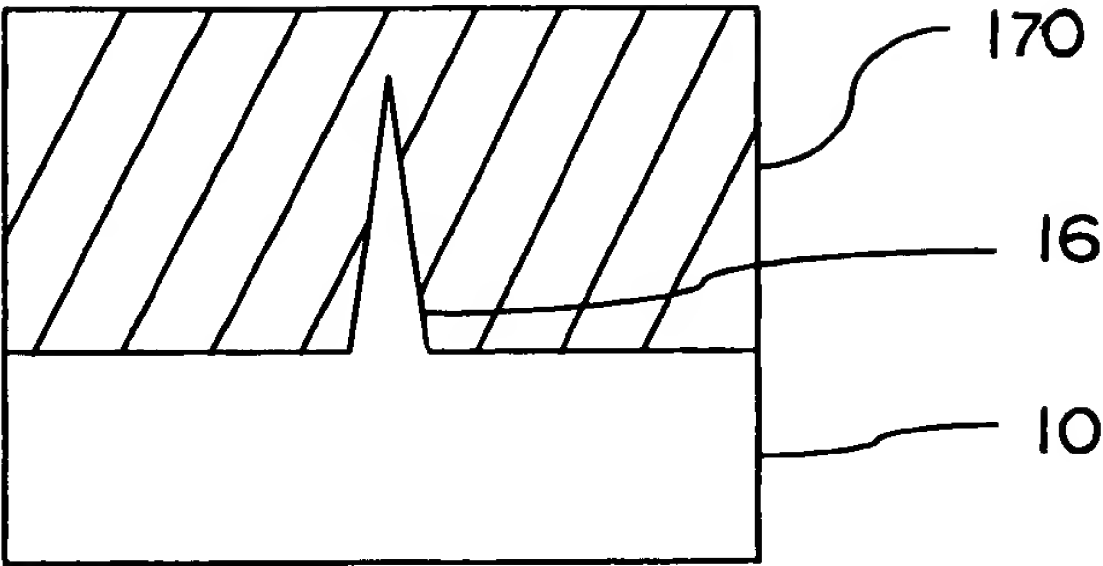
FIG. 12A**FIG. 12B****FIG. 12C**

FIG. 13A



CMP or Etch Back

FIG. 13B

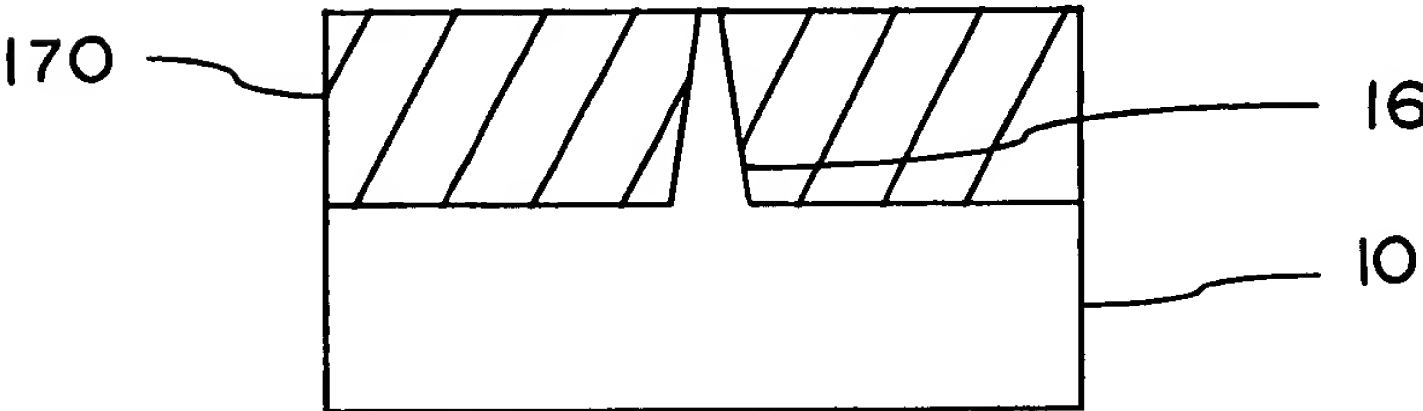


FIG. 13C

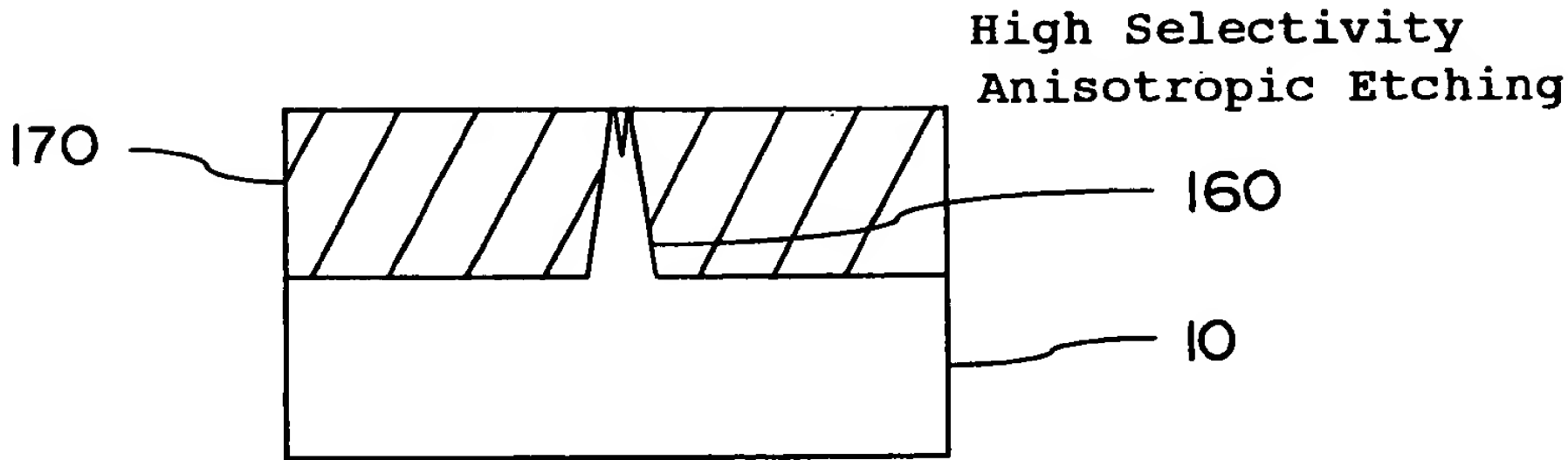
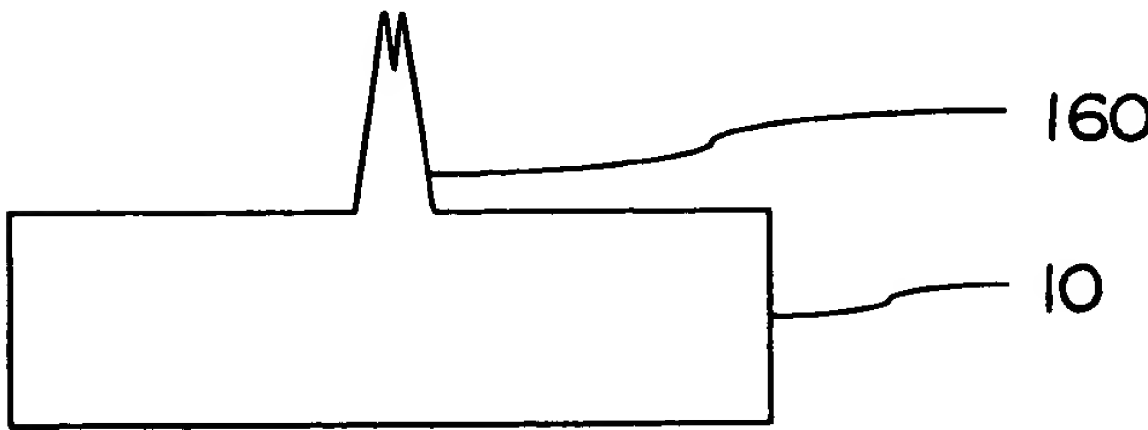


FIG. 13D



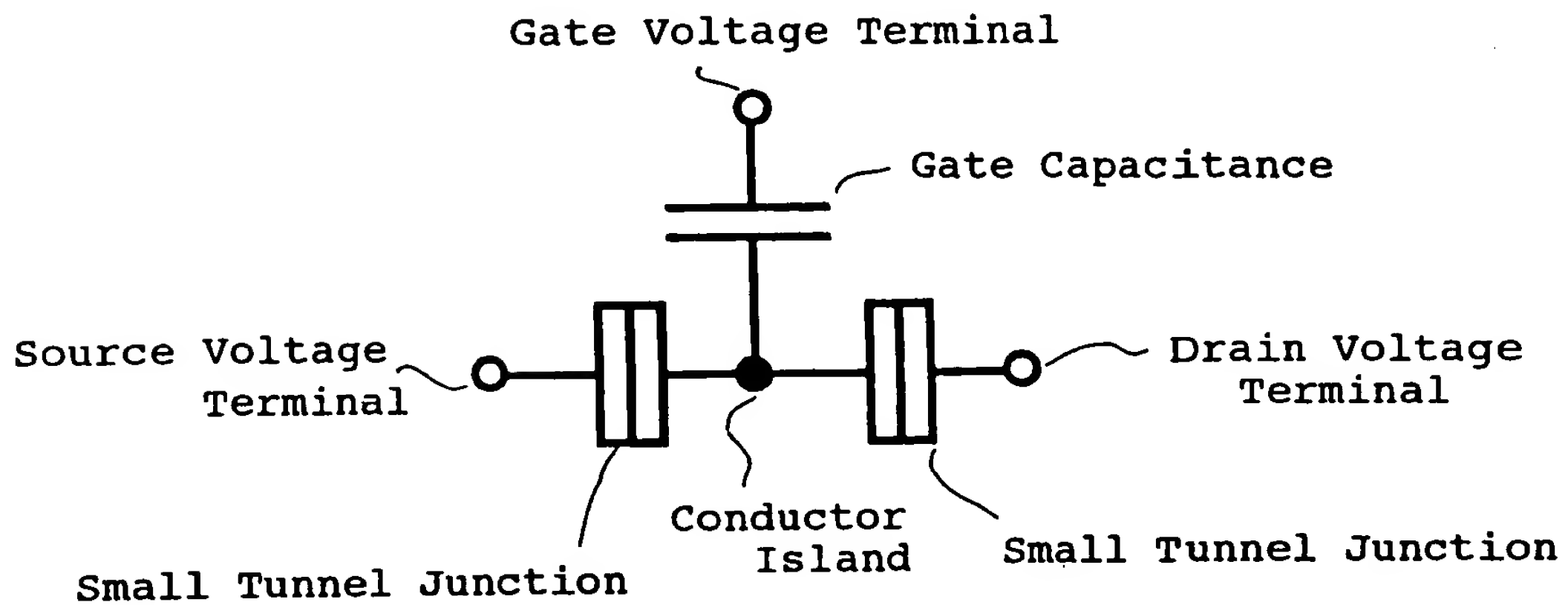


FIG. 14A PRIOR ART

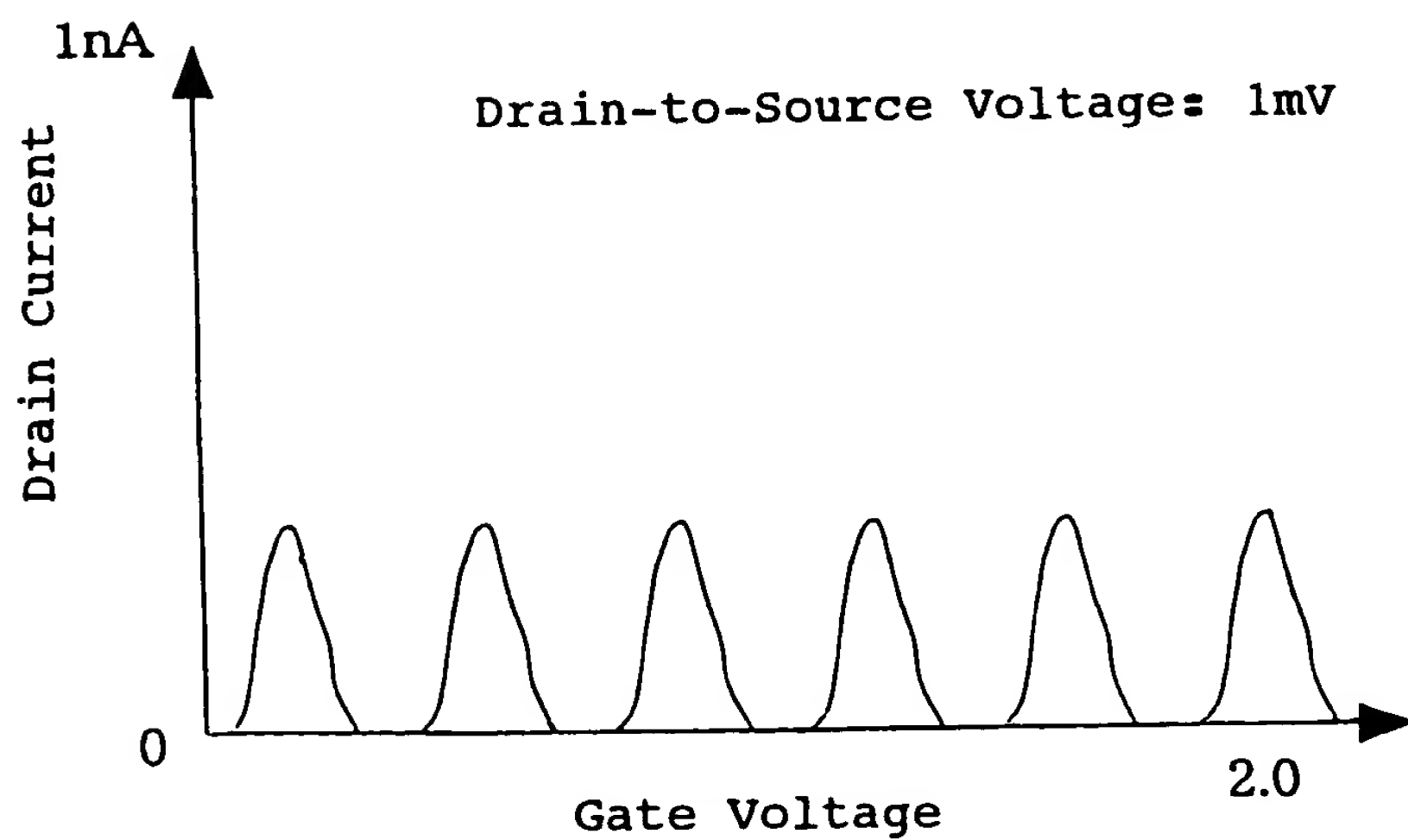
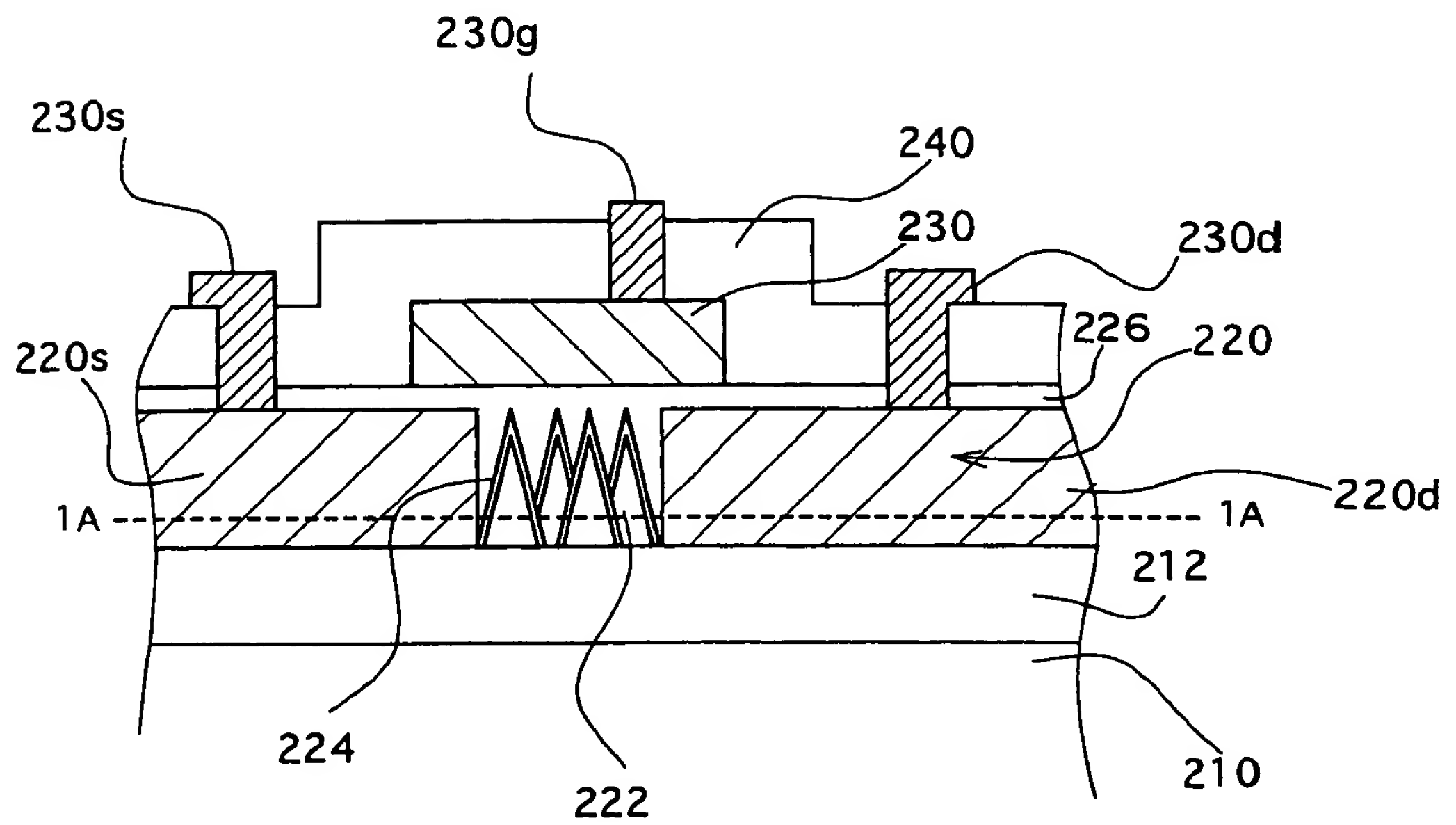
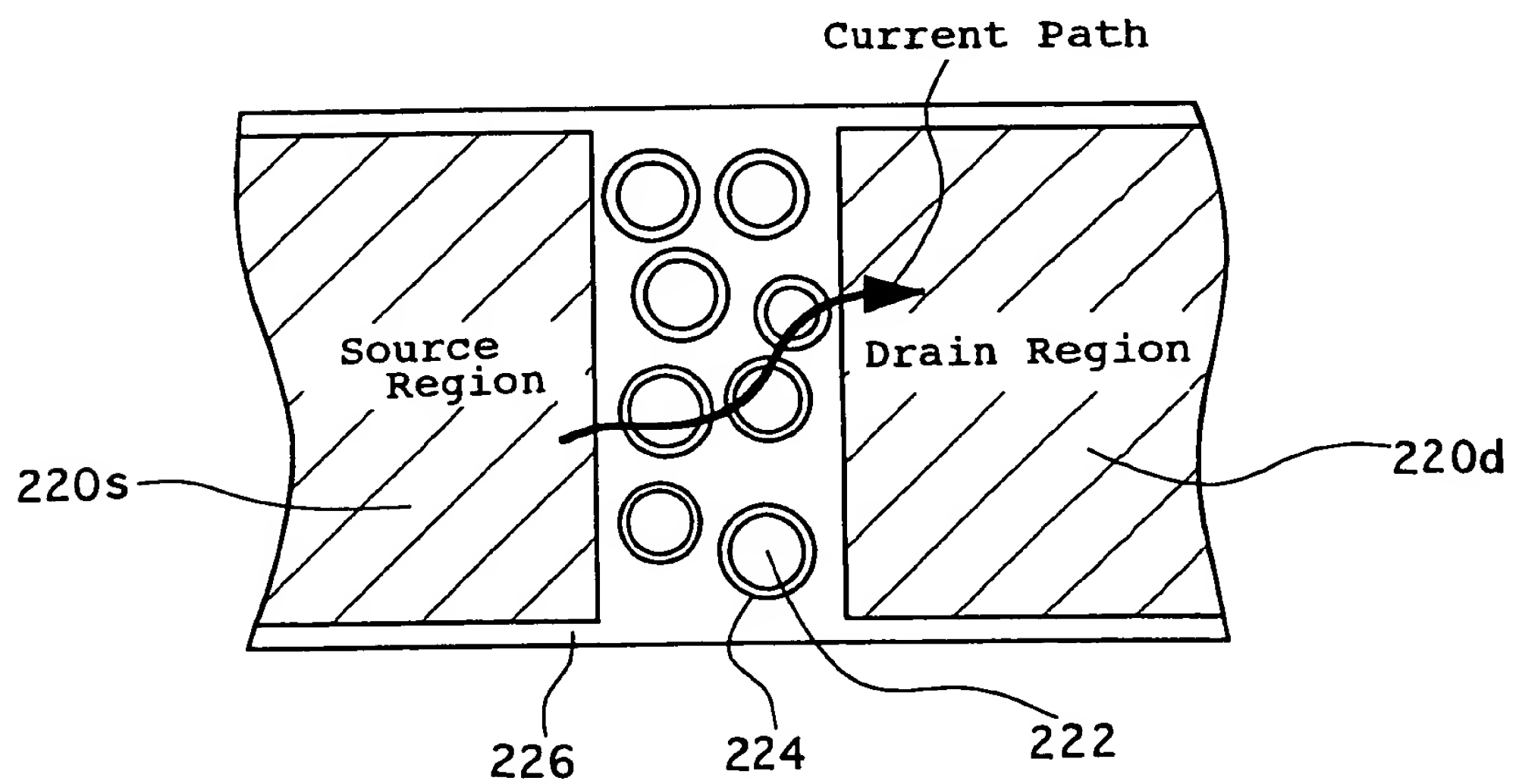
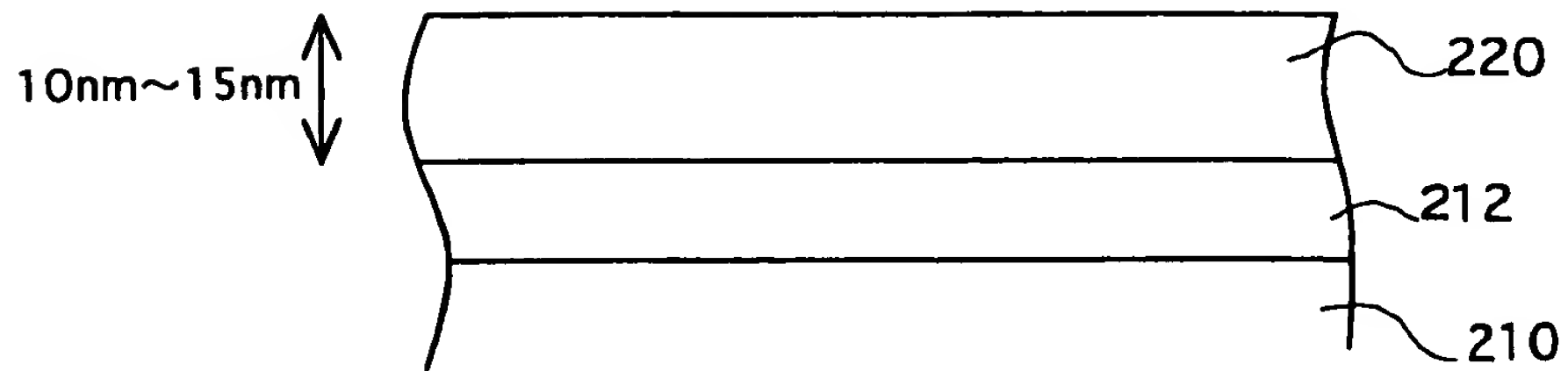
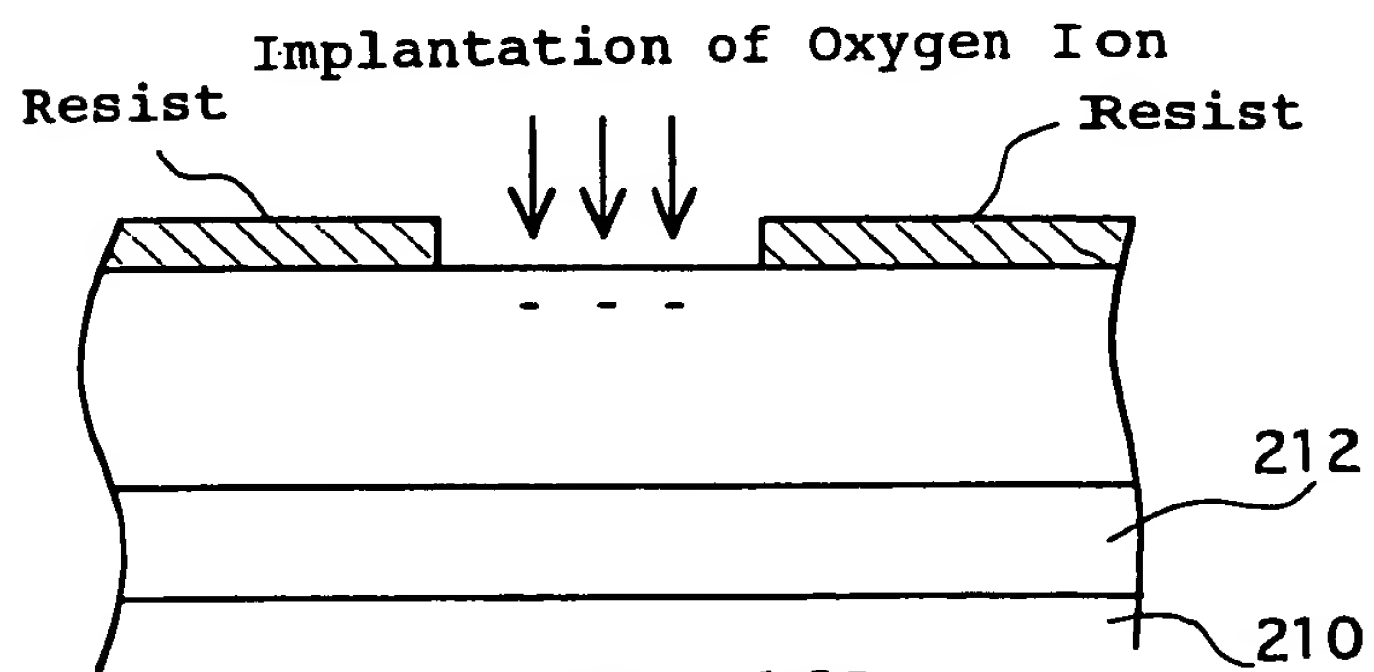
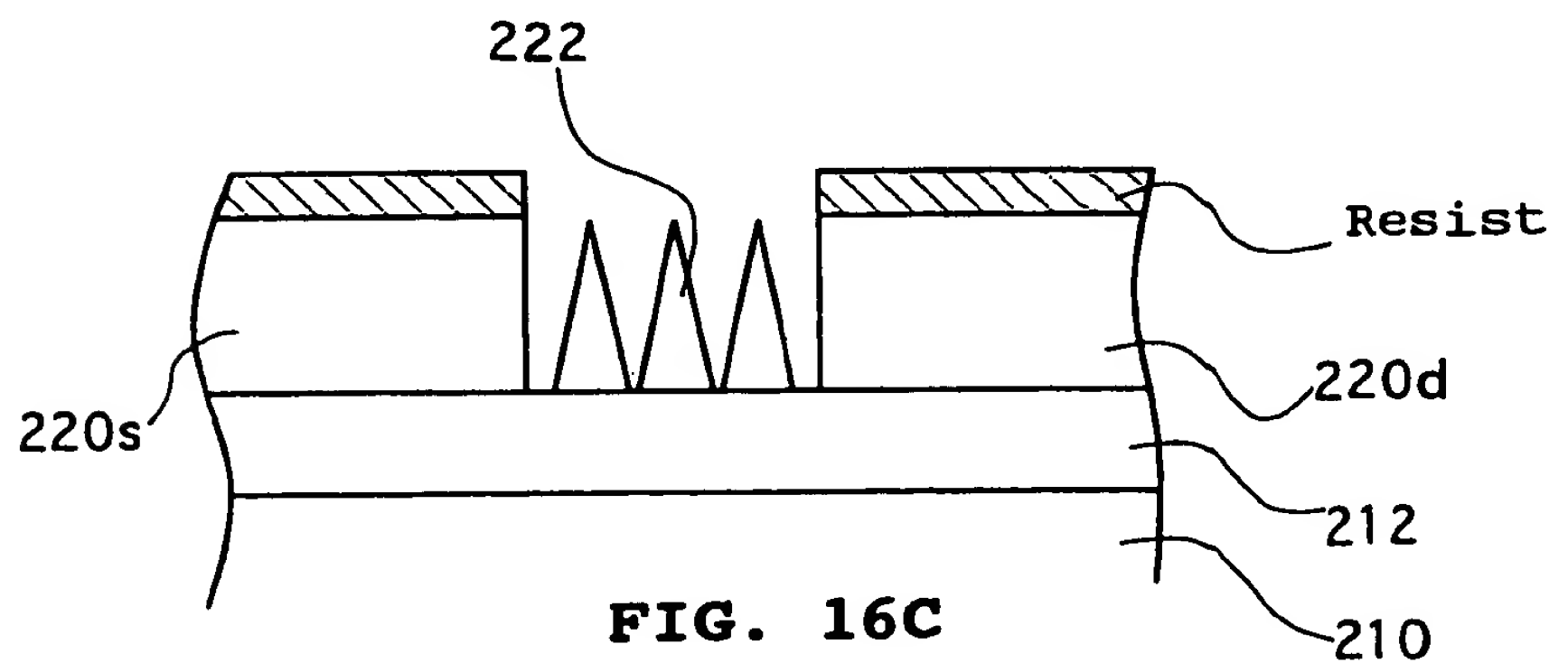
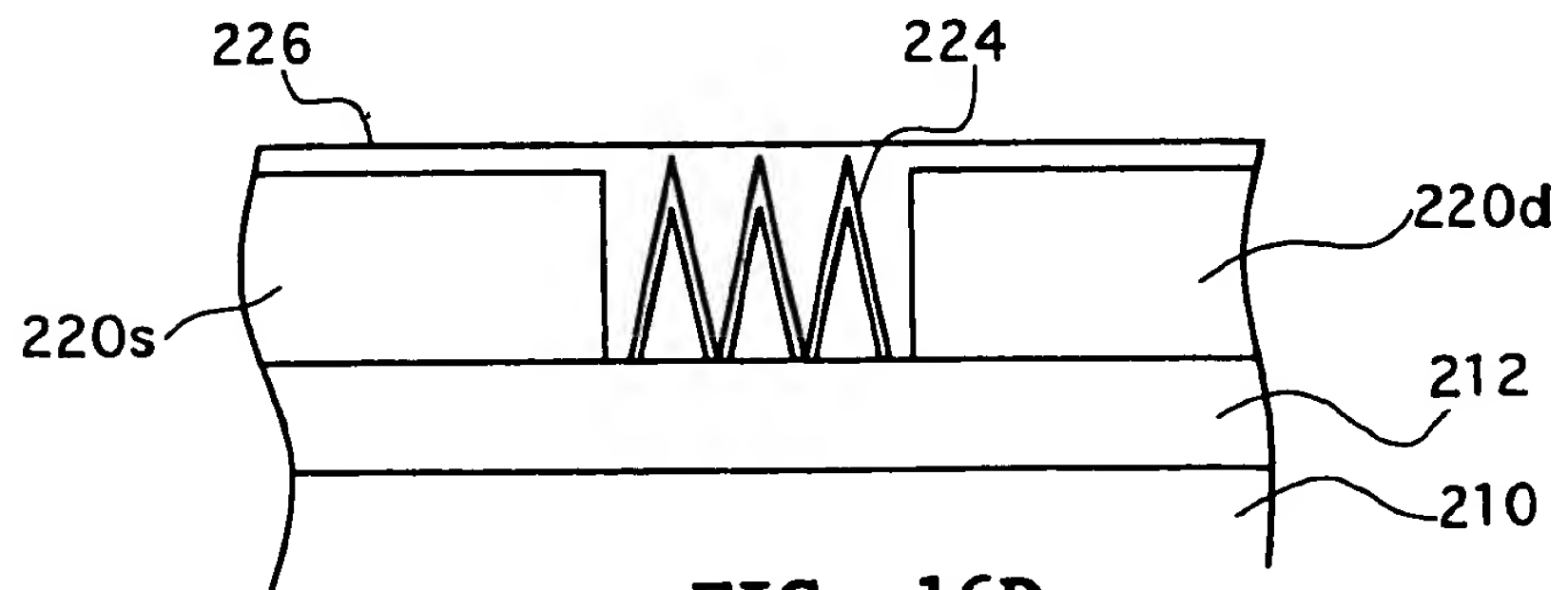


FIG. 14B PRIOR ART

**FIG. 15A****FIG. 15B**

**FIG. 16A****FIG. 16B****FIG. 16C****FIG. 16D**

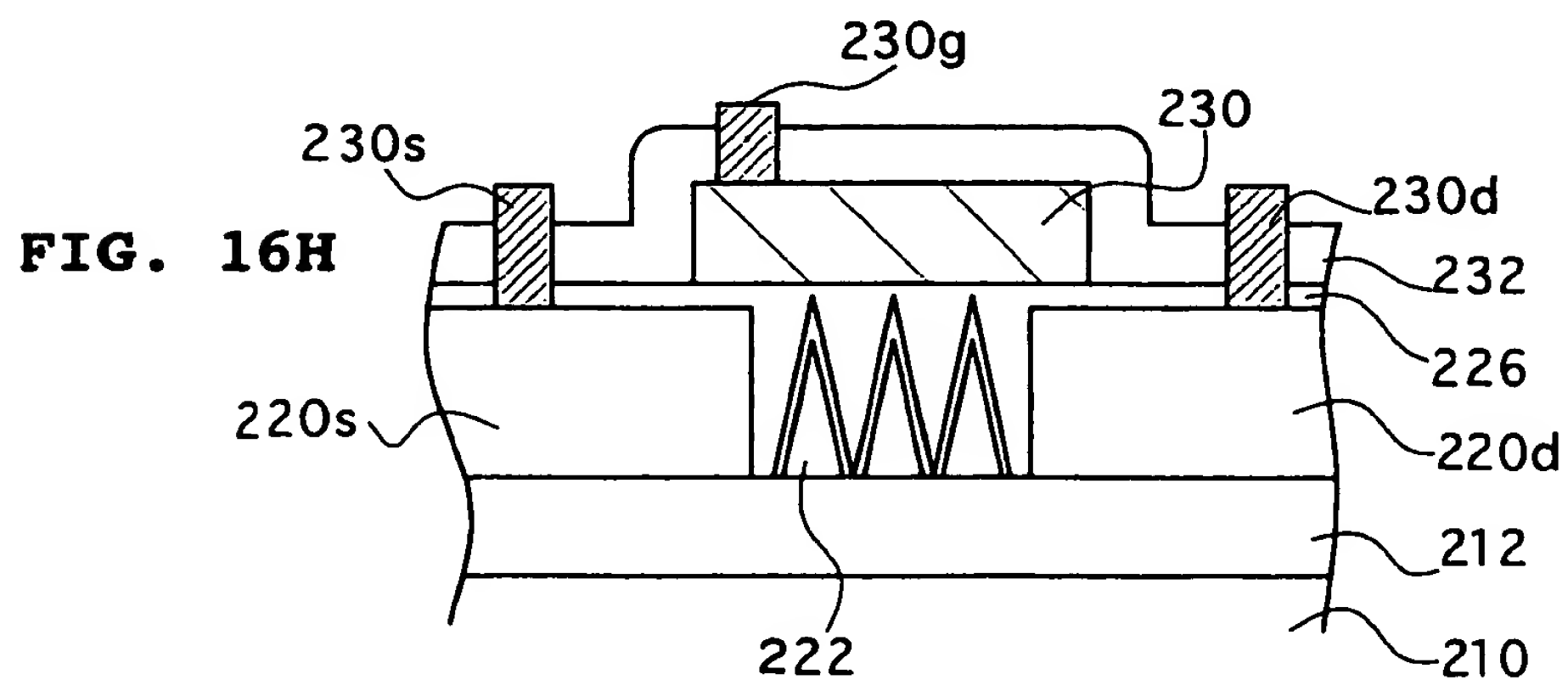
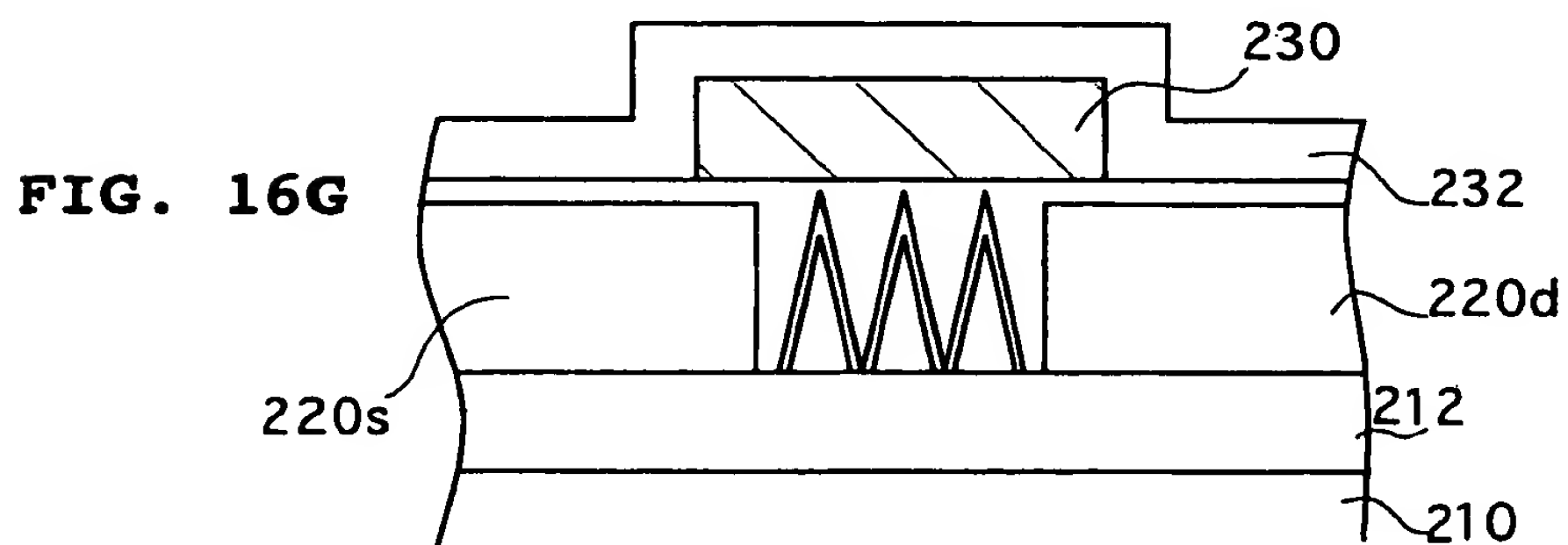
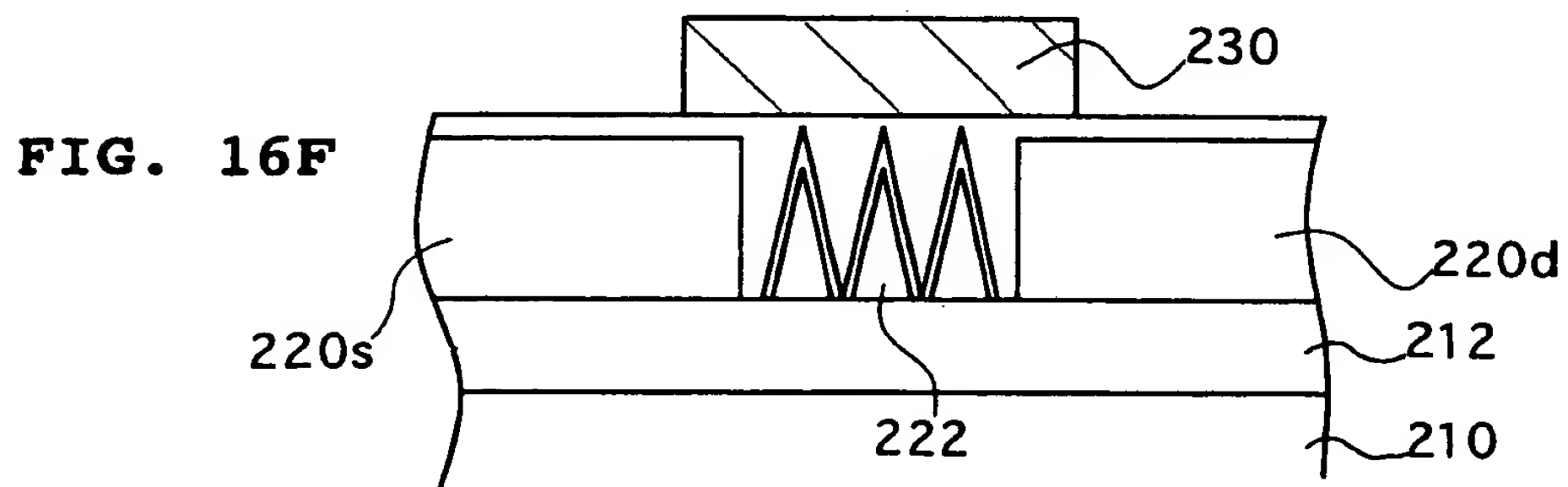
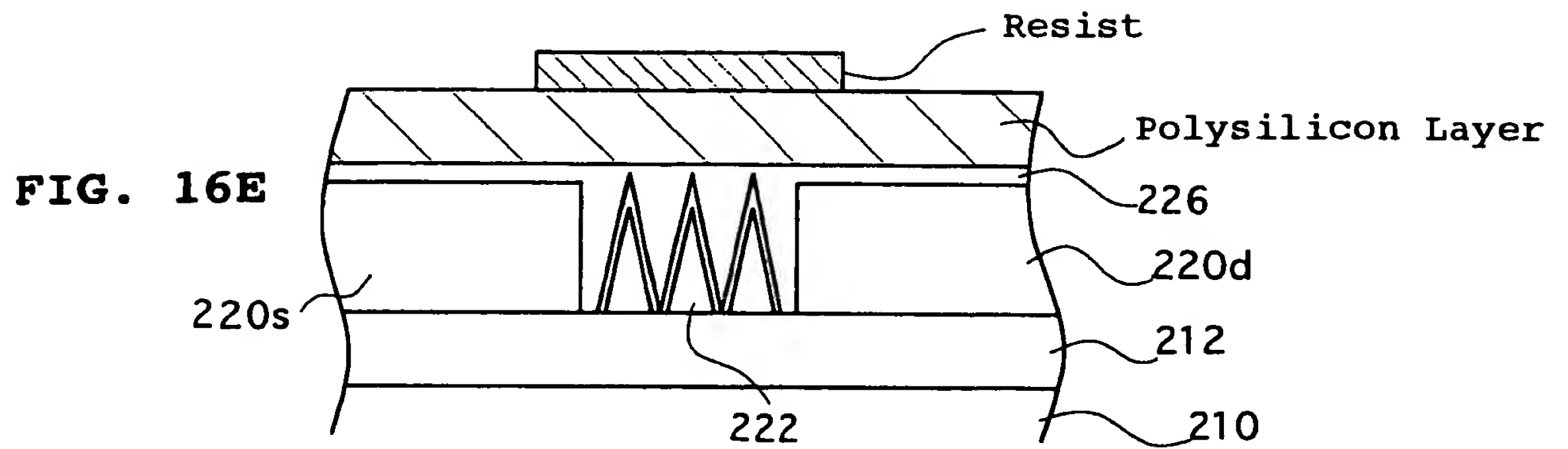
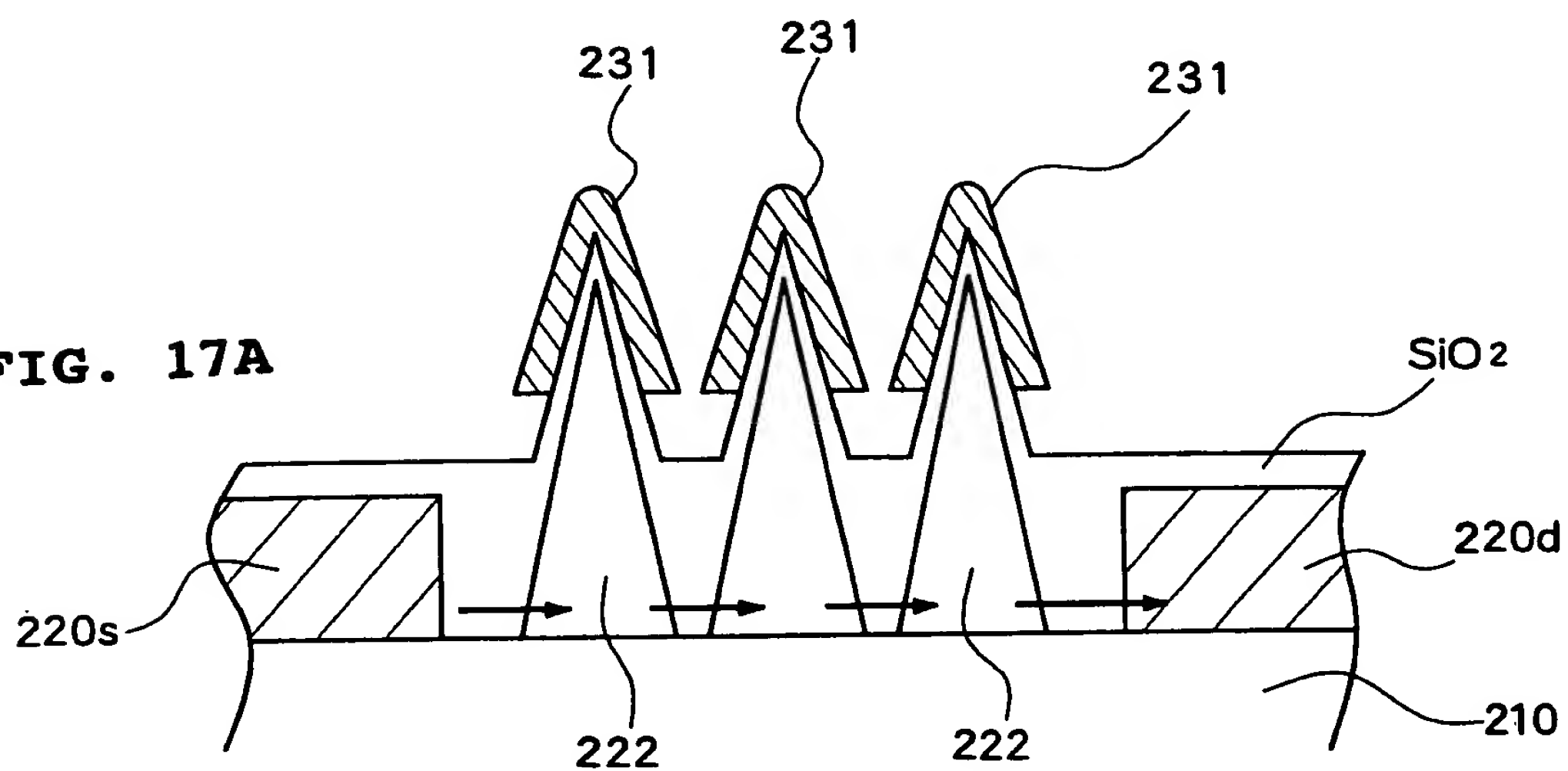


FIG. 17A



Selective Gate Control

FIG. 17B

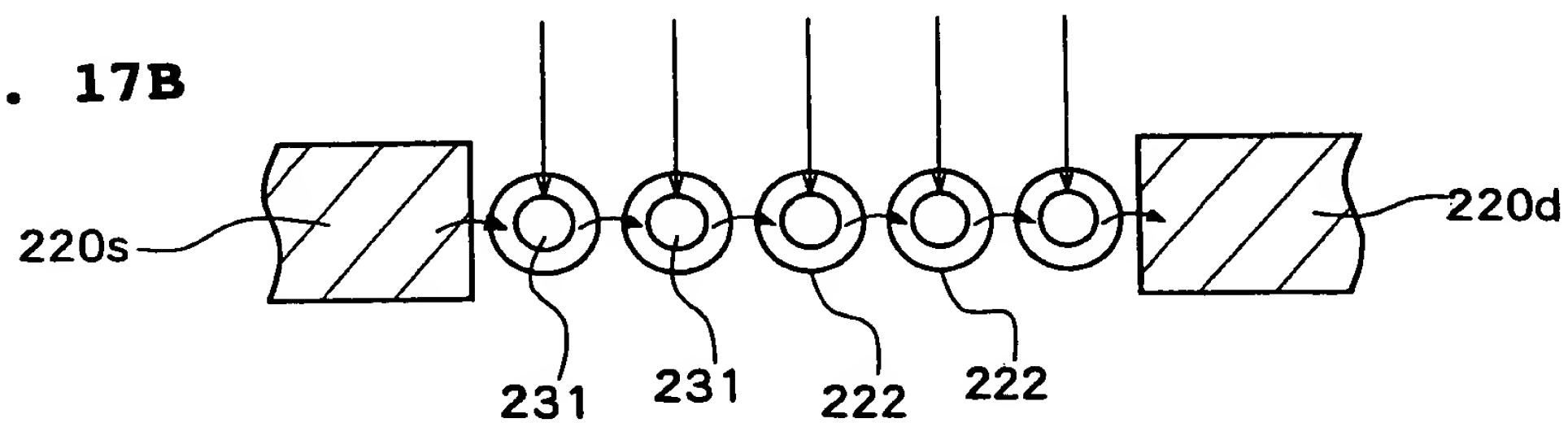
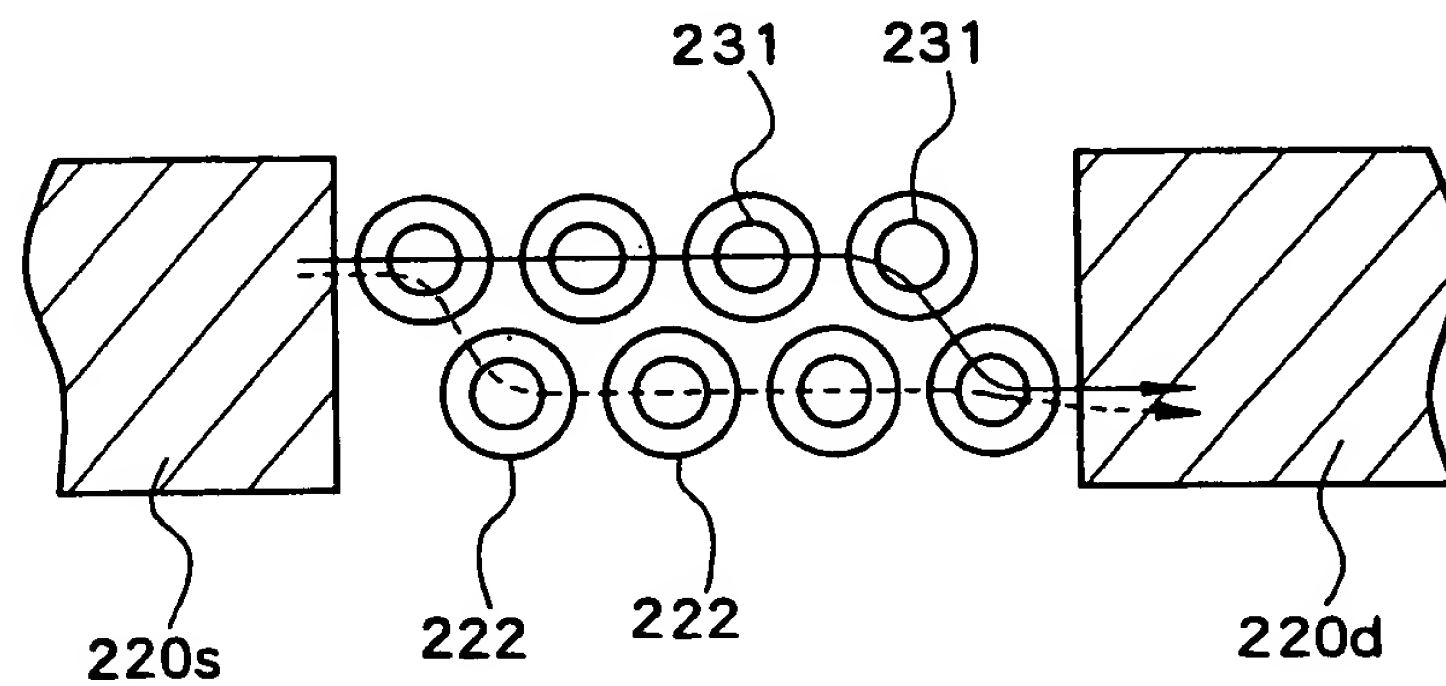
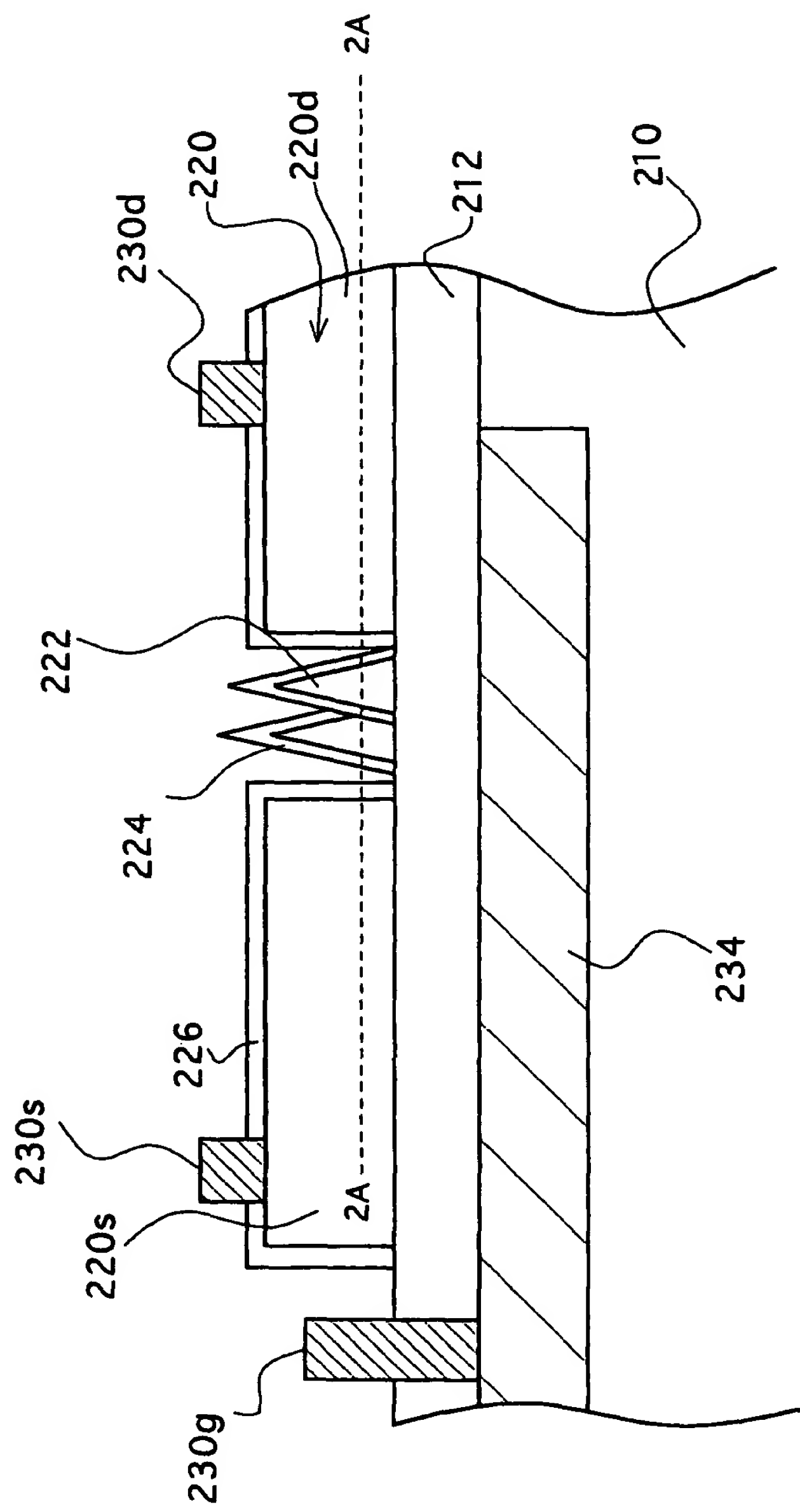


FIG. 17C





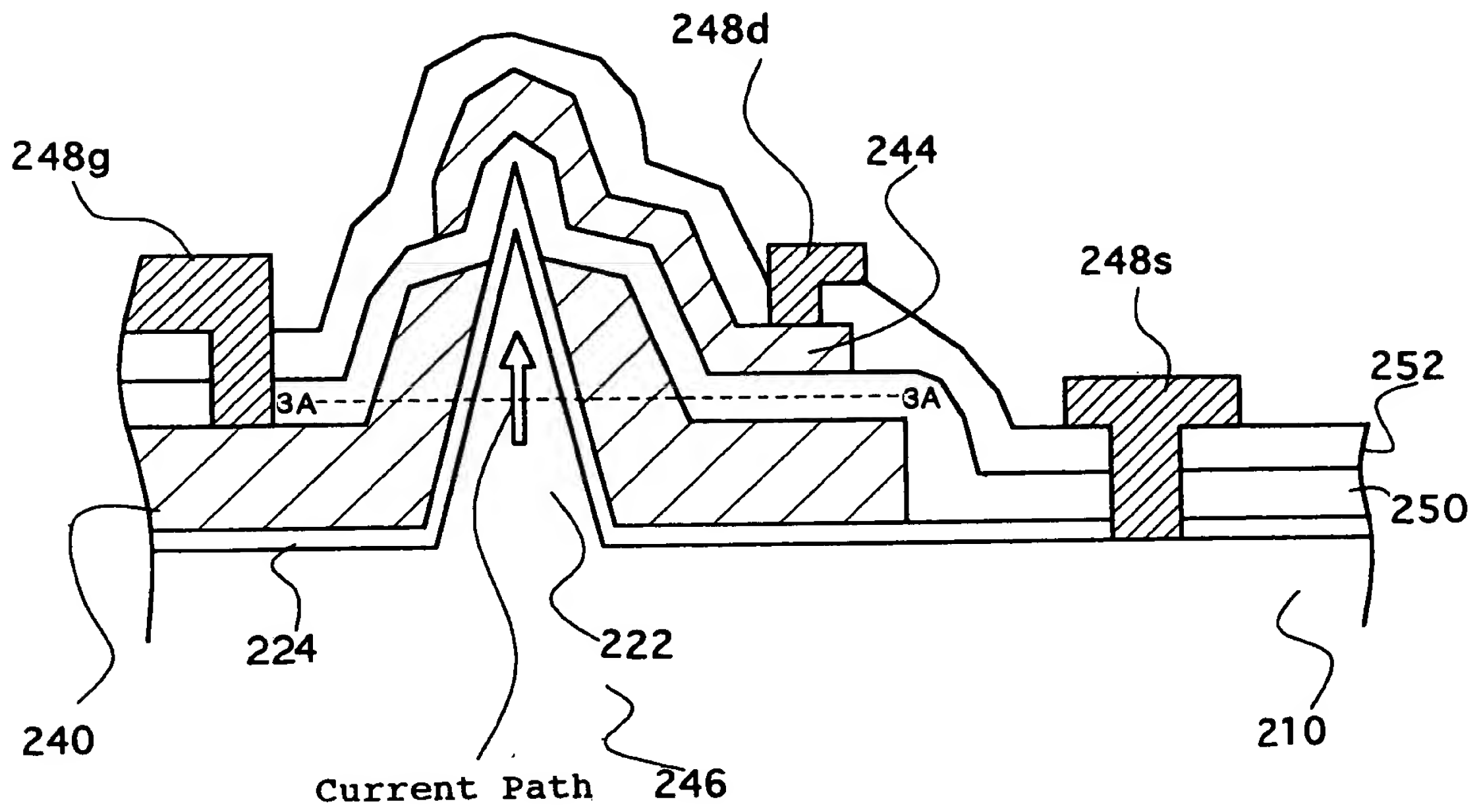


FIG. 19A

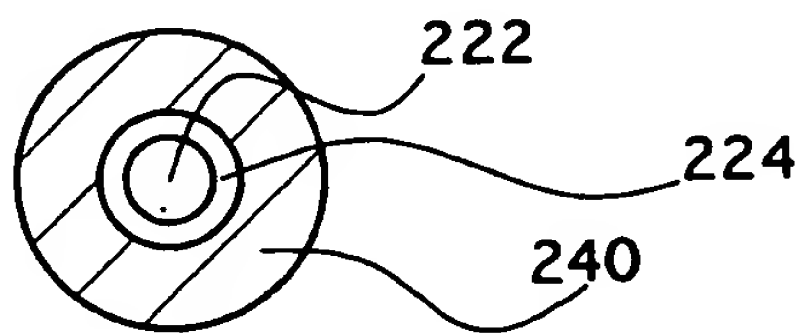


FIG. 19B

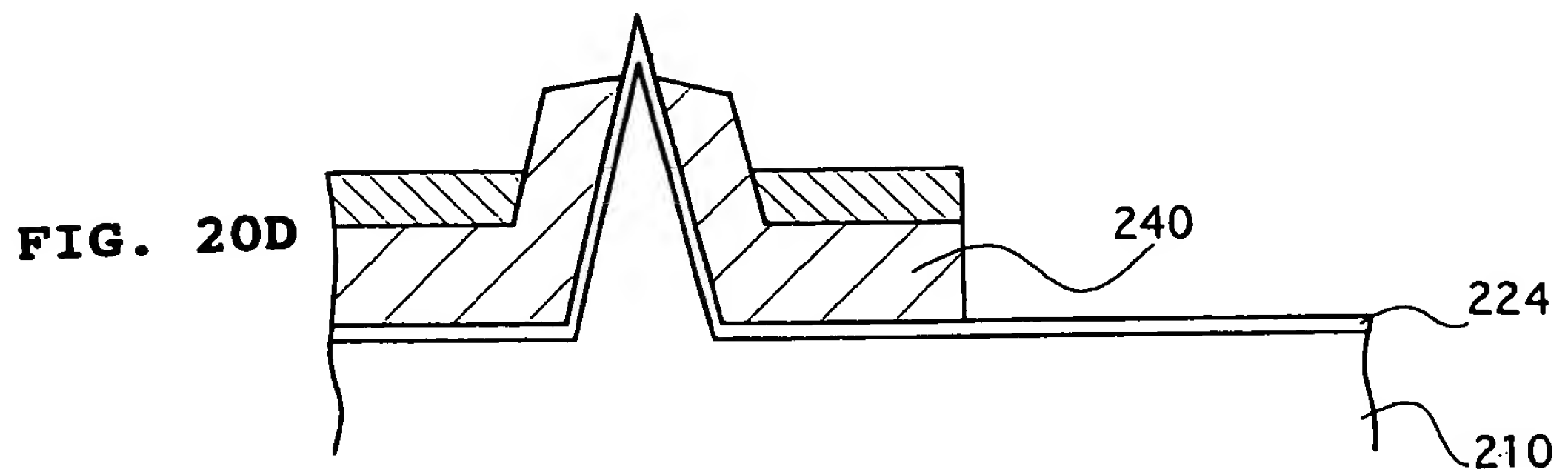
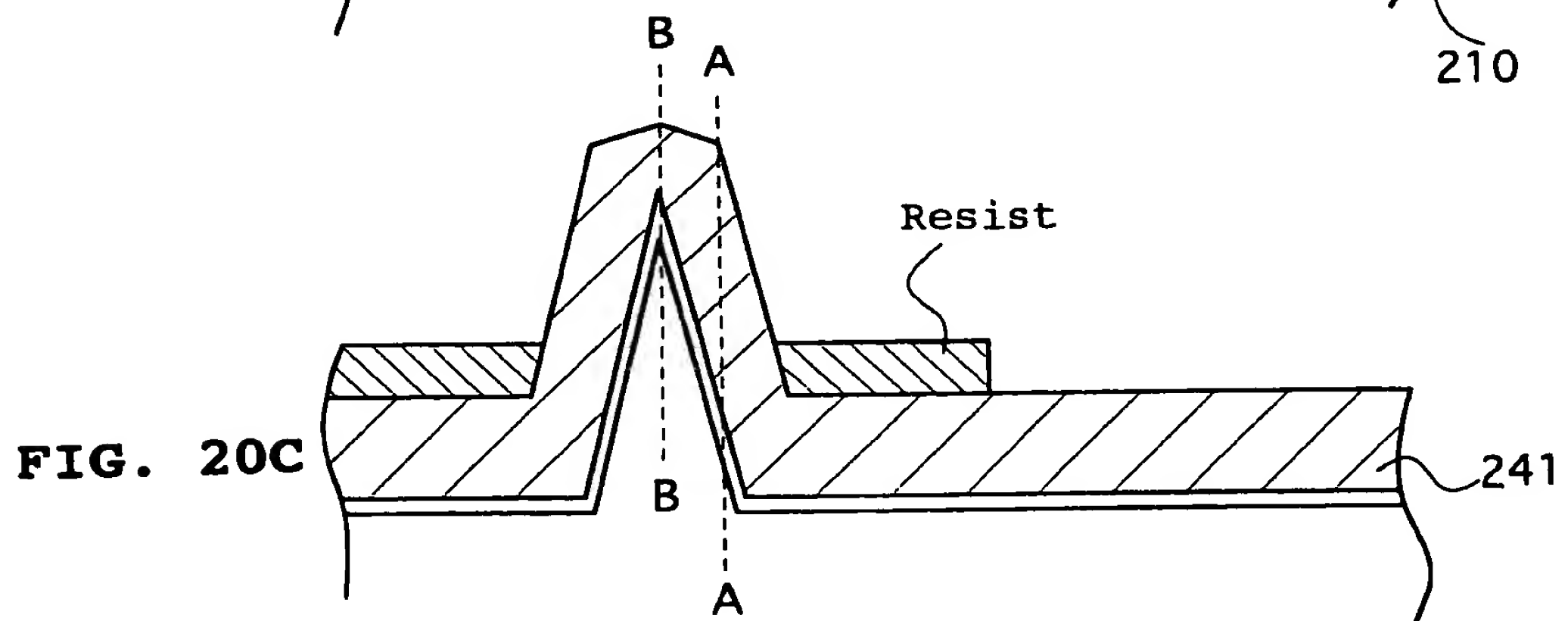
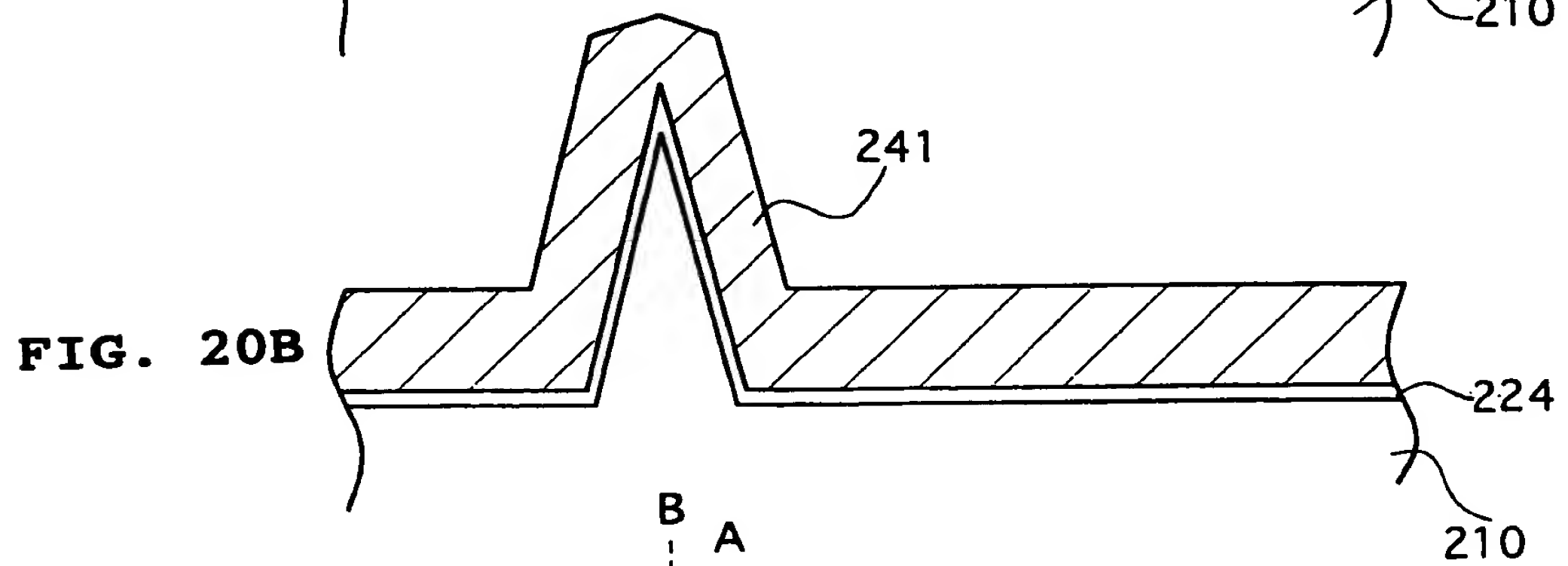
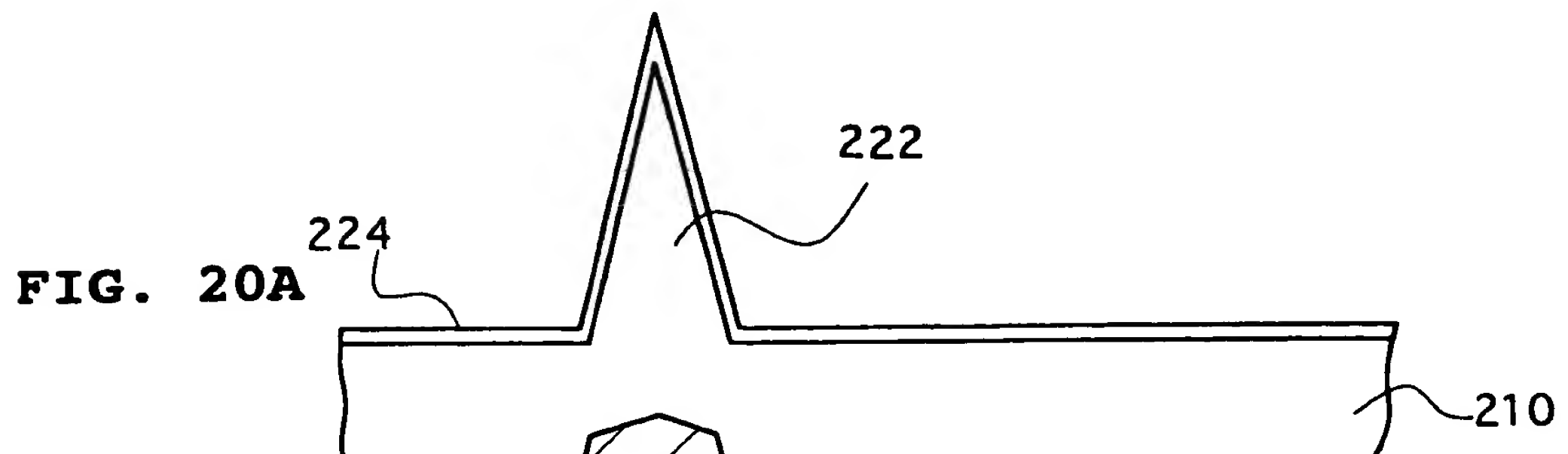


FIG. 20E

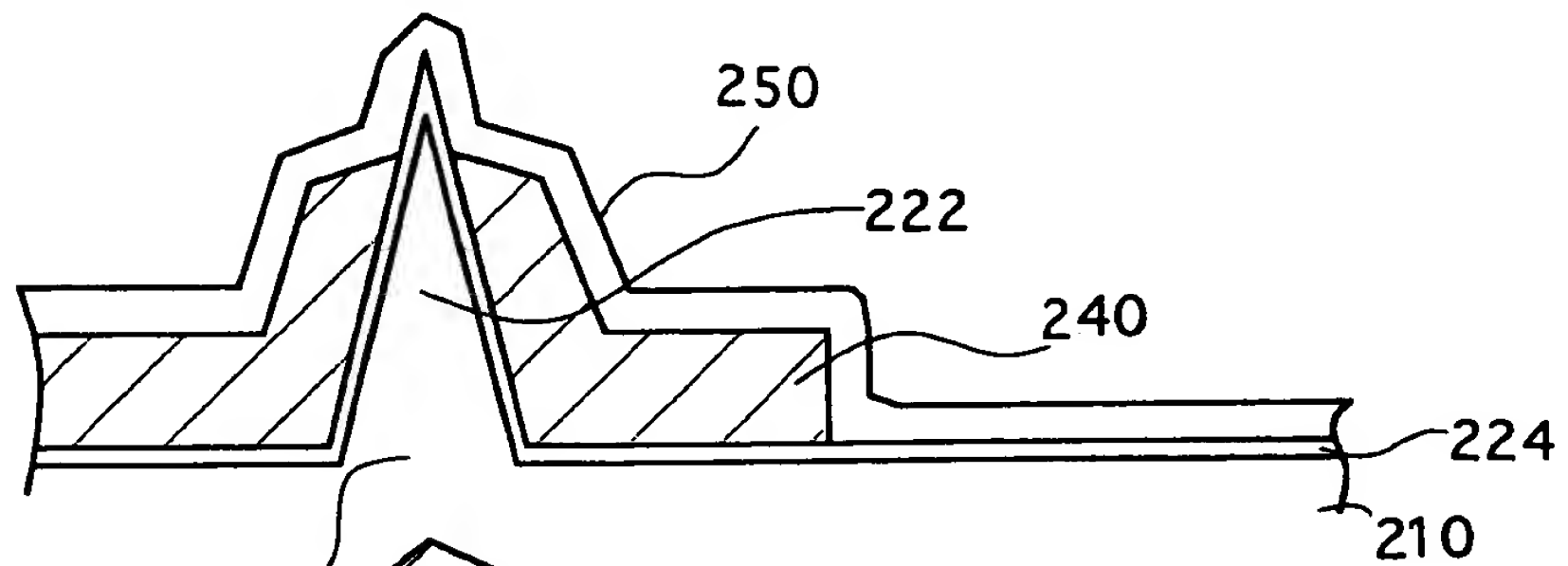


FIG. 20F

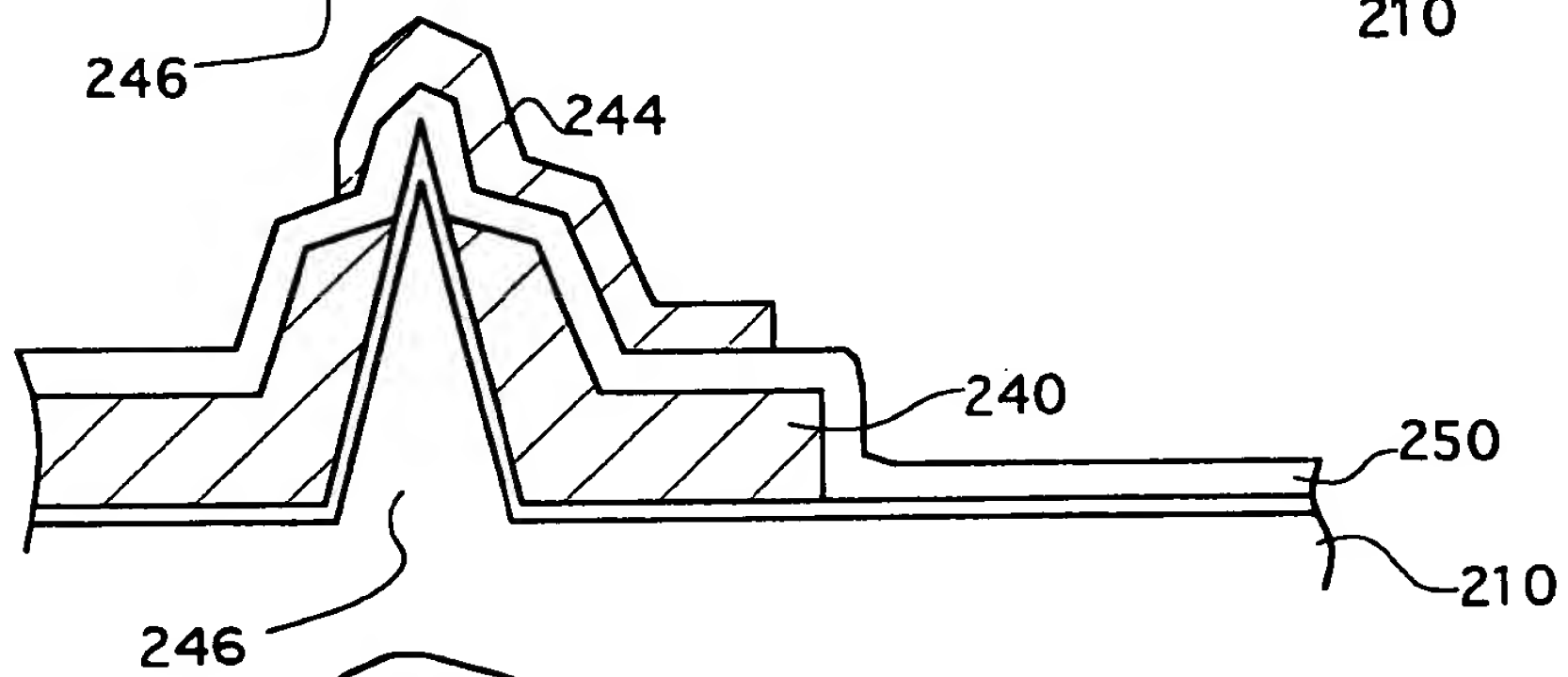


FIG. 20G

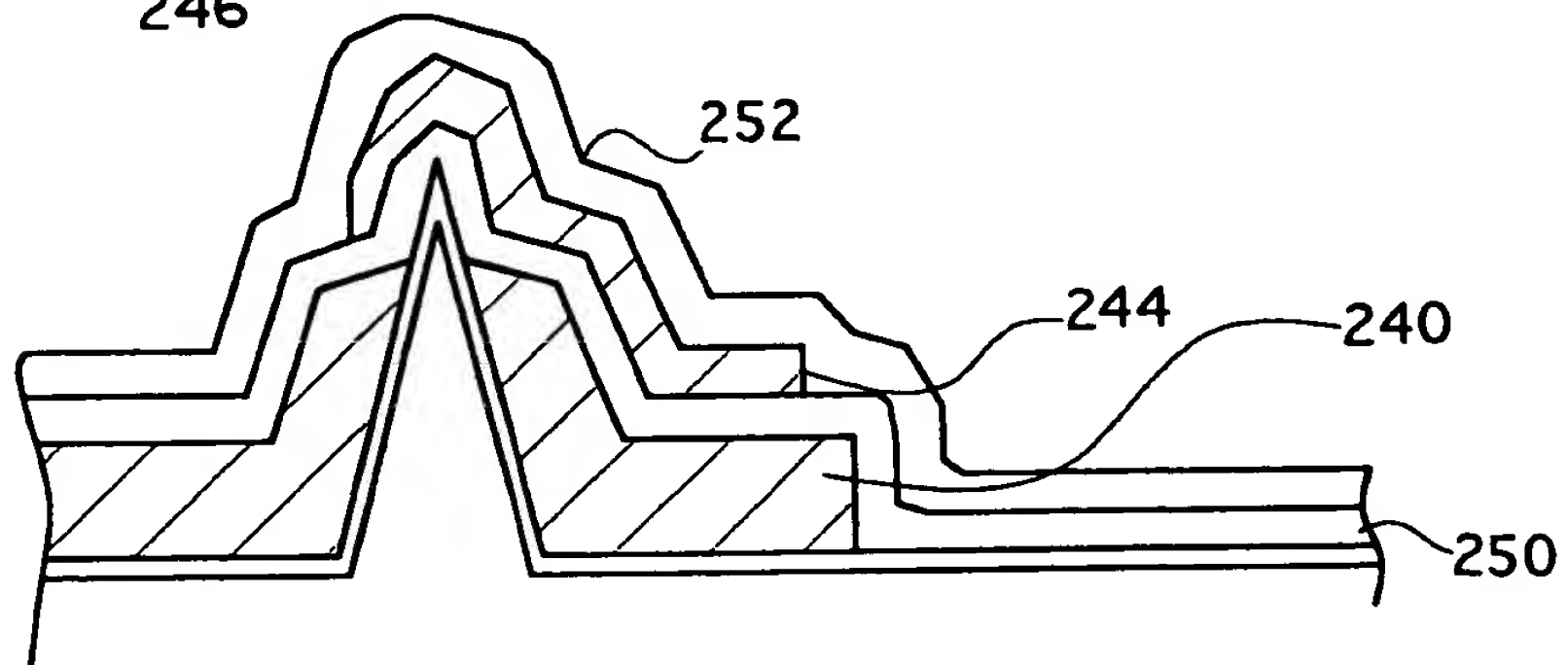
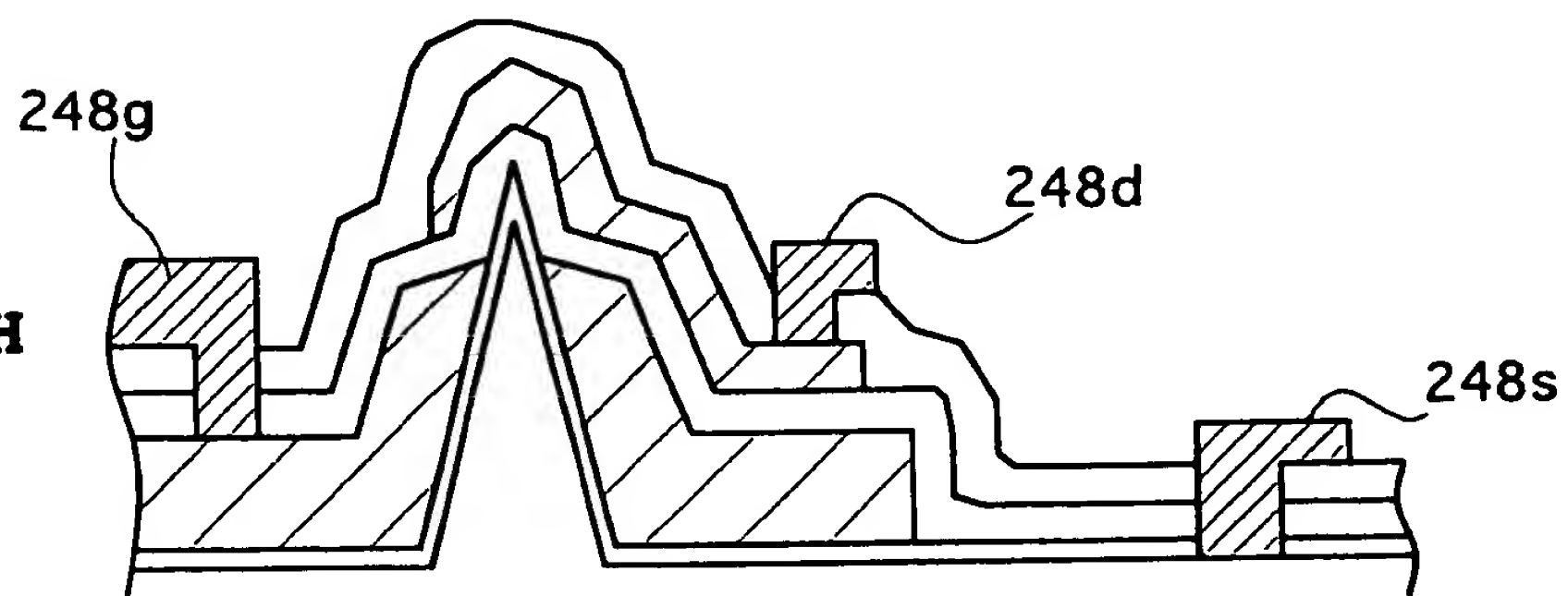


FIG. 20H



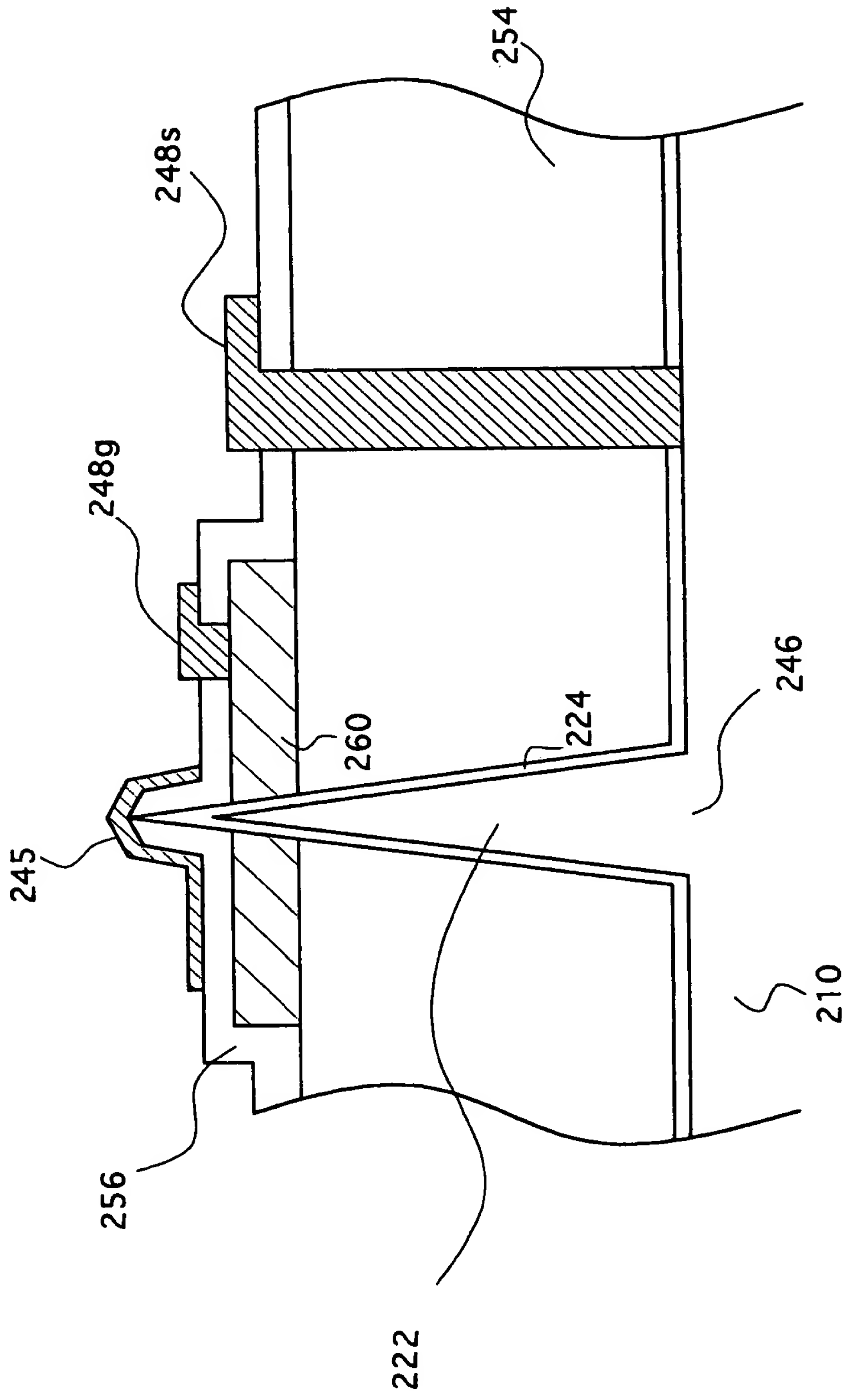


FIG. 21

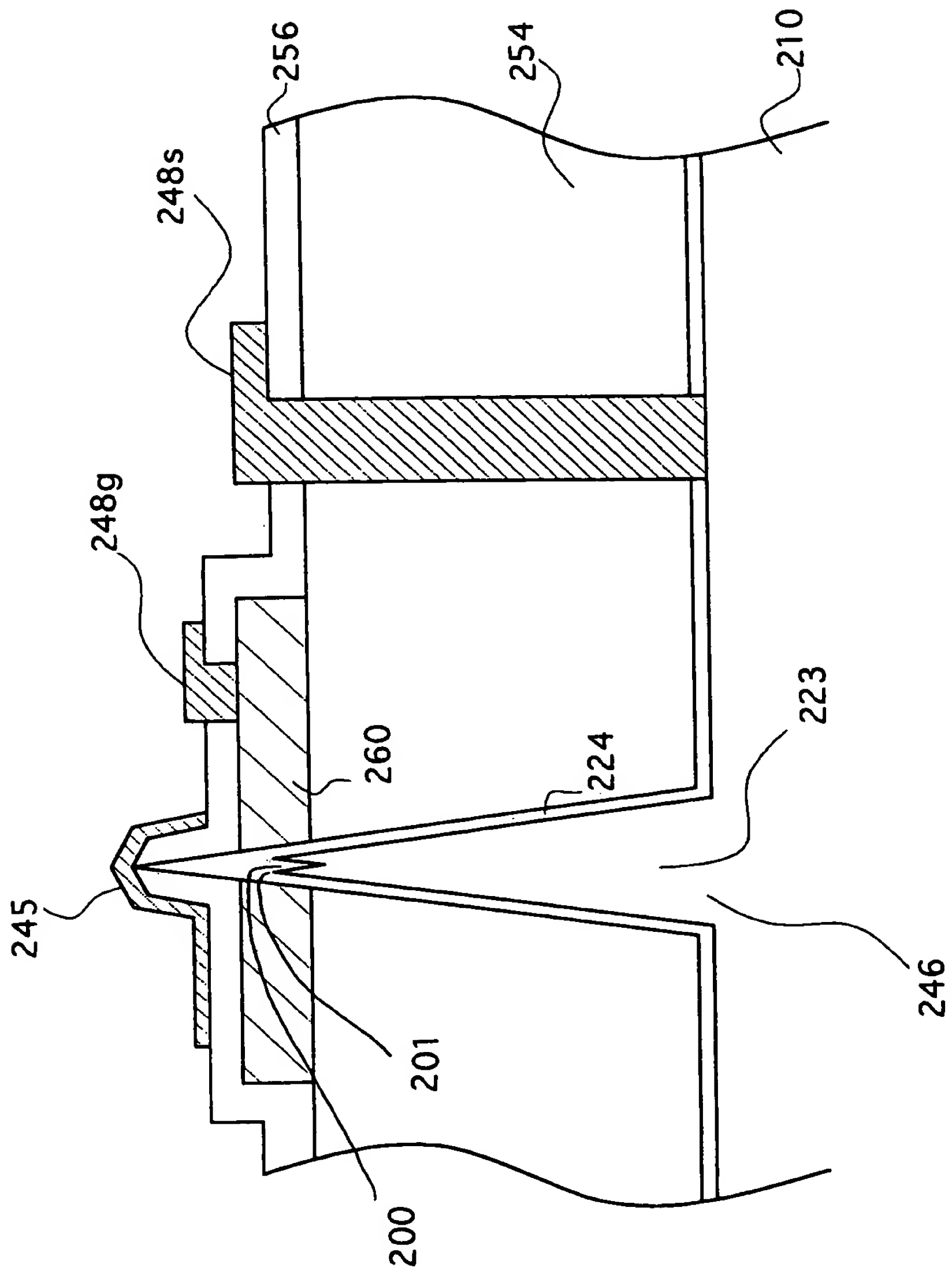
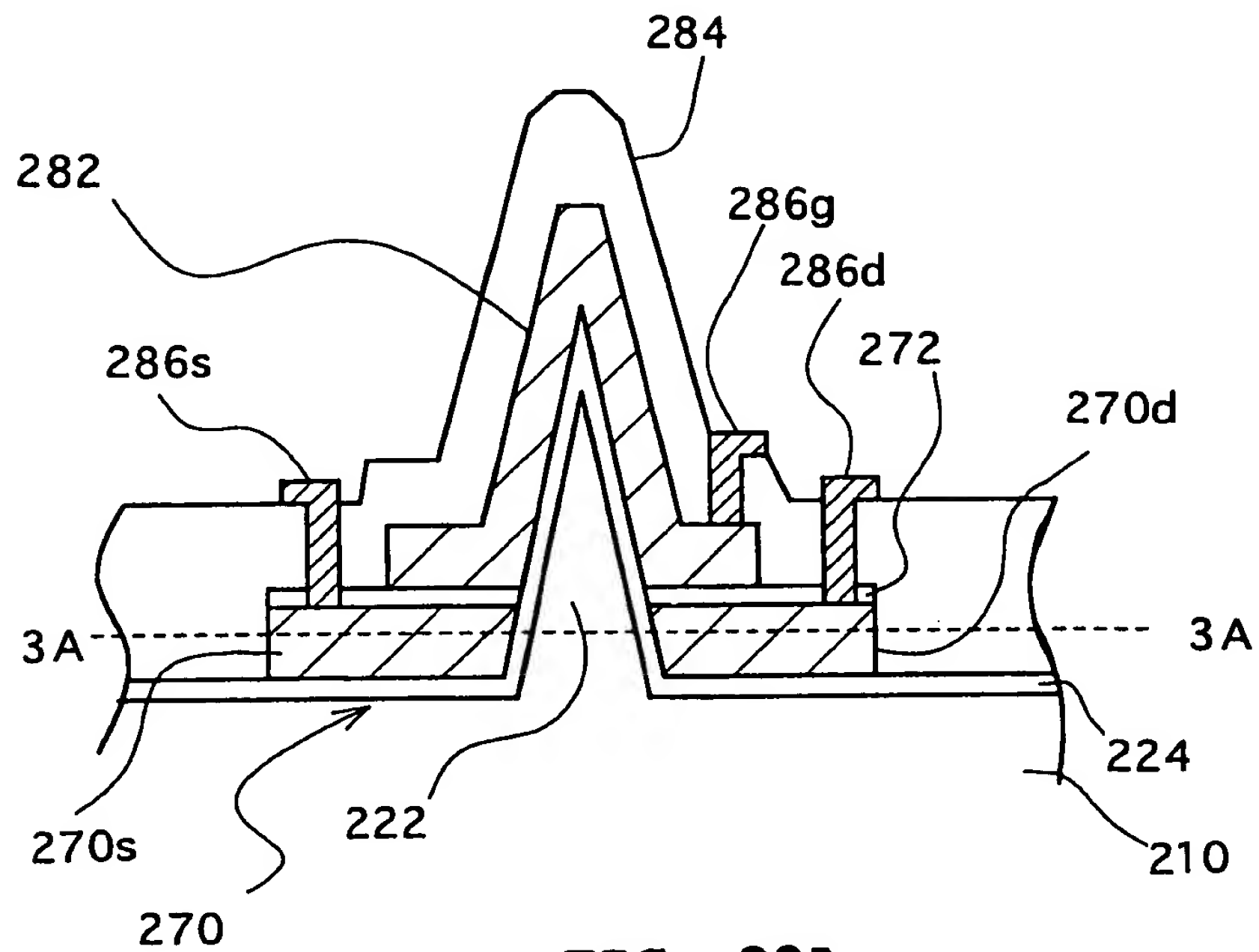
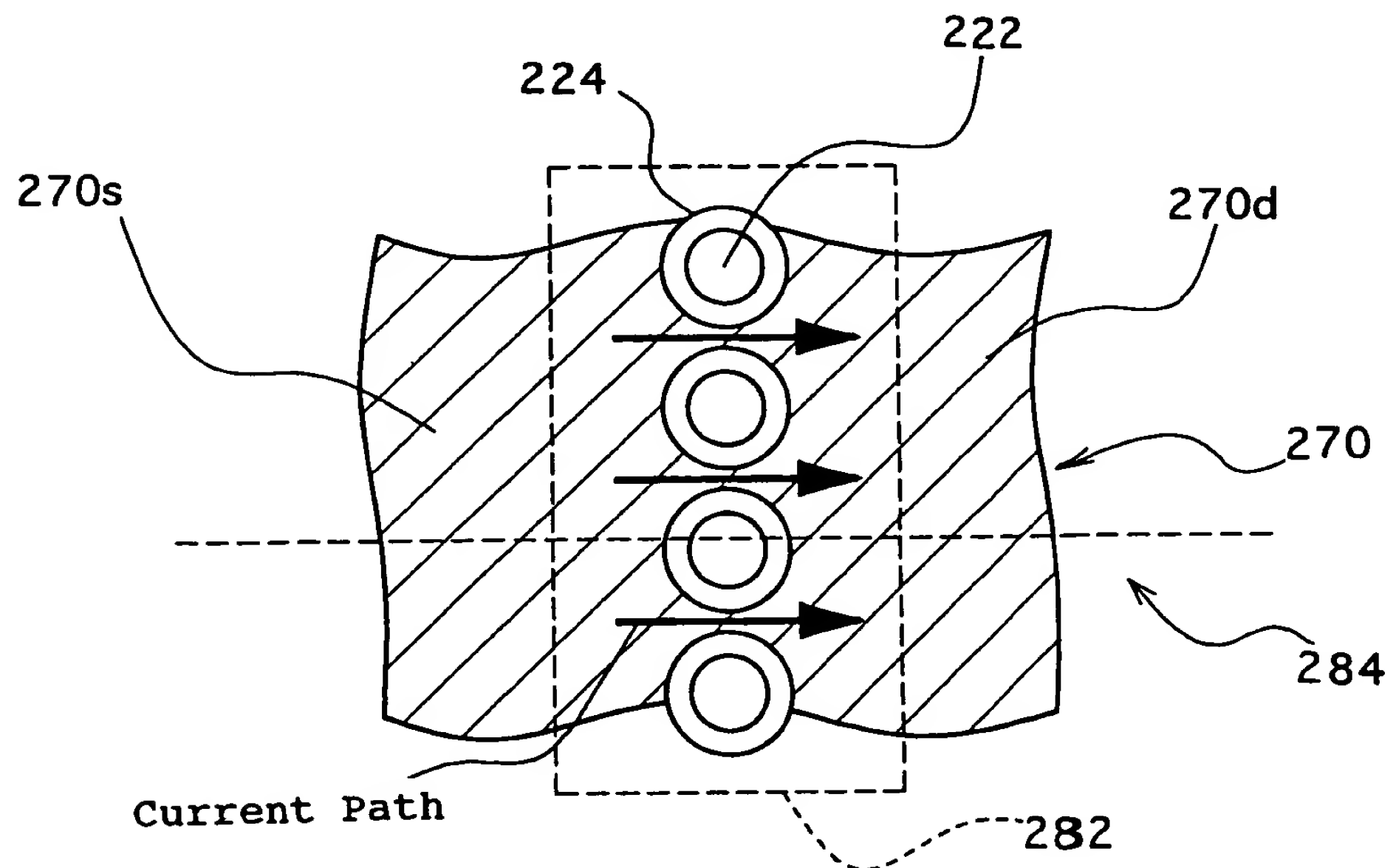


FIG. 22

**FIG. 23A****FIG. 23B**

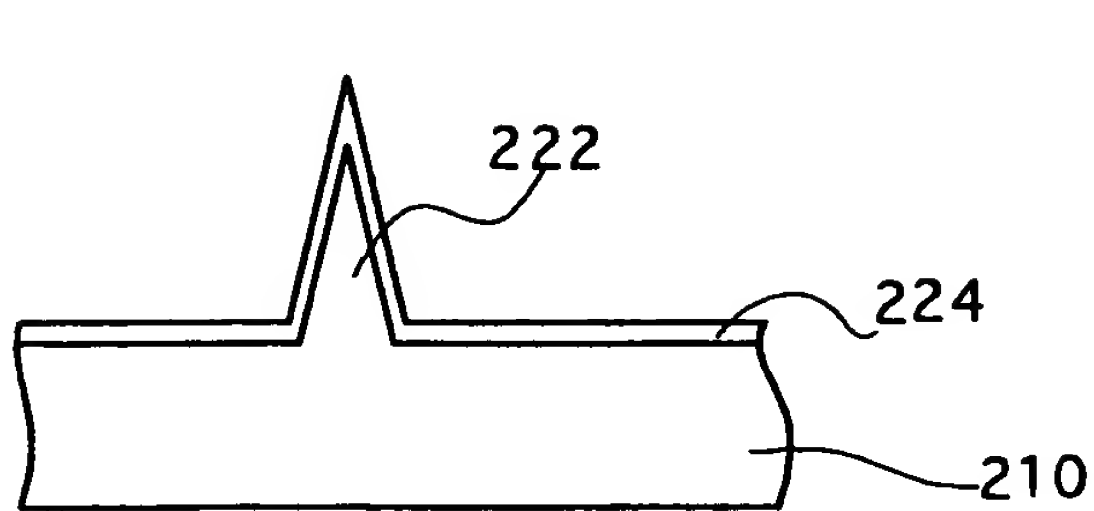


FIG. 24A

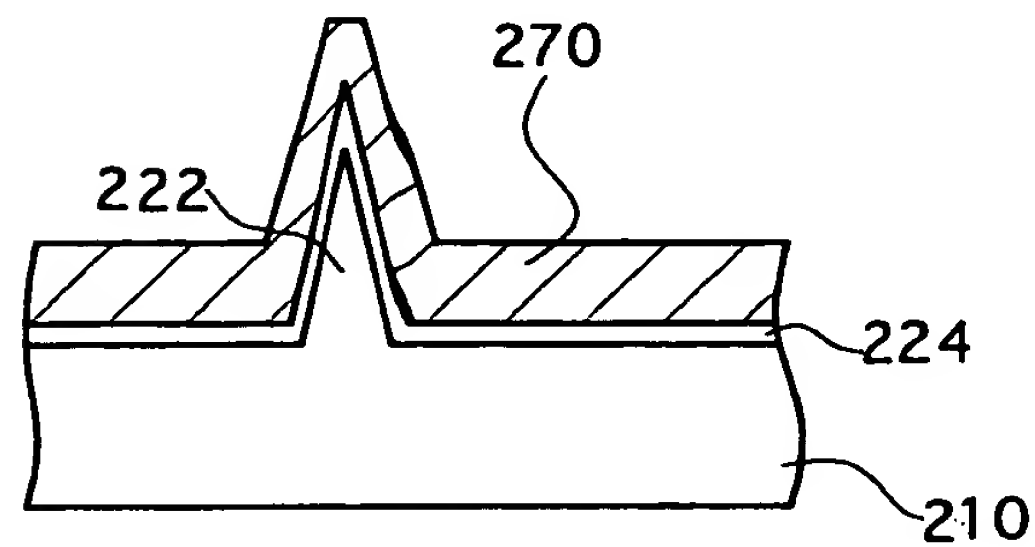


FIG. 24B

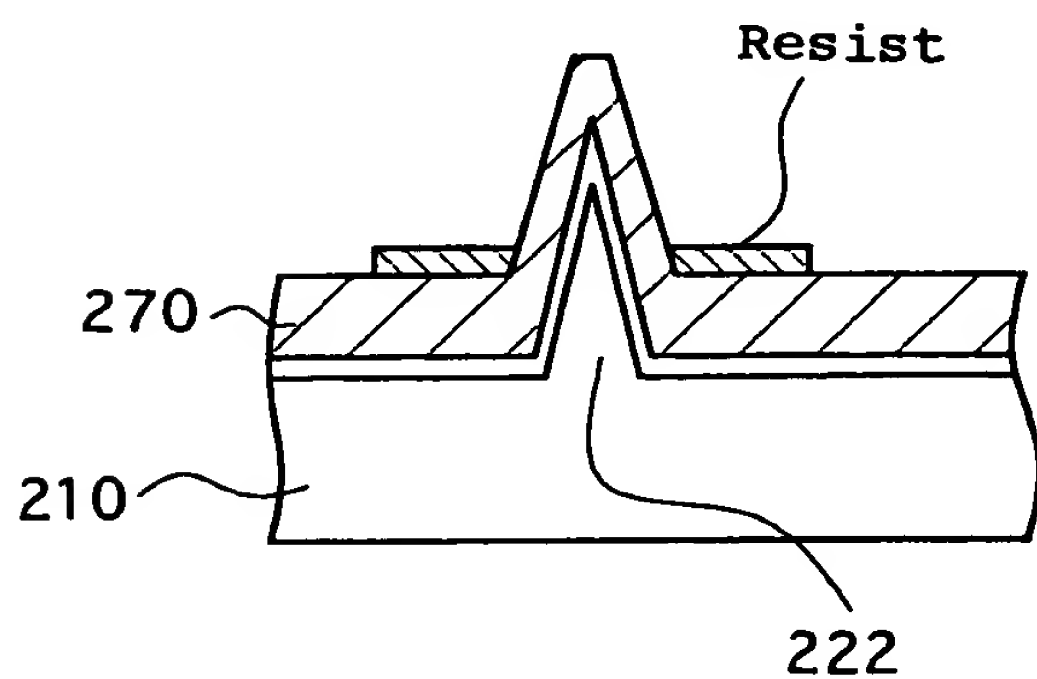


FIG. 24C

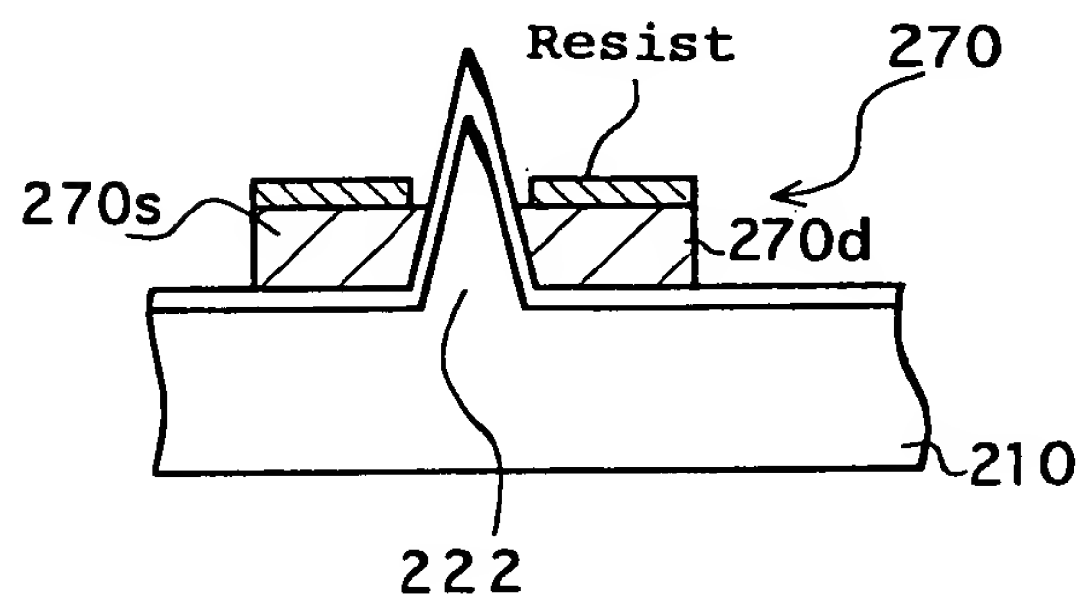


FIG. 24D

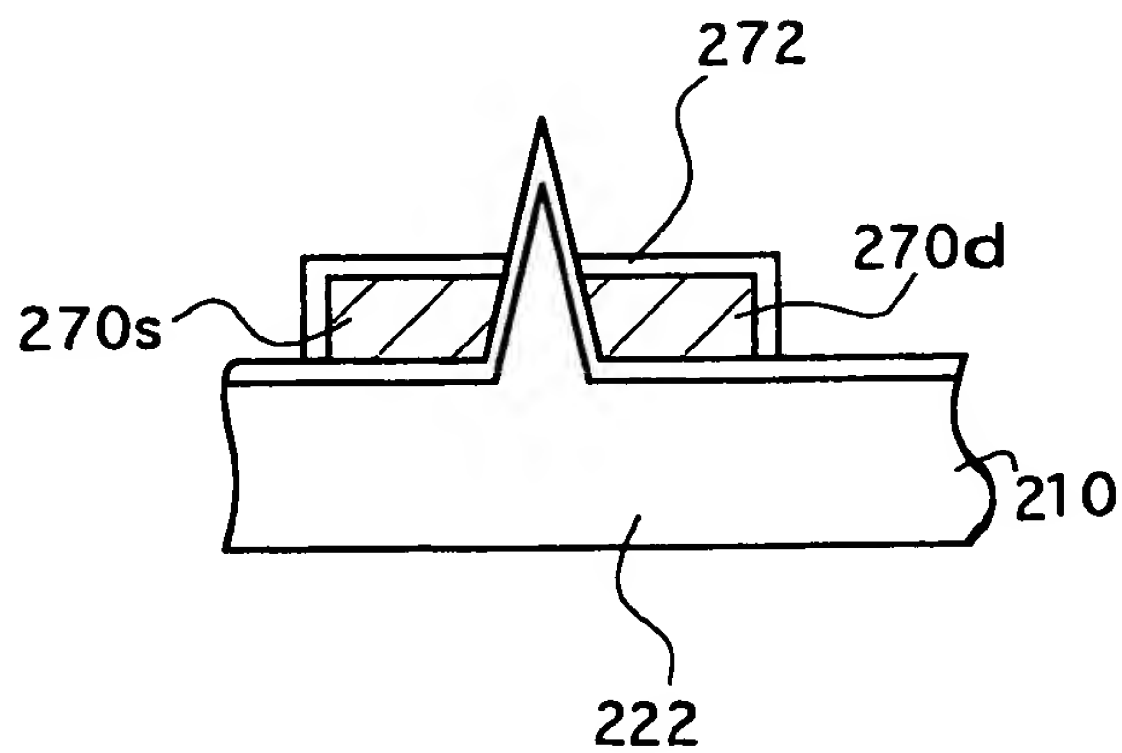
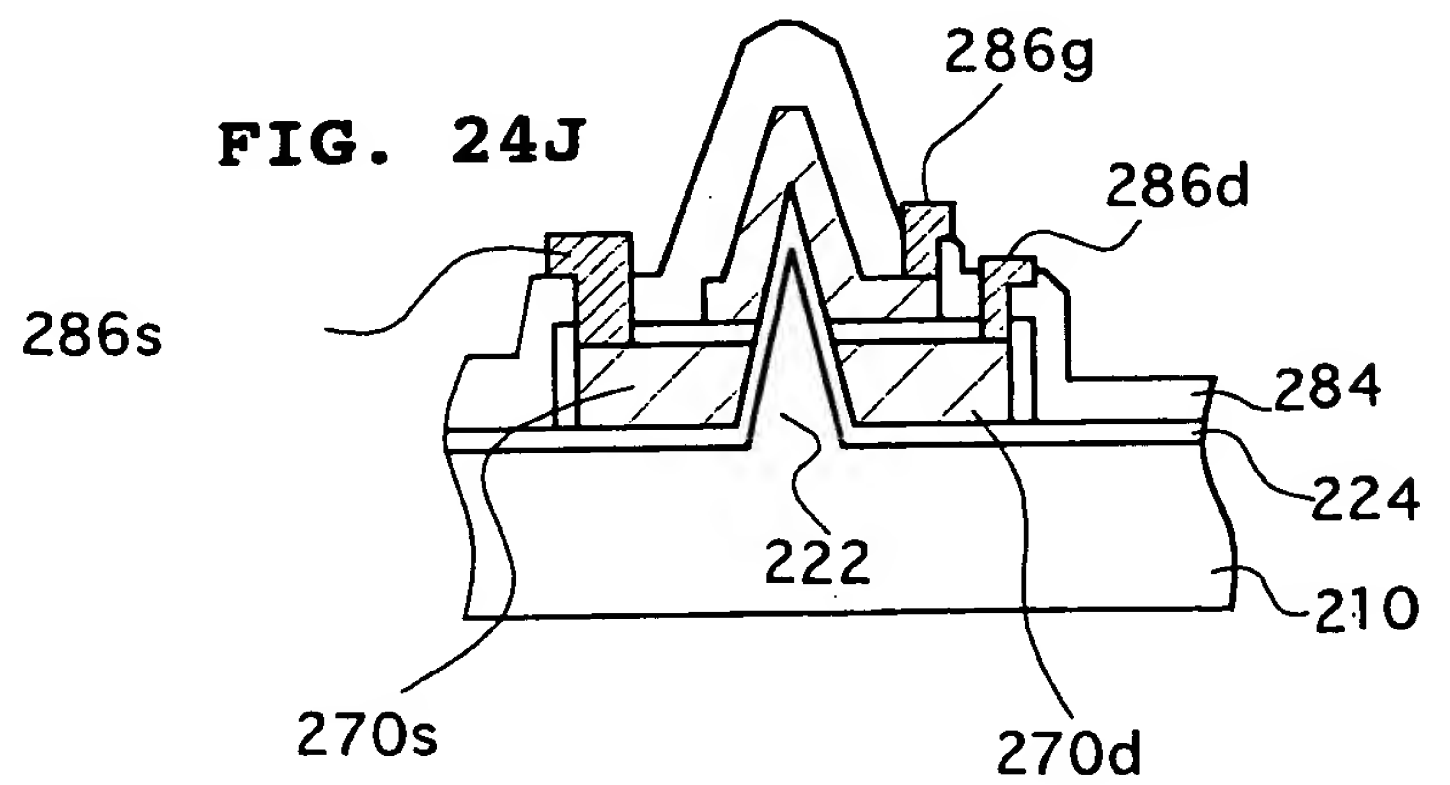
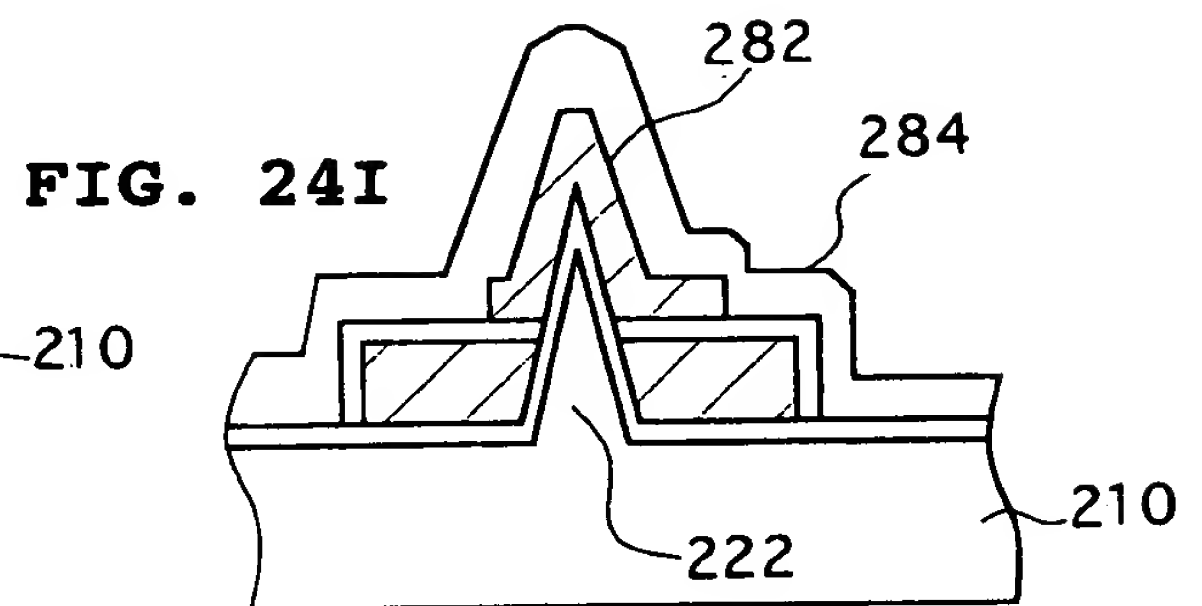
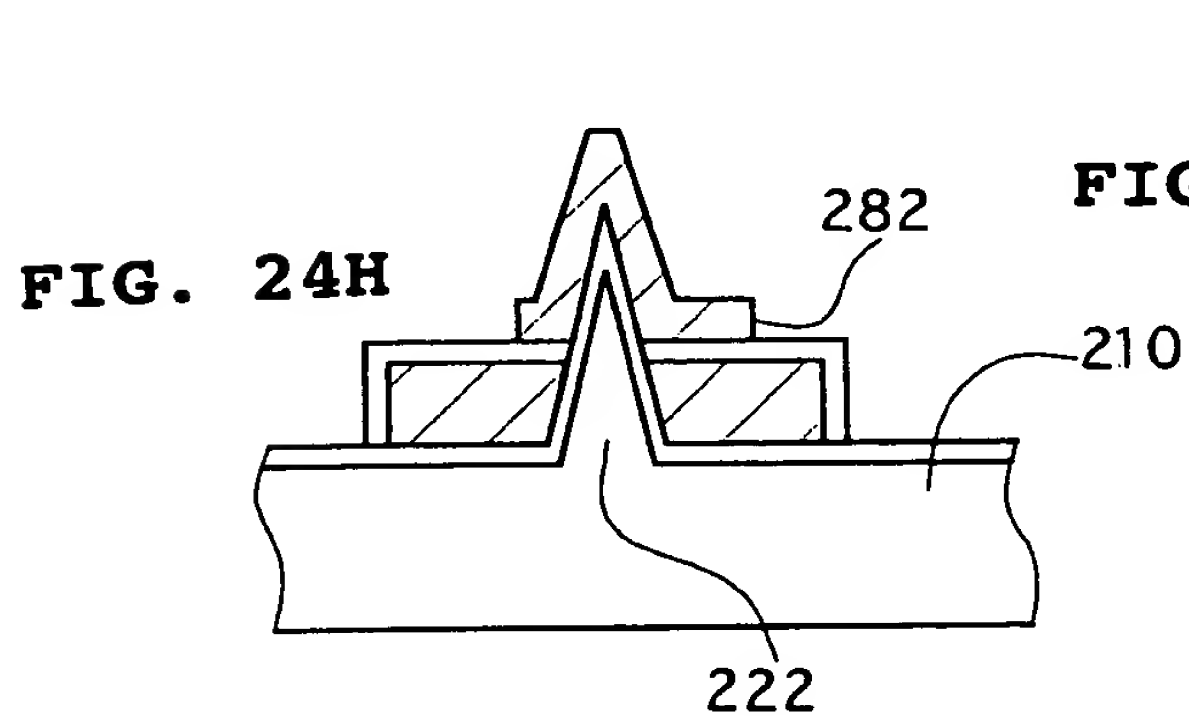
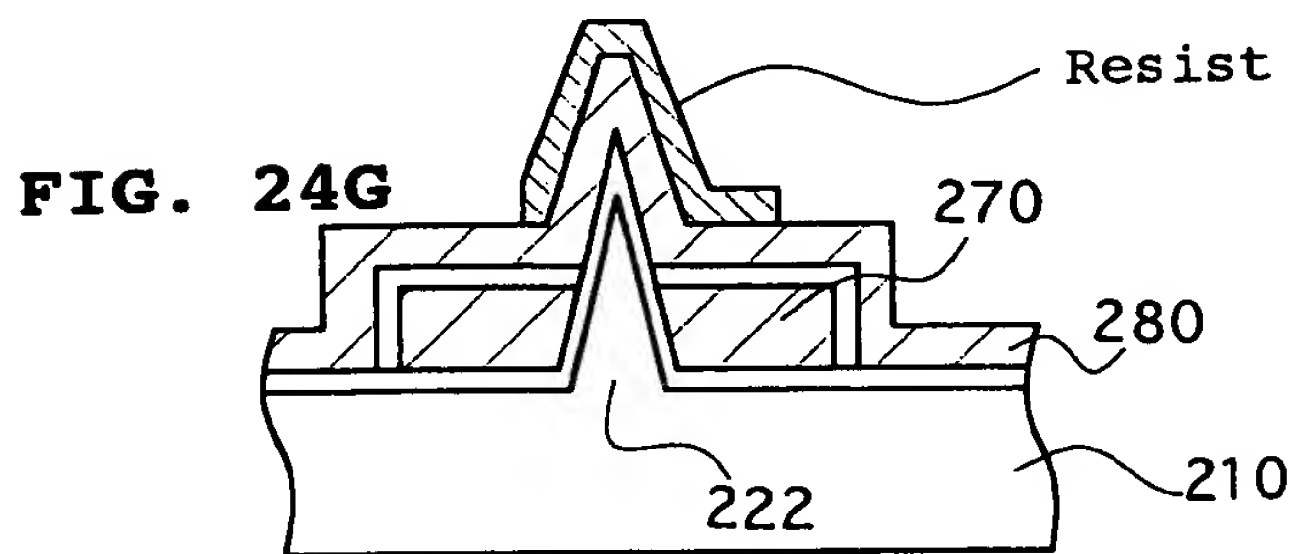
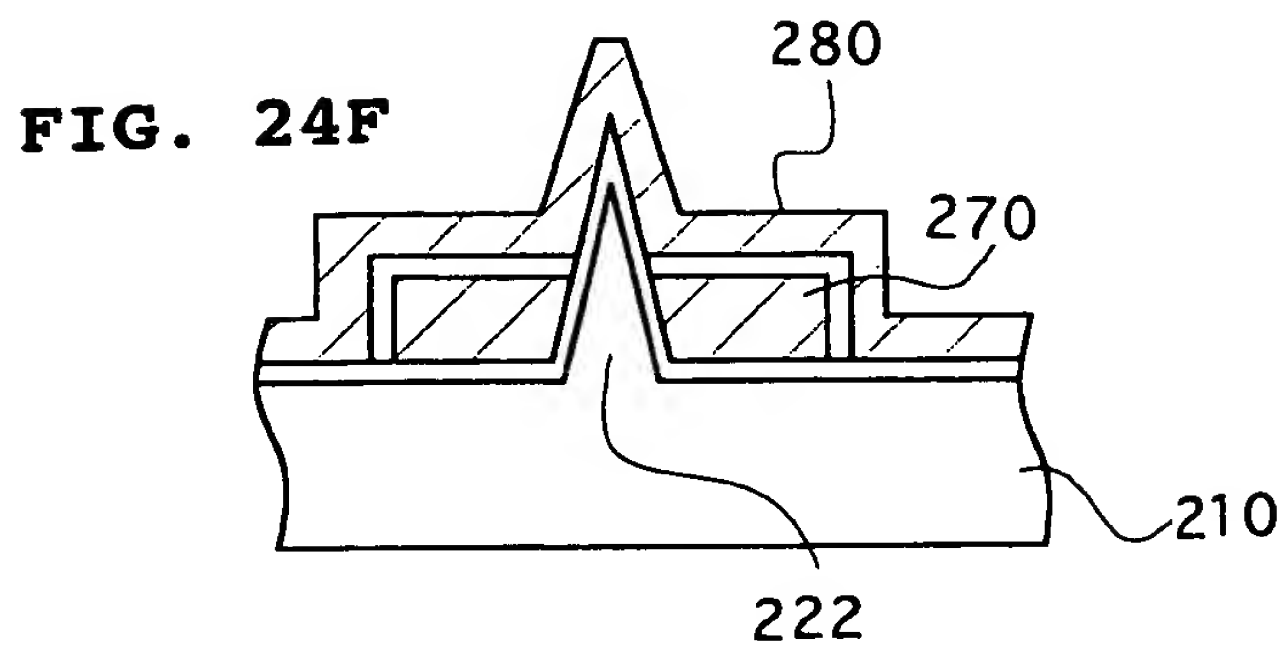


FIG. 24E



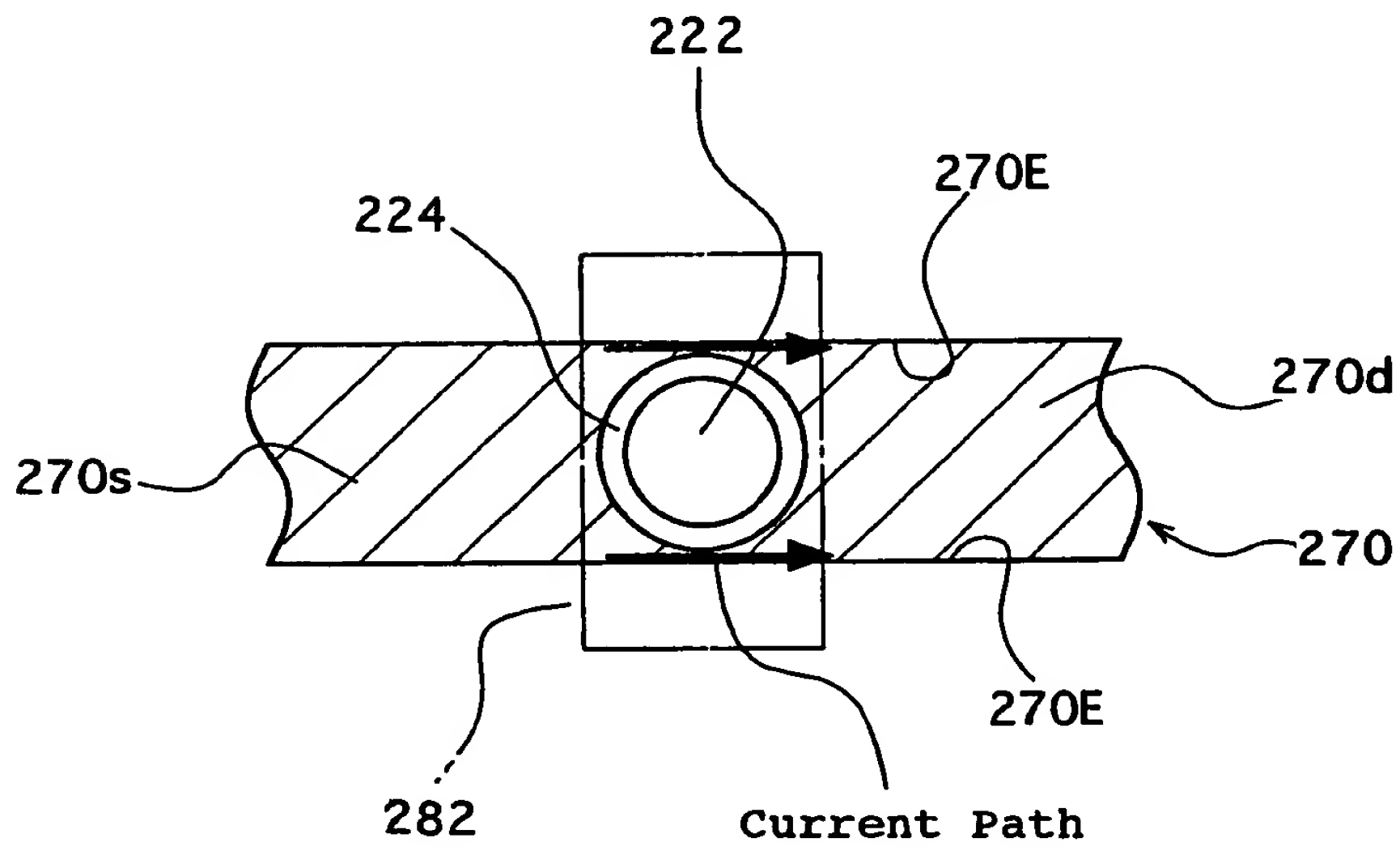


FIG. 25A

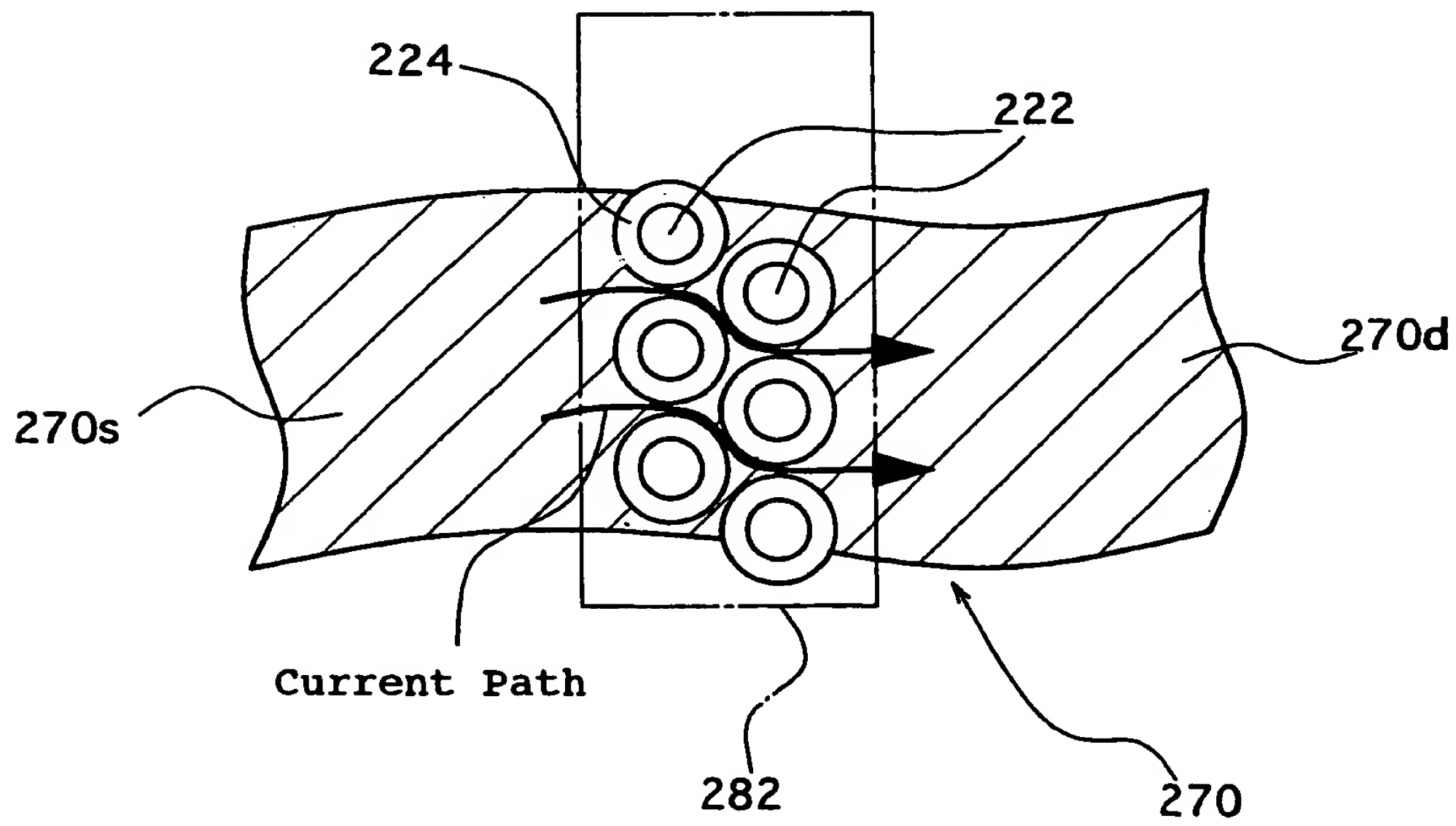


FIG. 25B

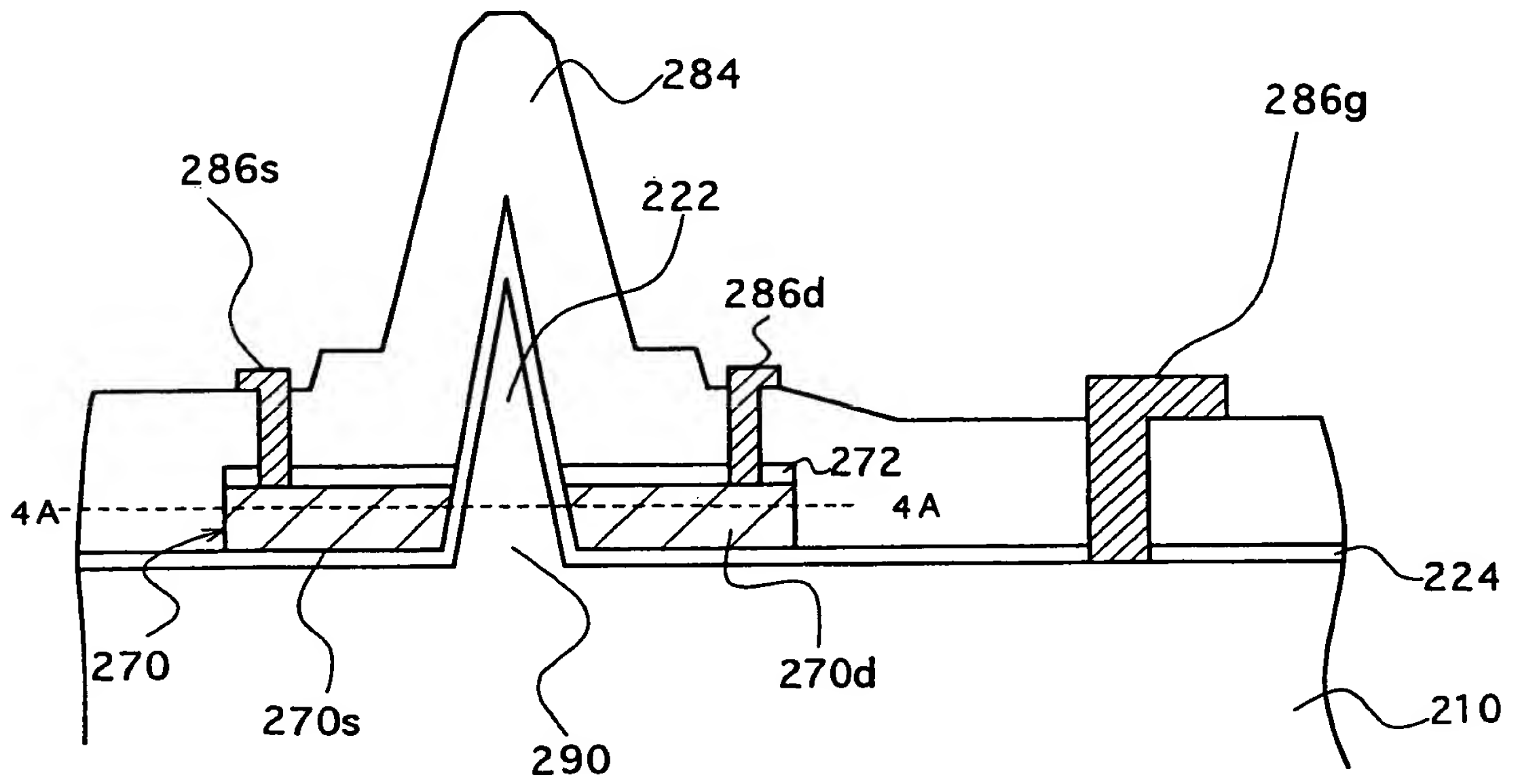


FIG. 26A

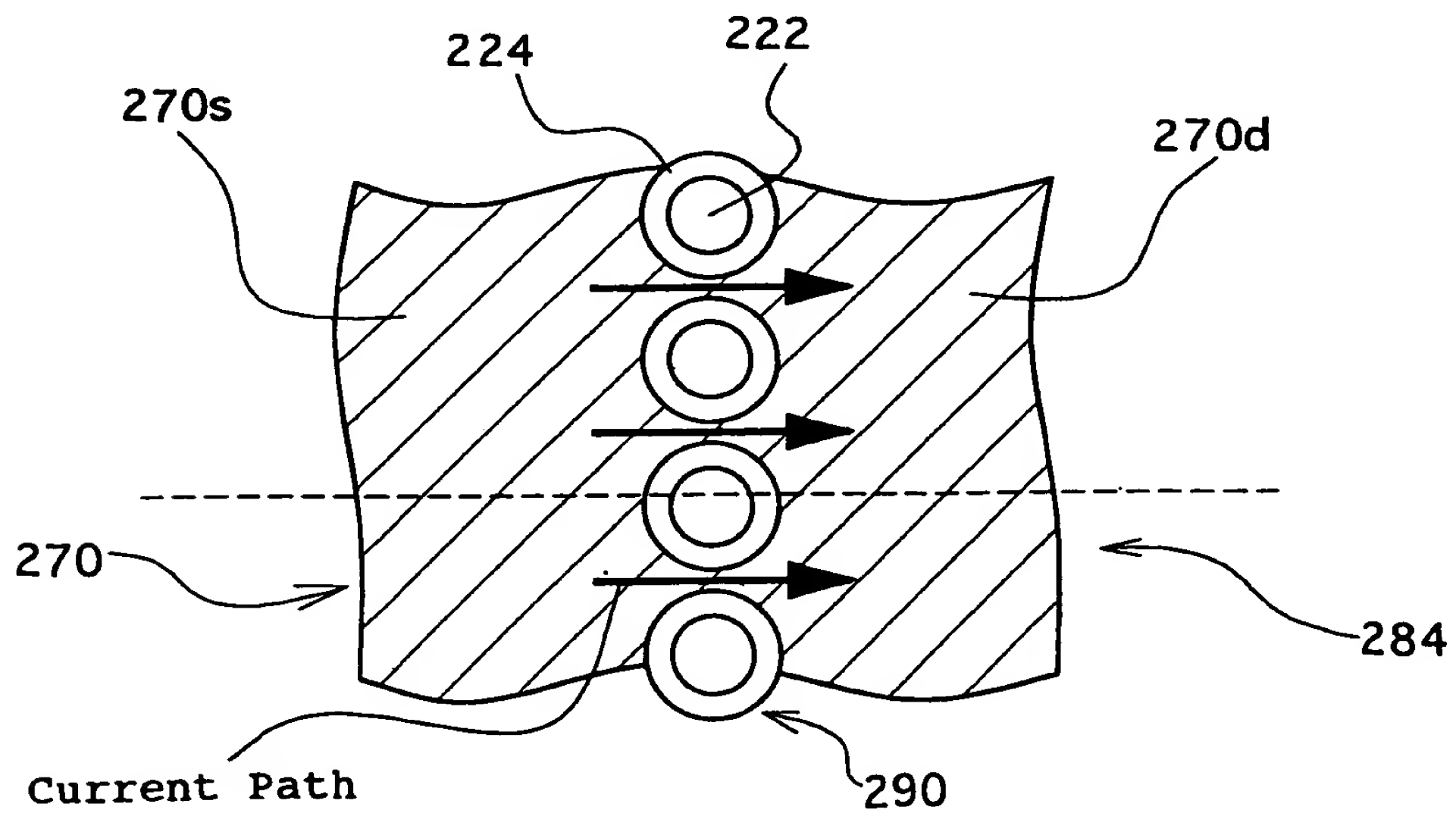
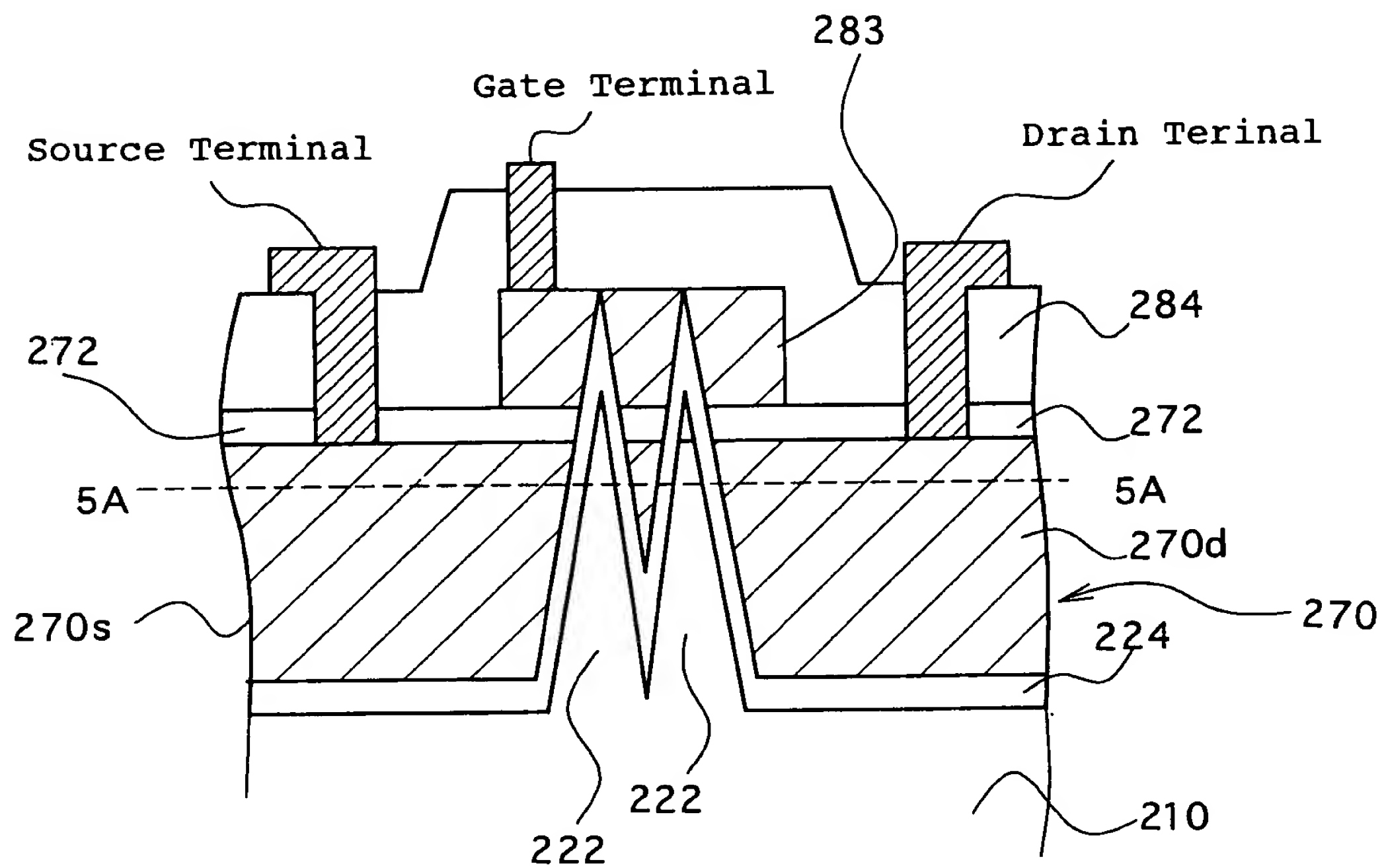
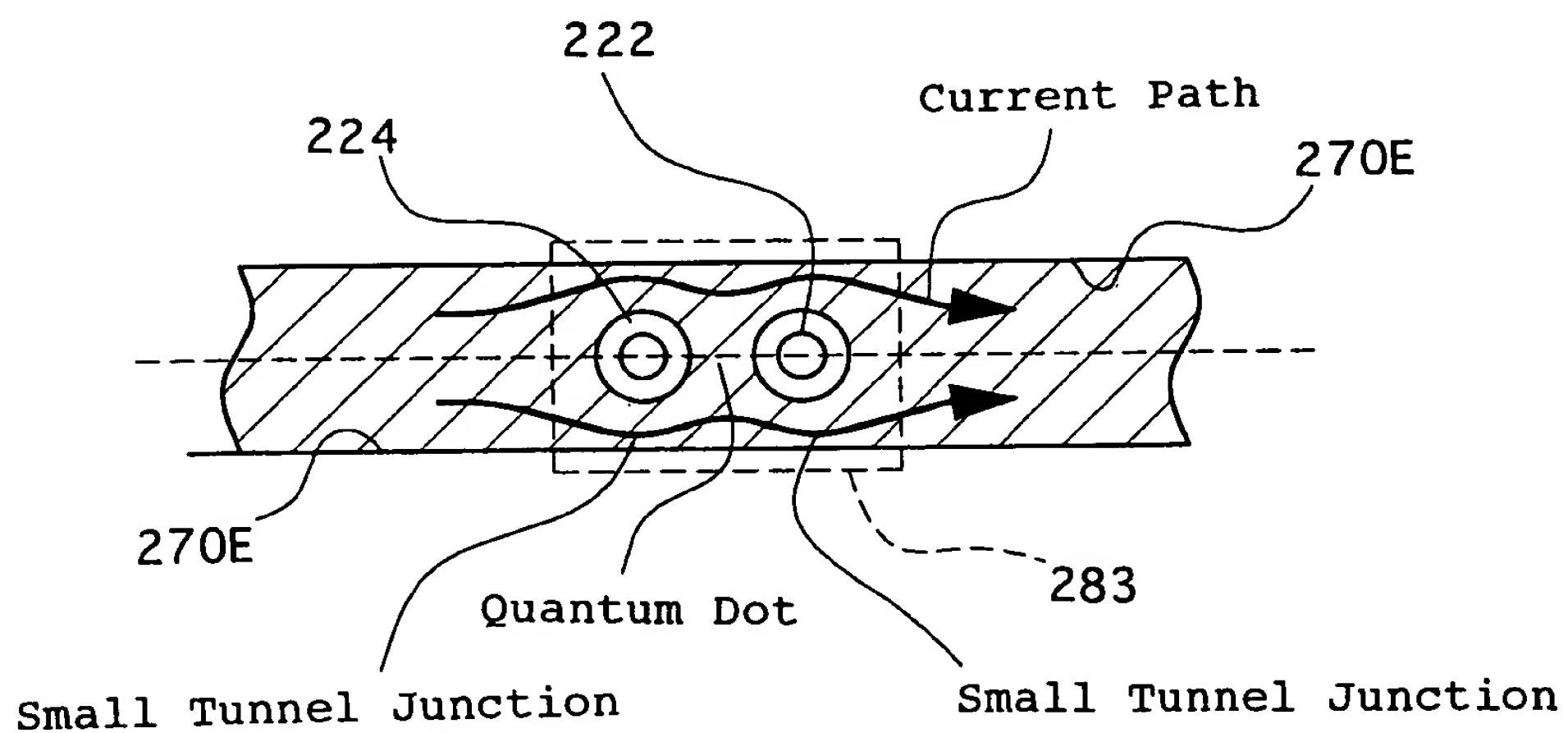


FIG. 26B

**FIG. 27A****FIG. 27B**

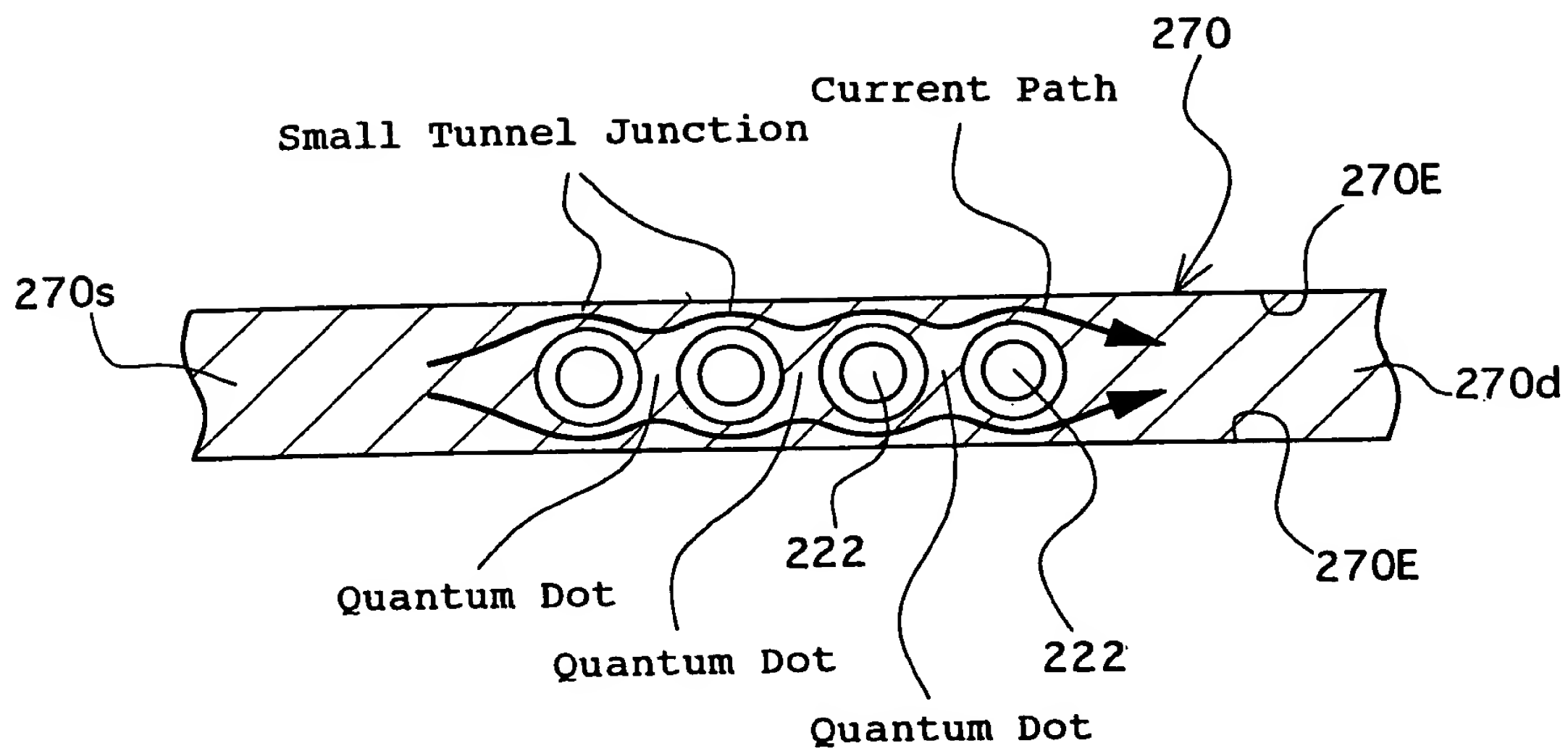


FIG. 28

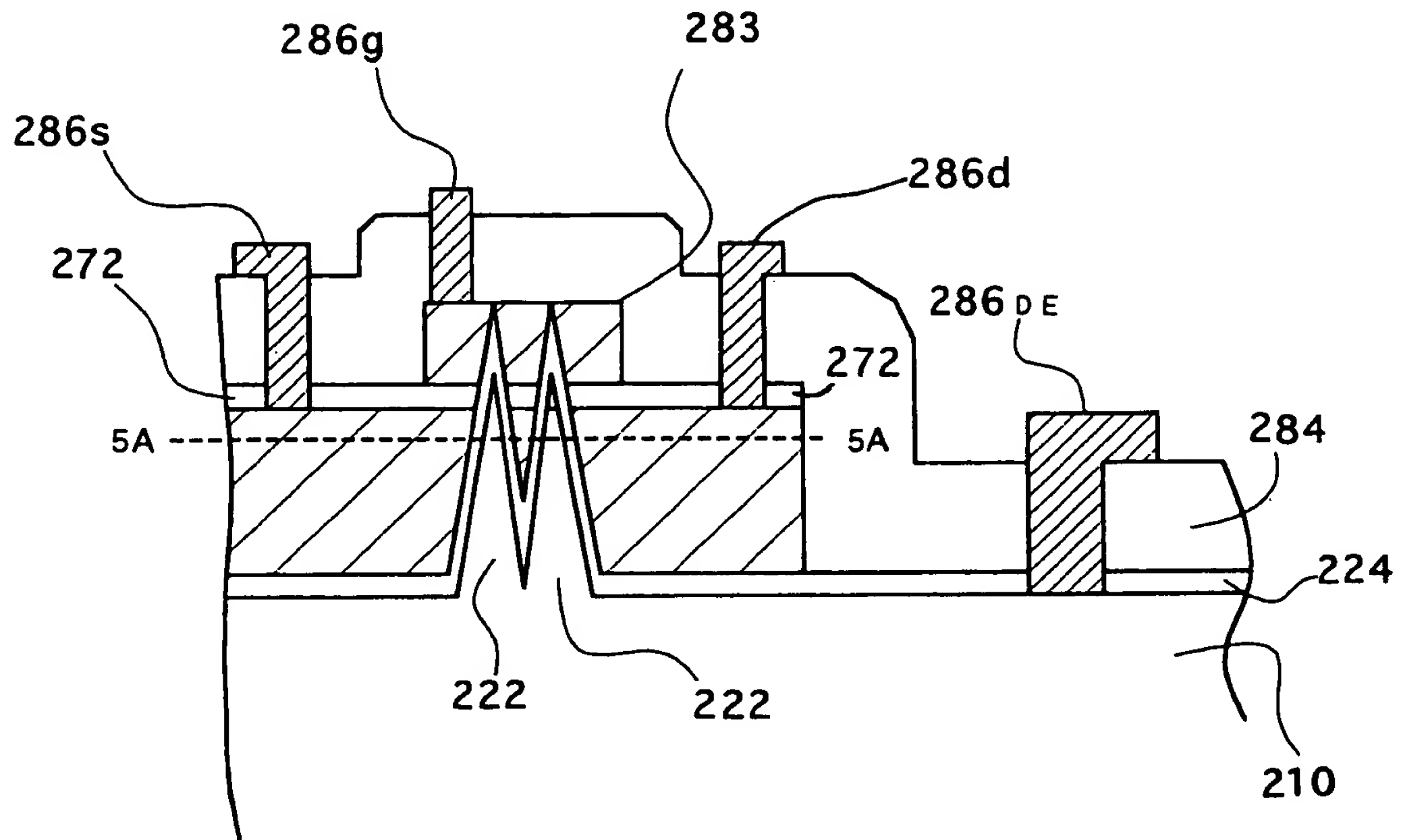


FIG. 29A

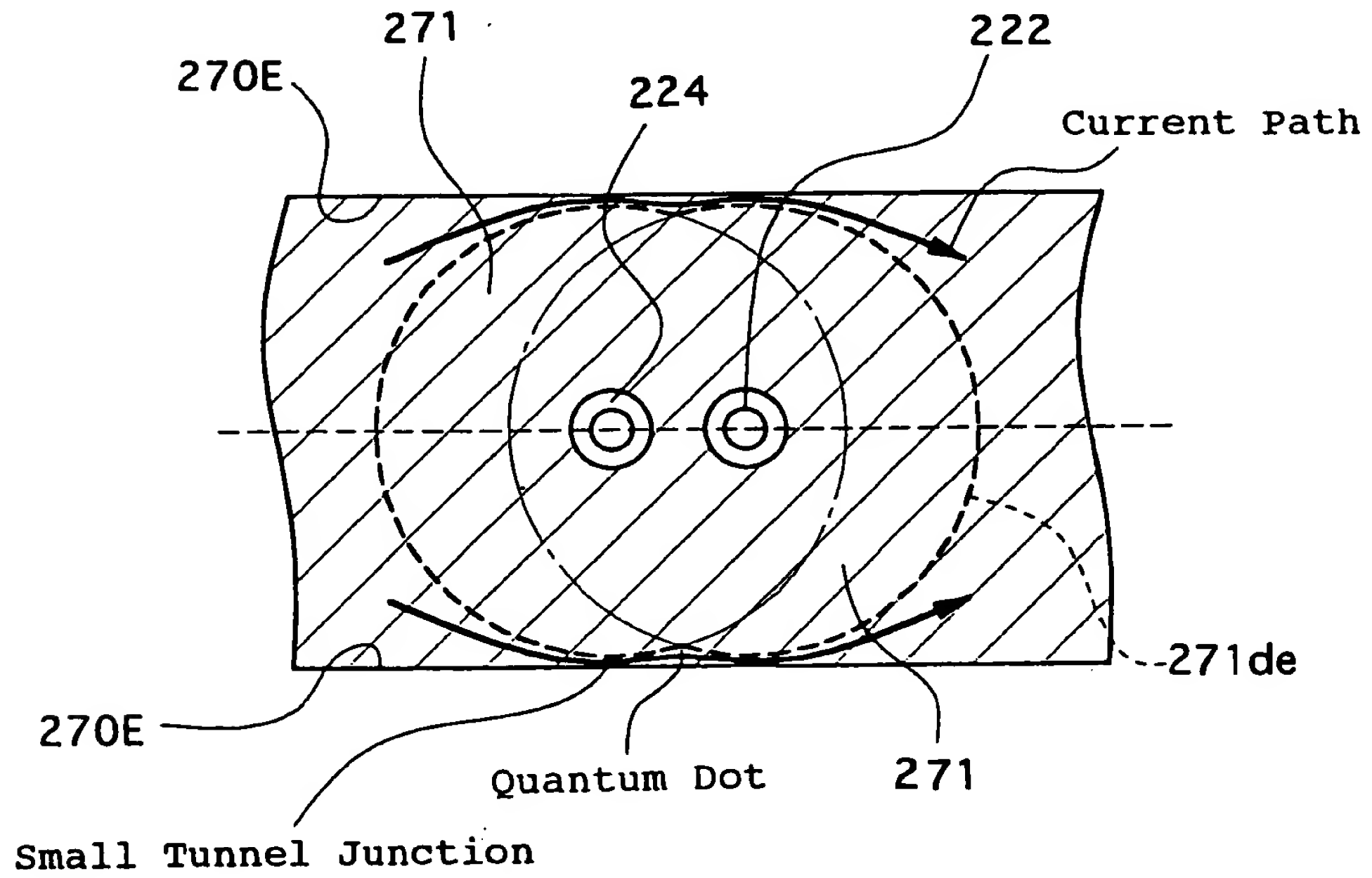
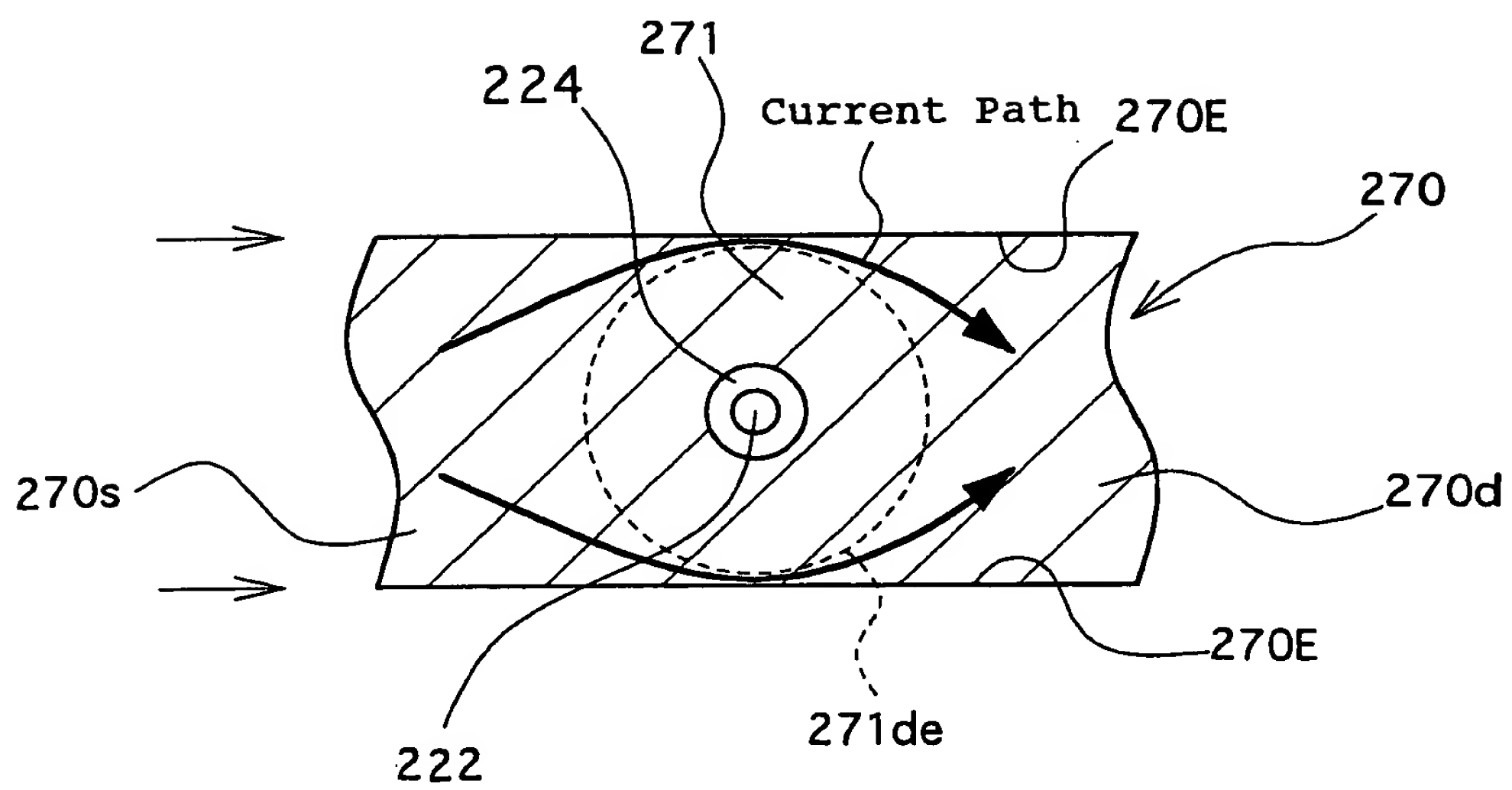


FIG. 29B

**FIG. 30**

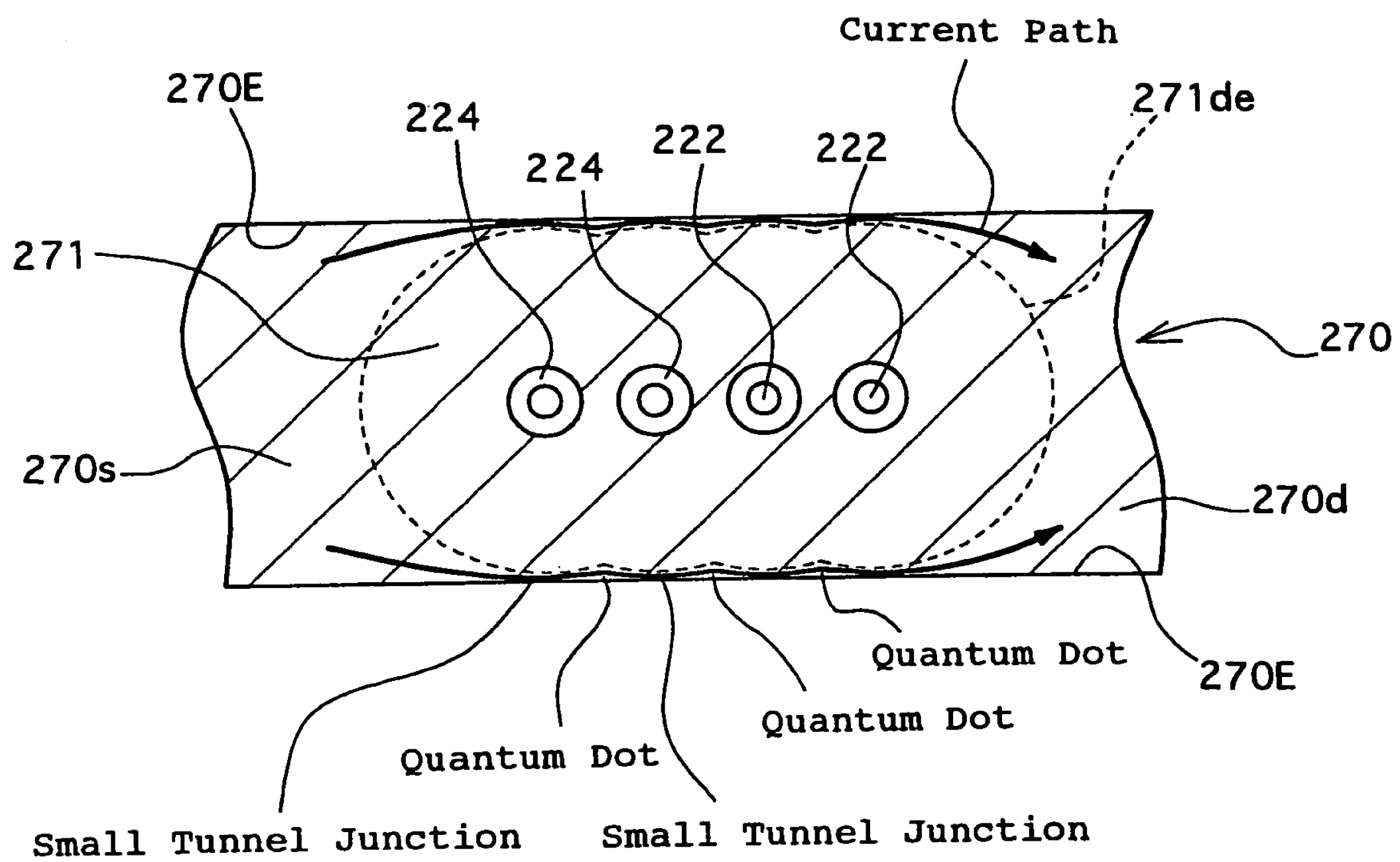


FIG. 31

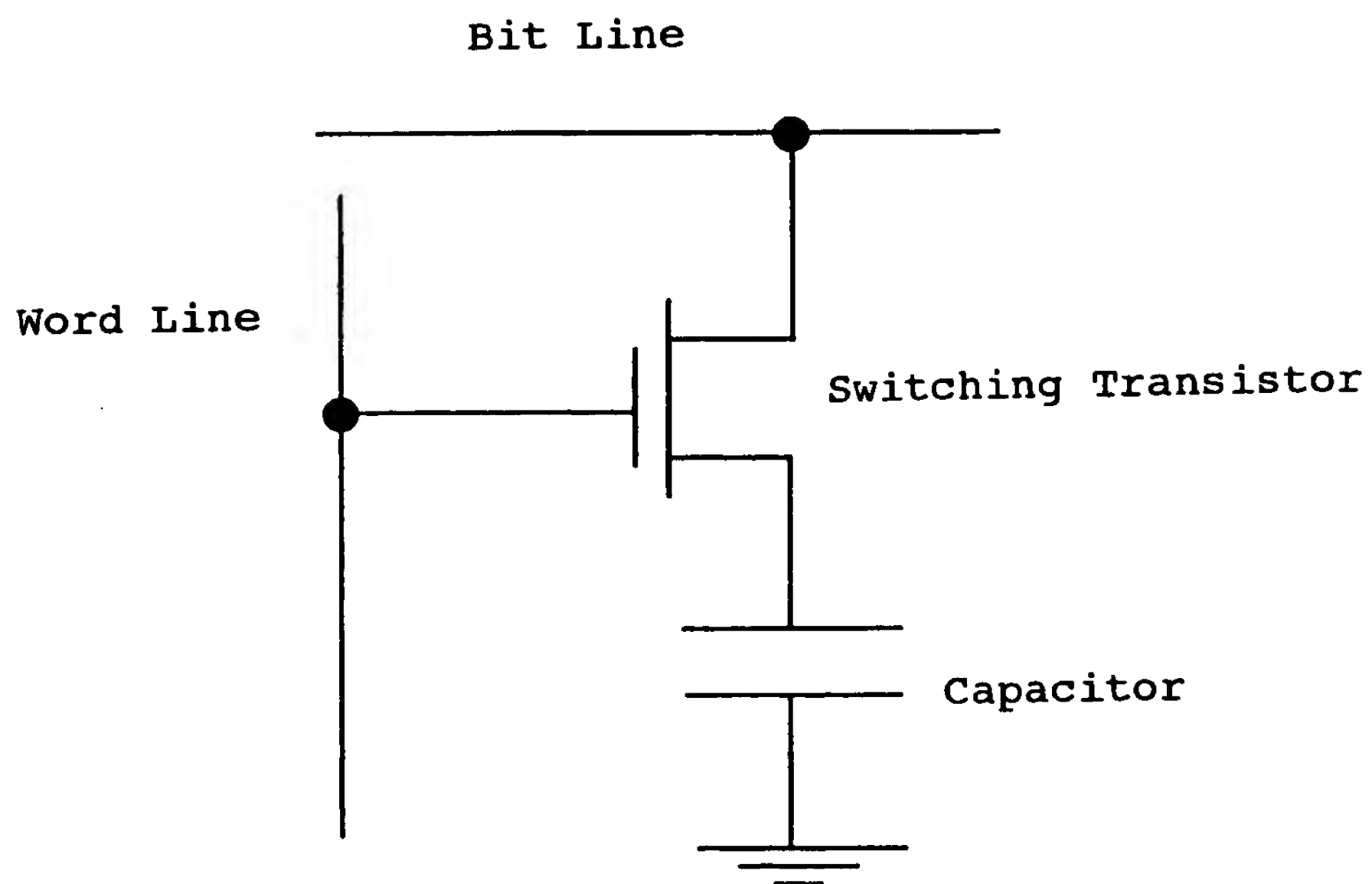


FIG. 32 PRIOR ART

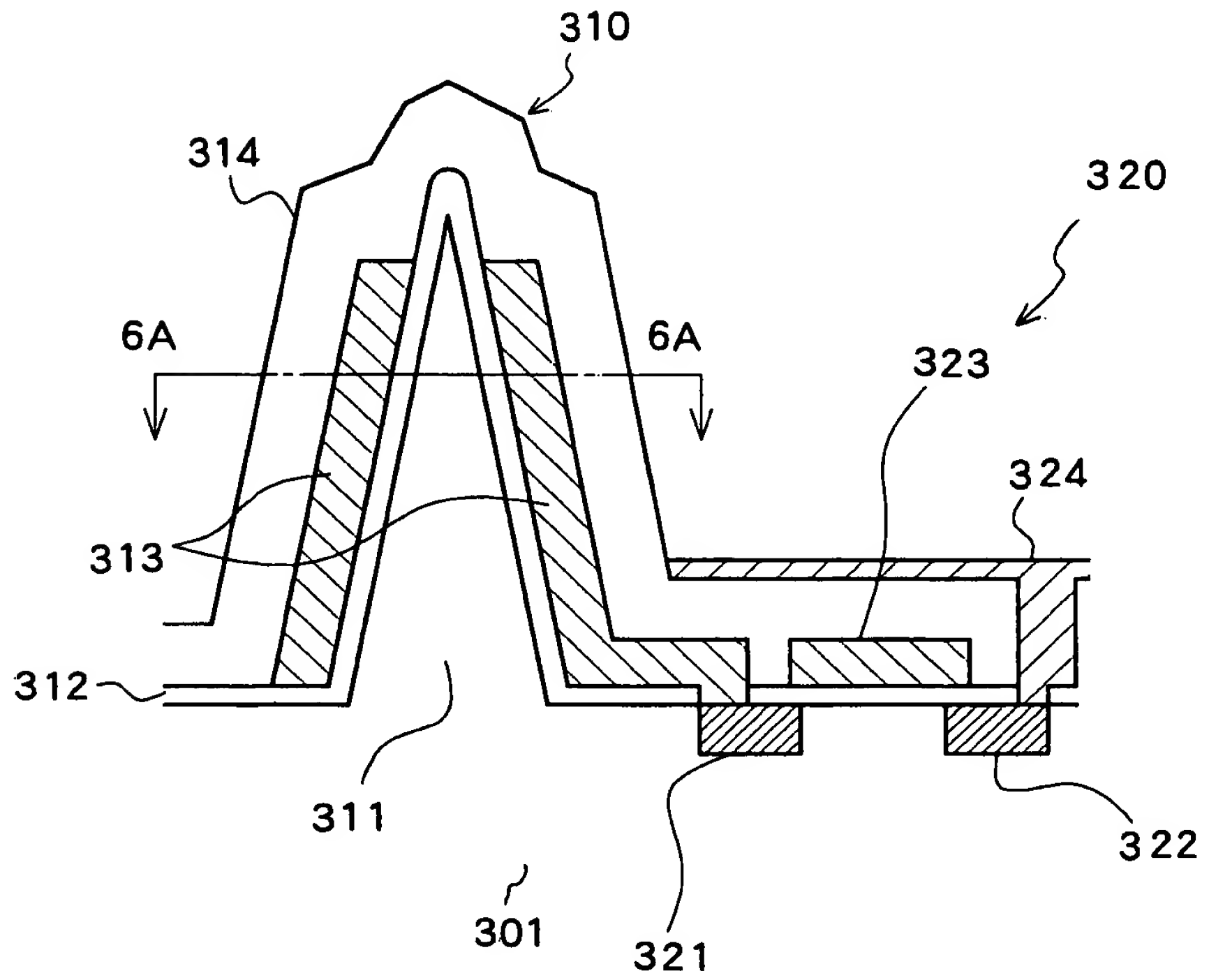


FIG. 33A

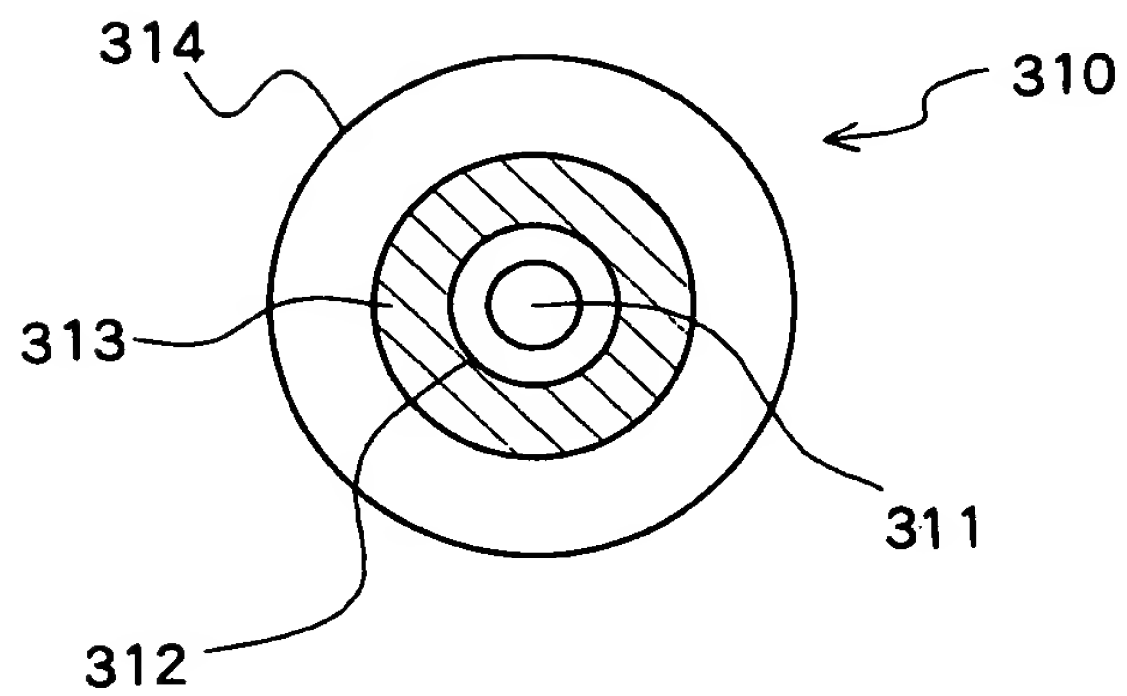


FIG. 33B

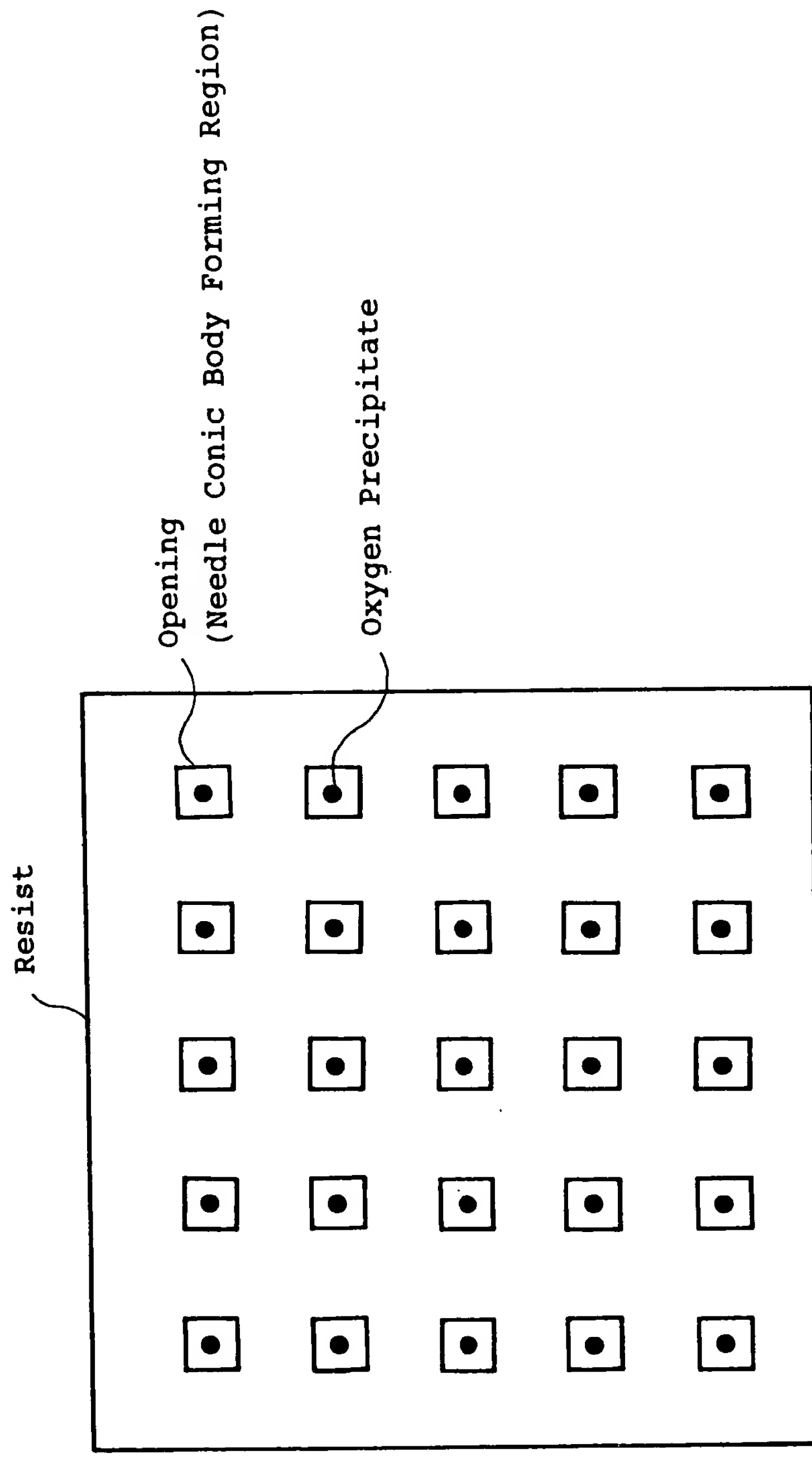
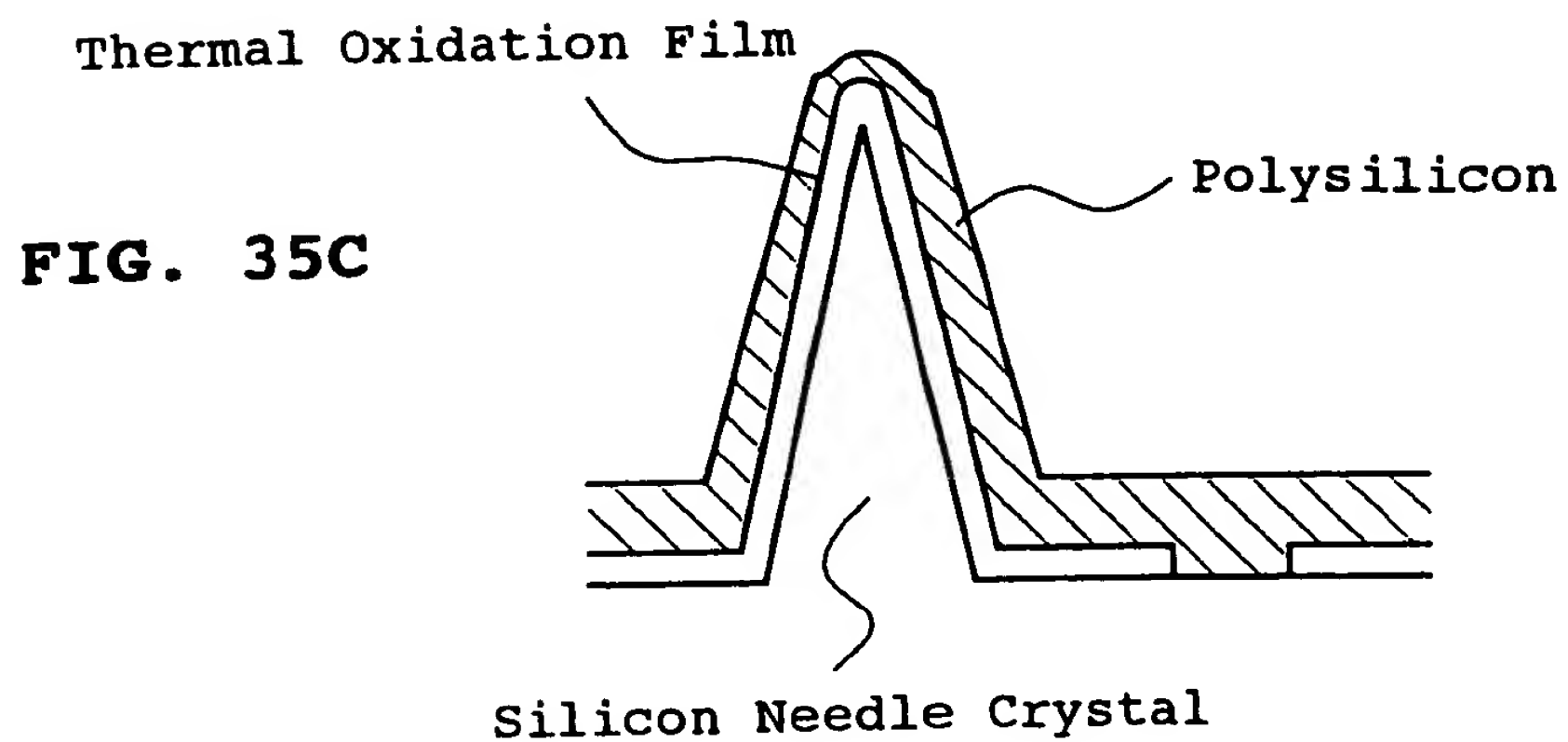
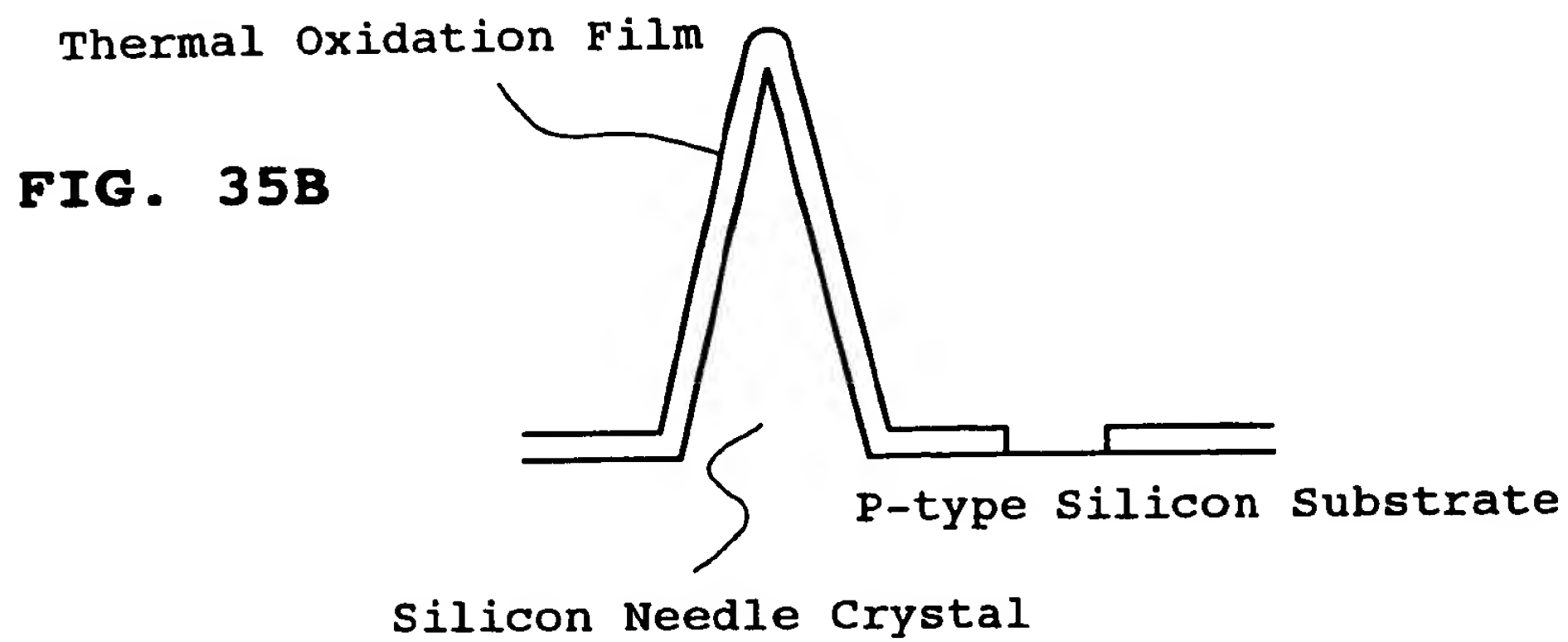
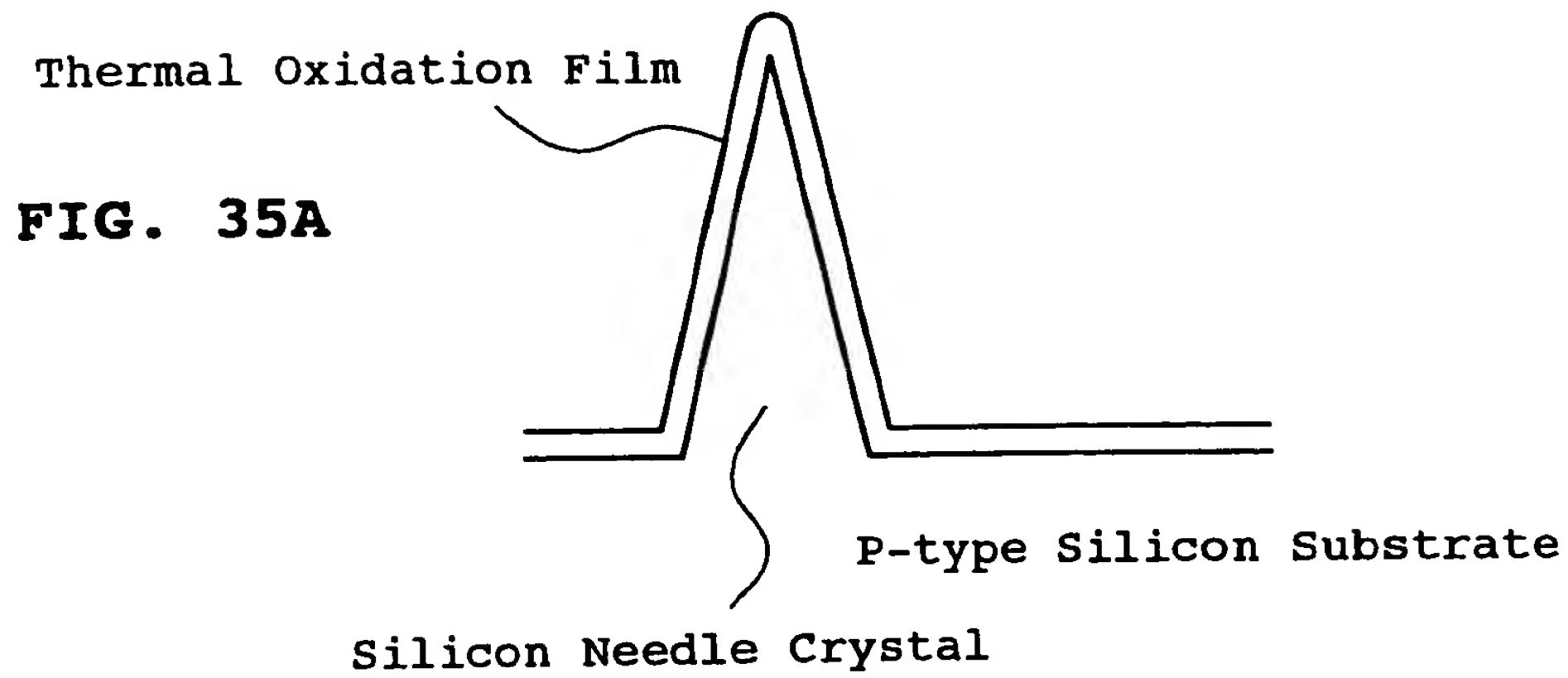
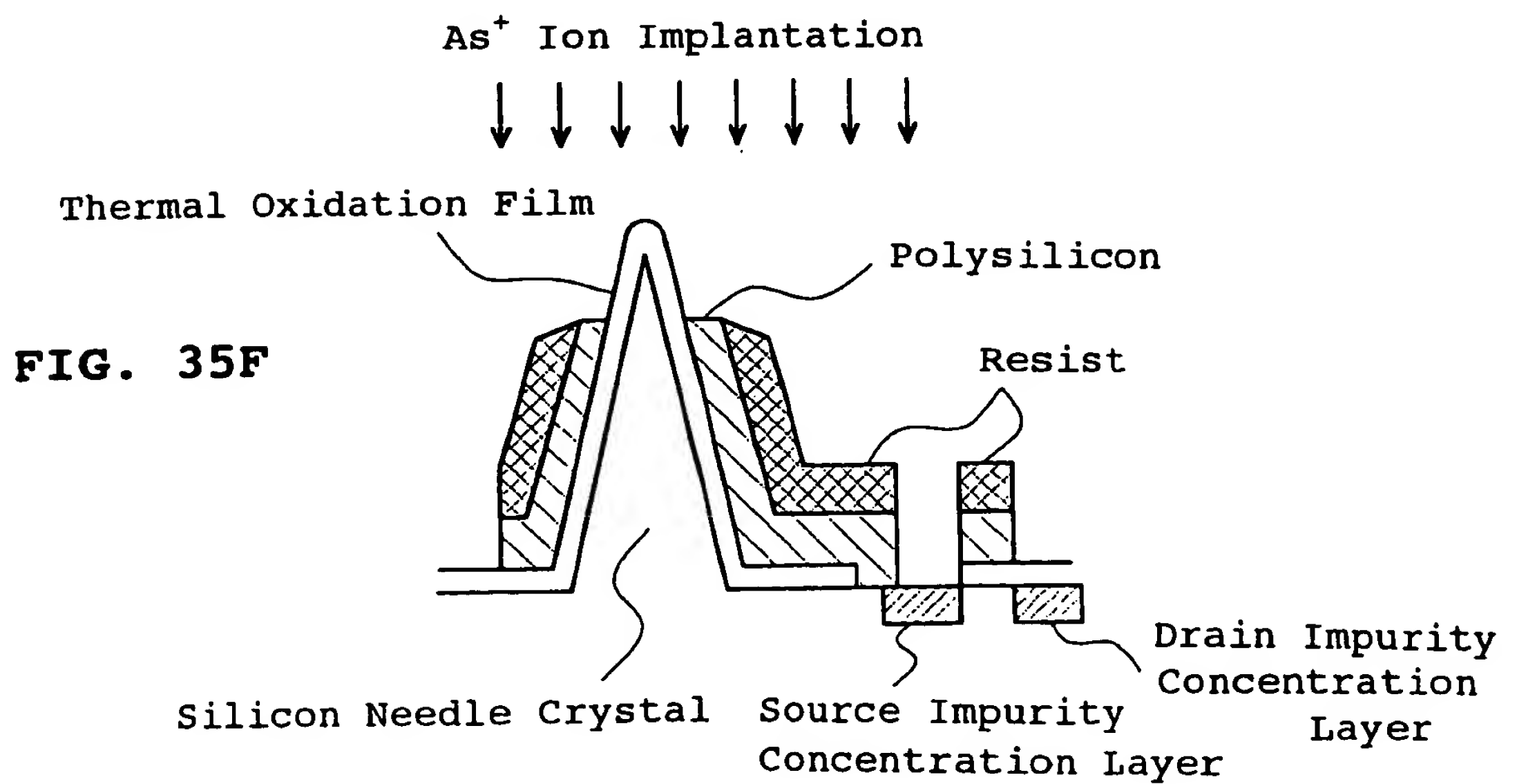
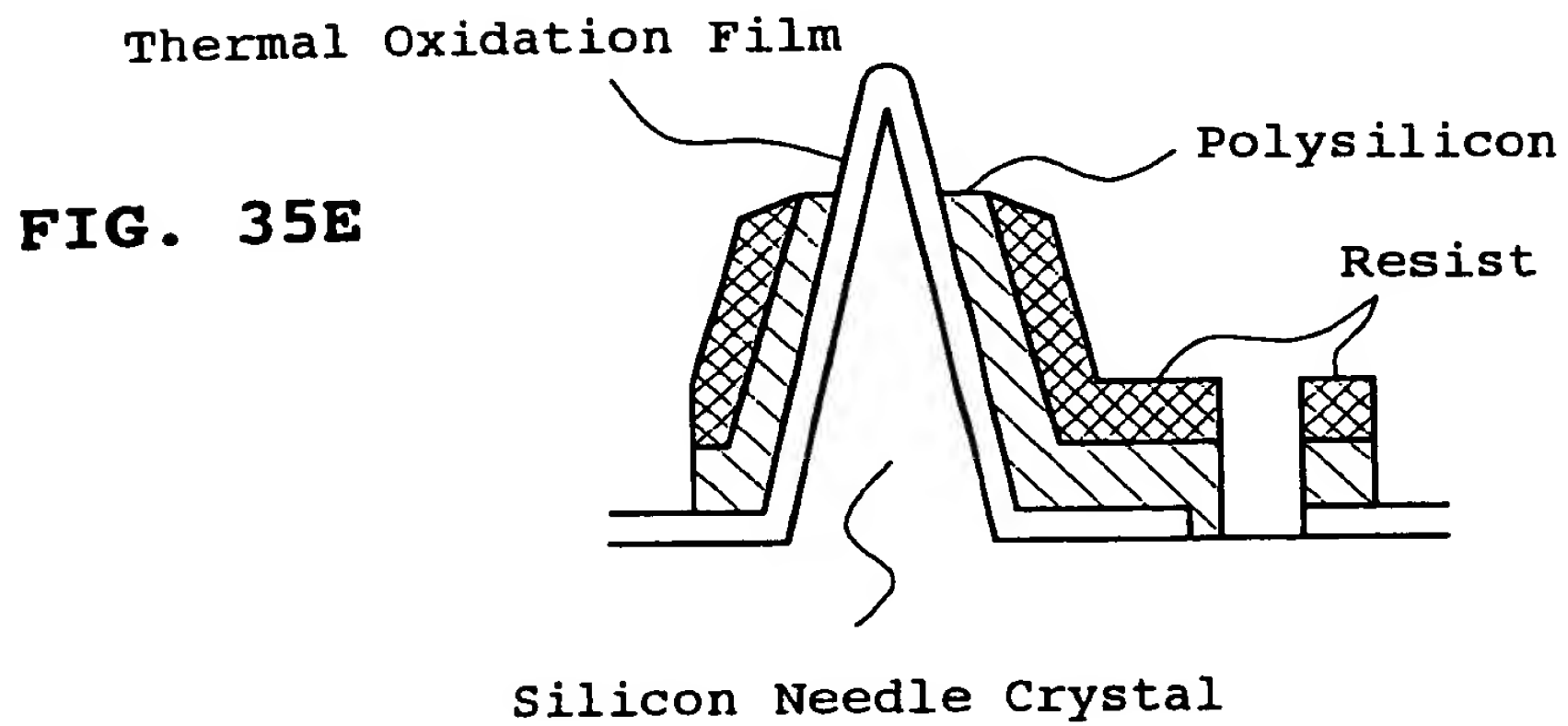
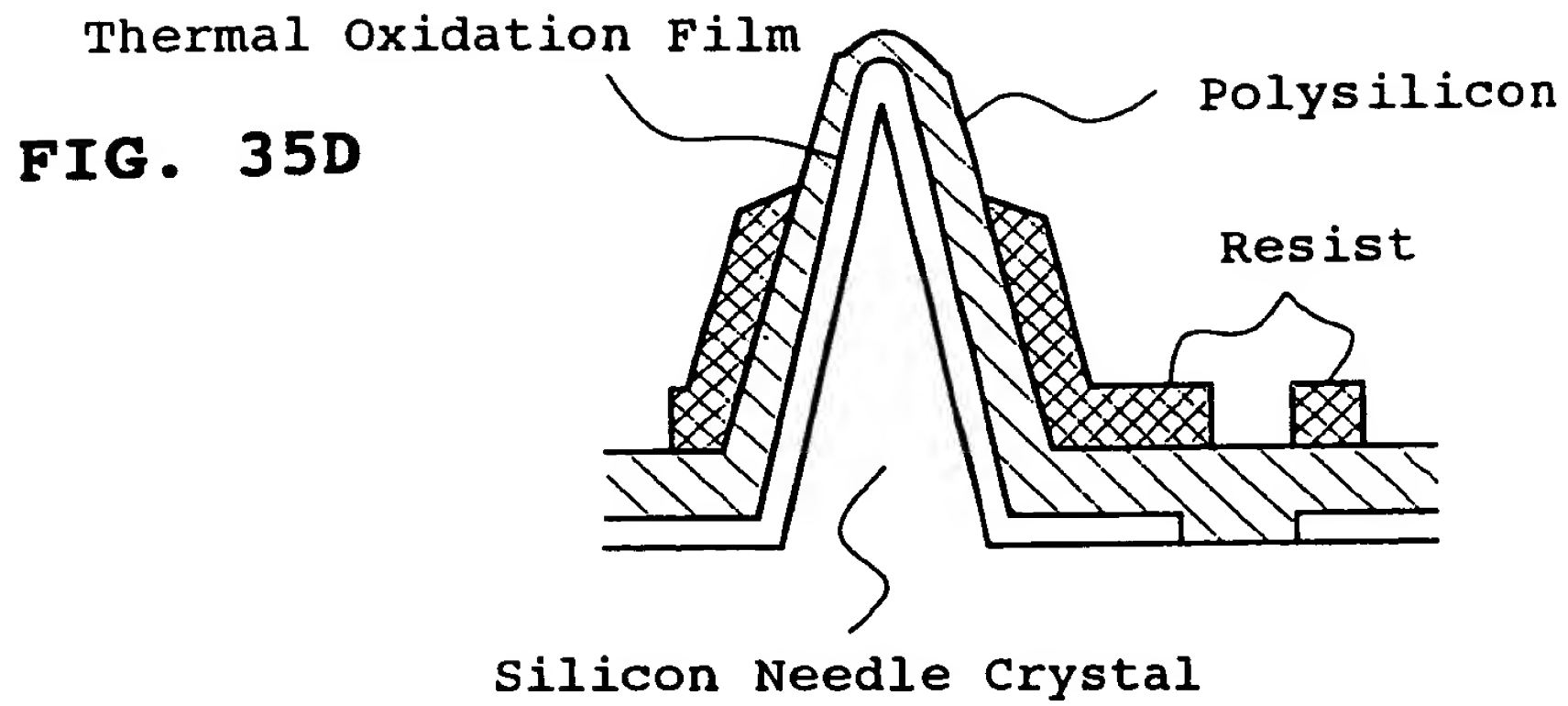
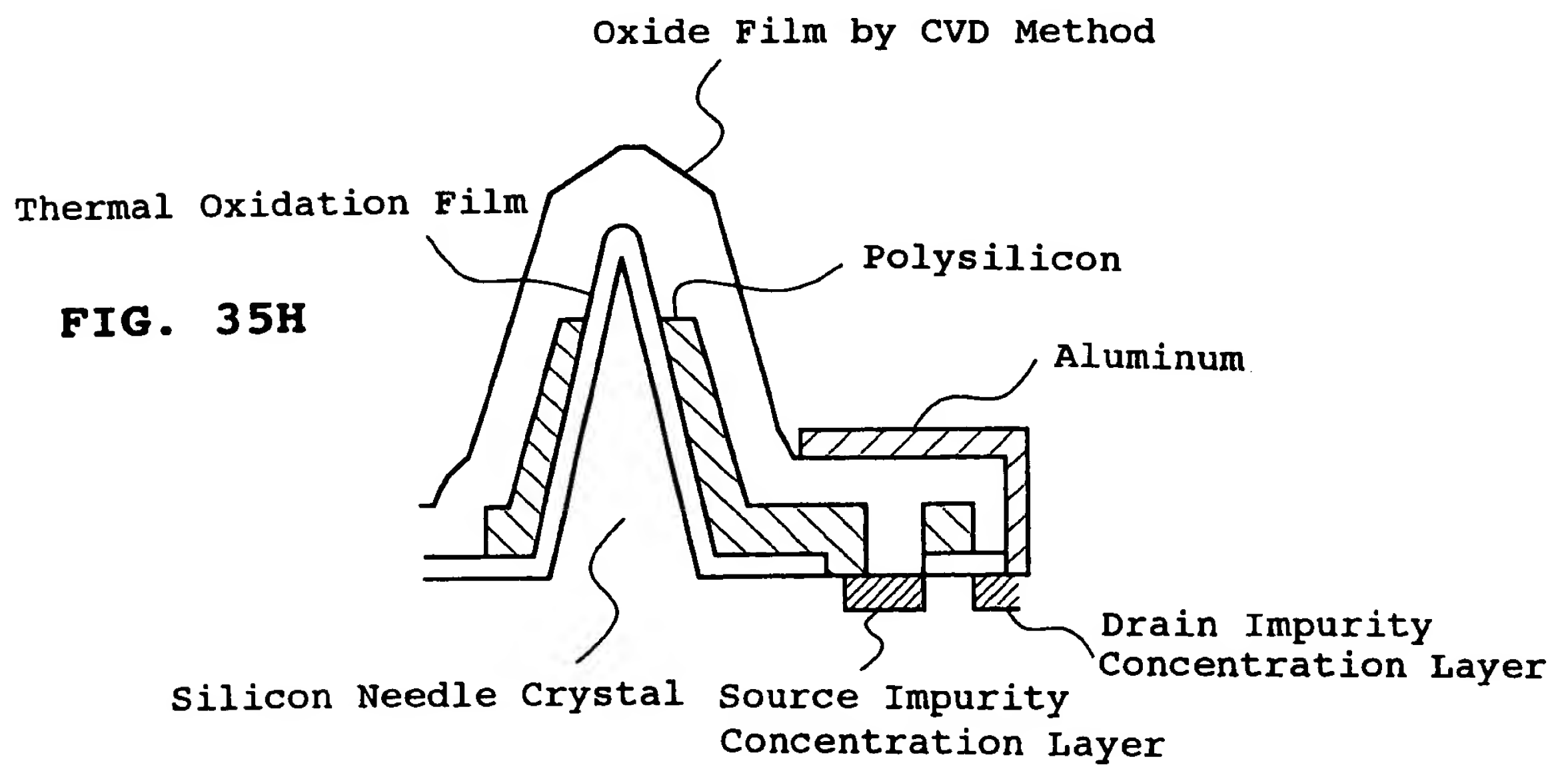
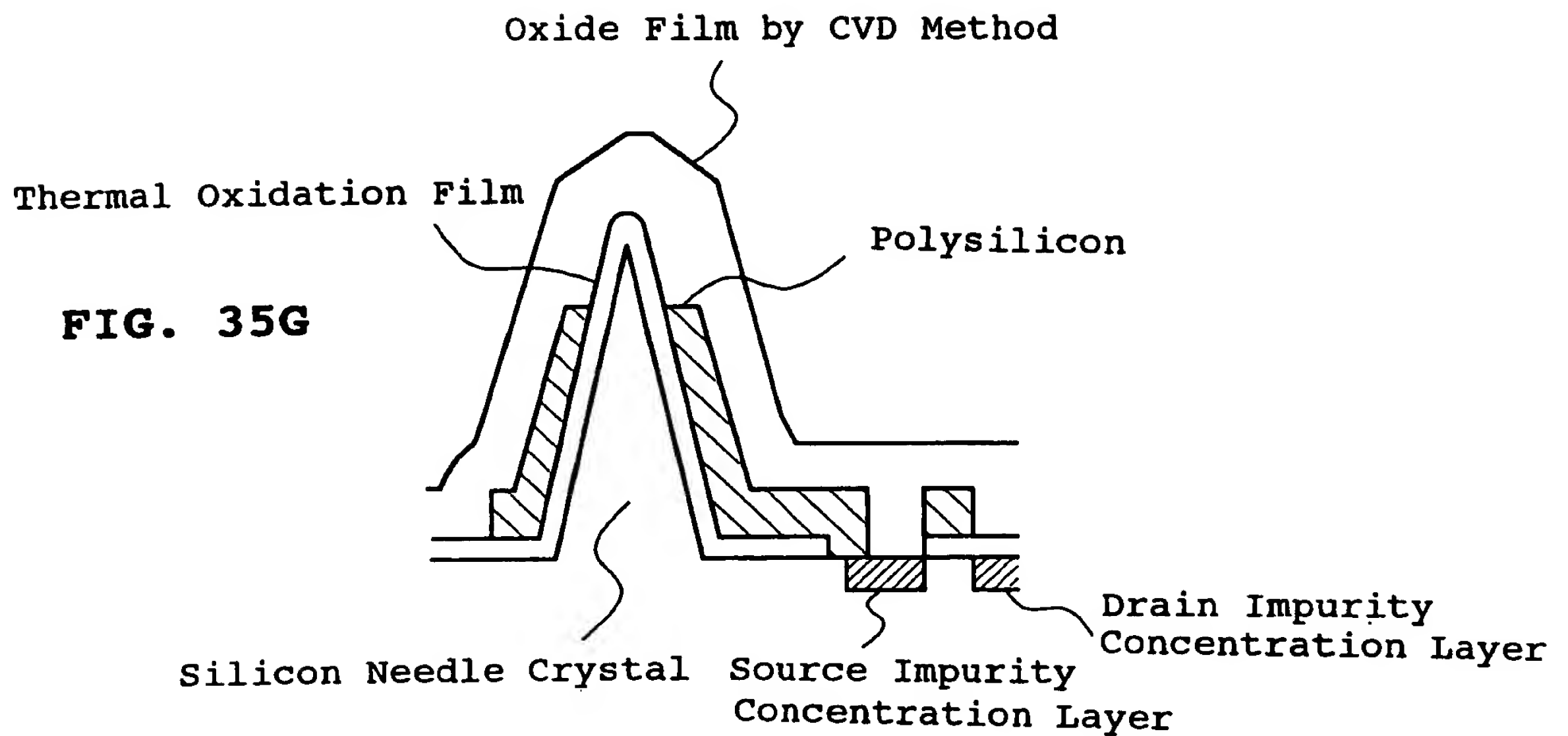
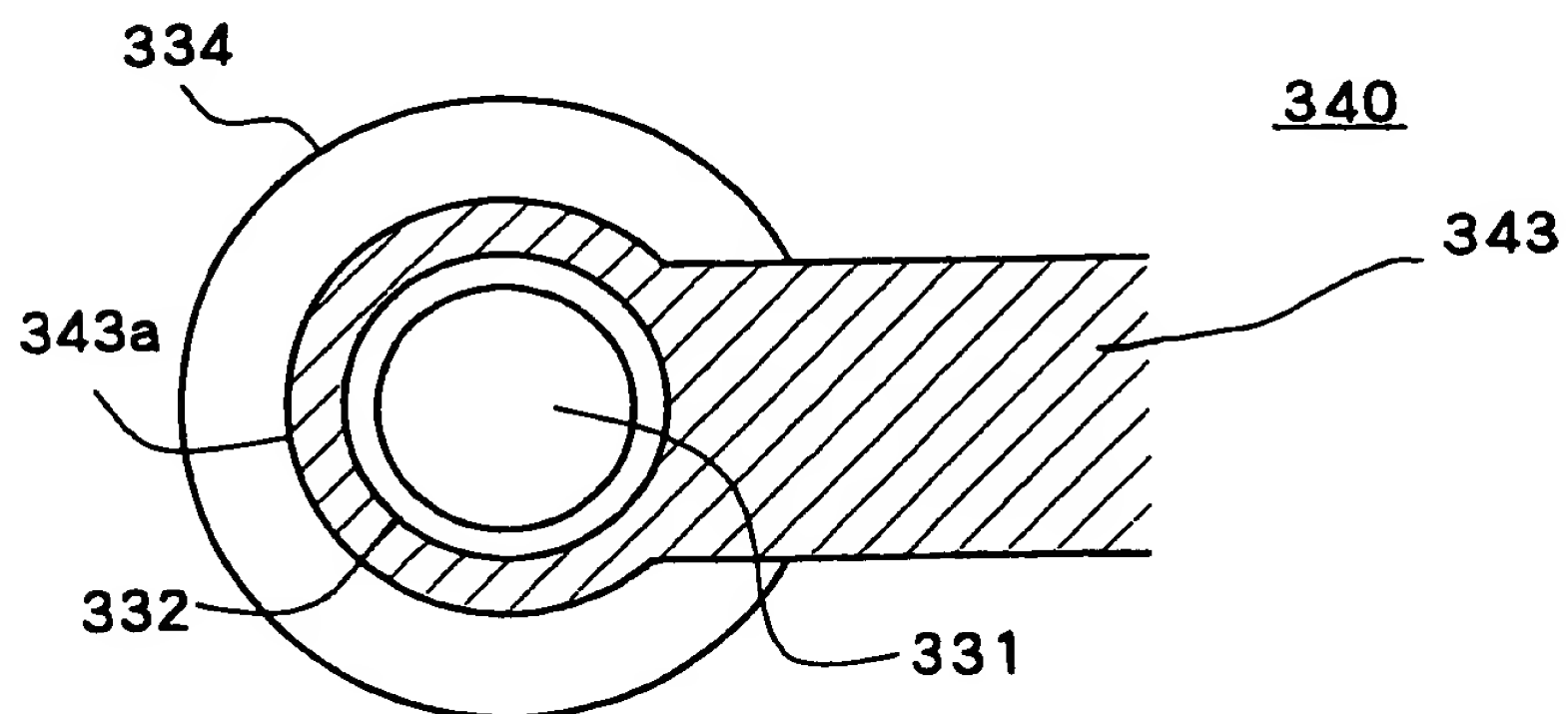
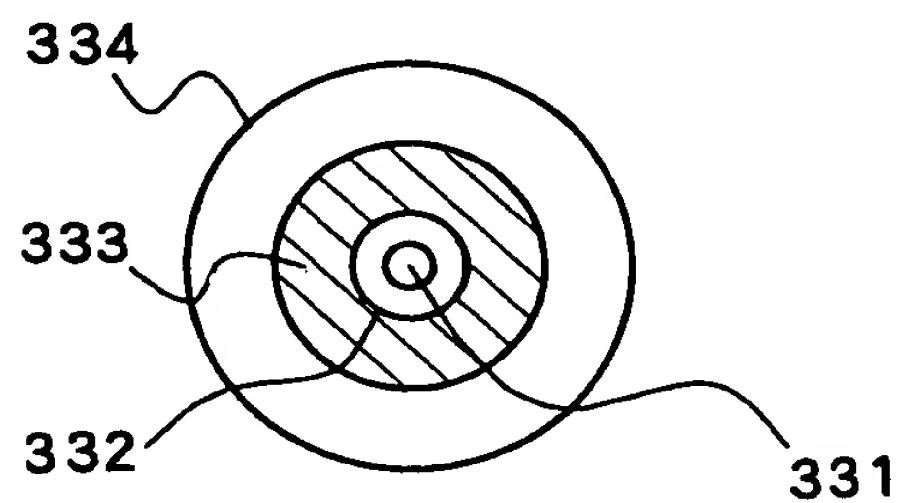
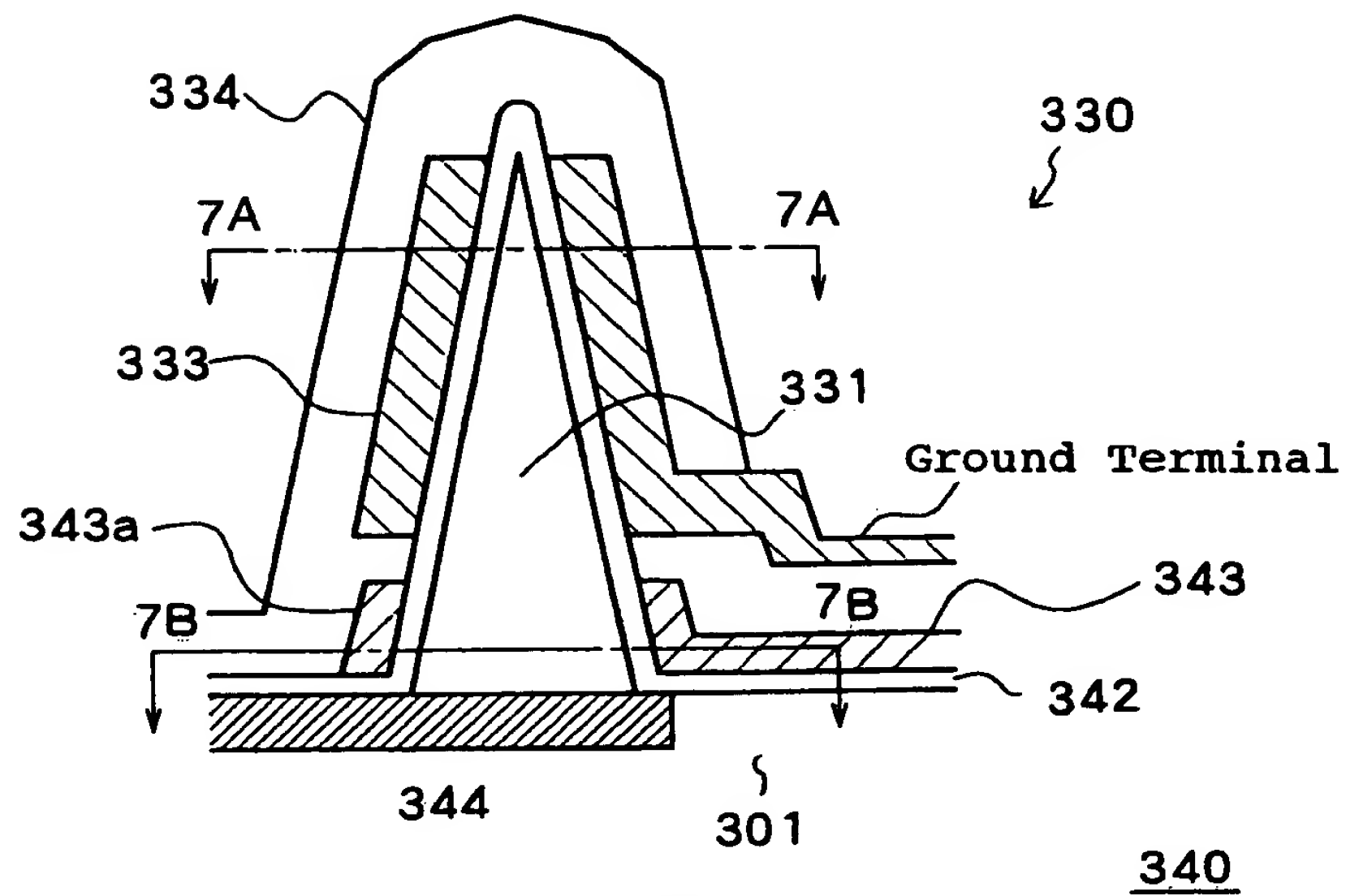


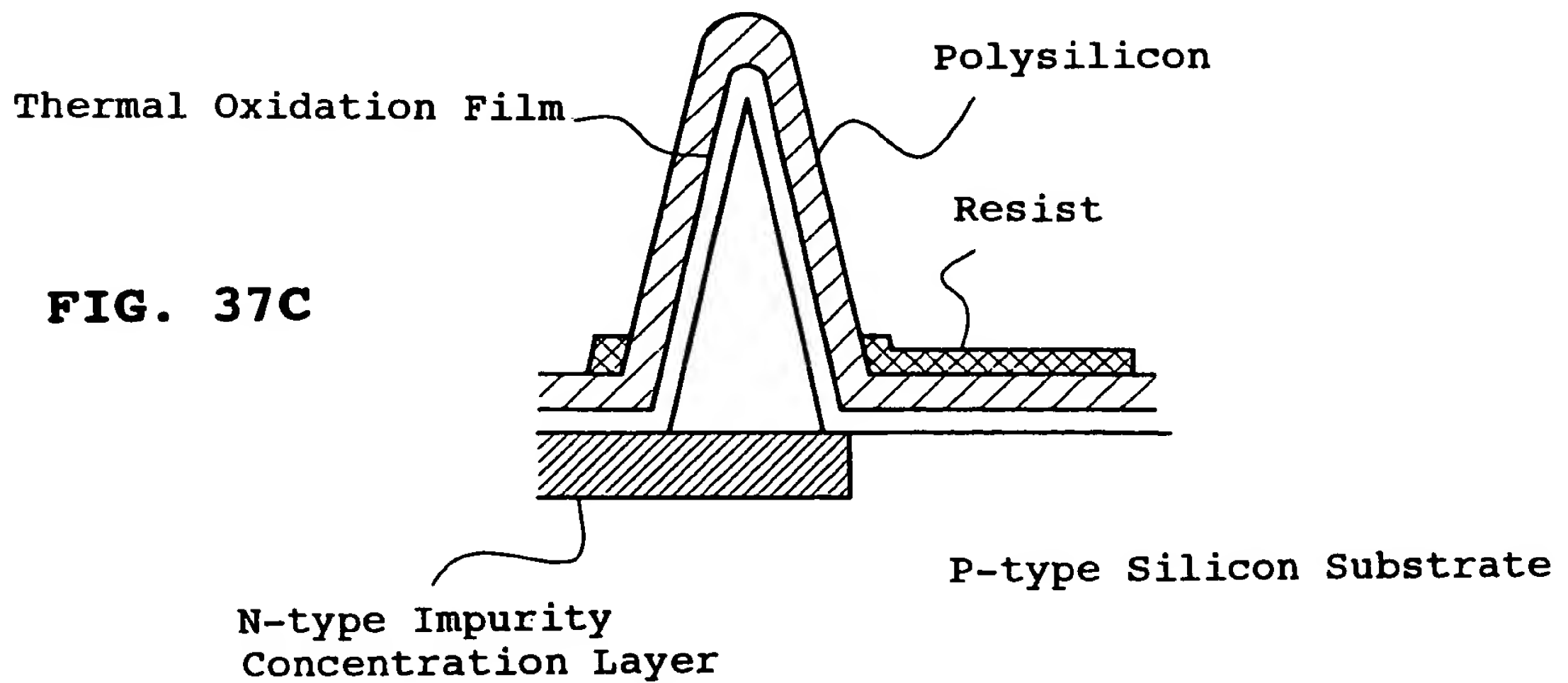
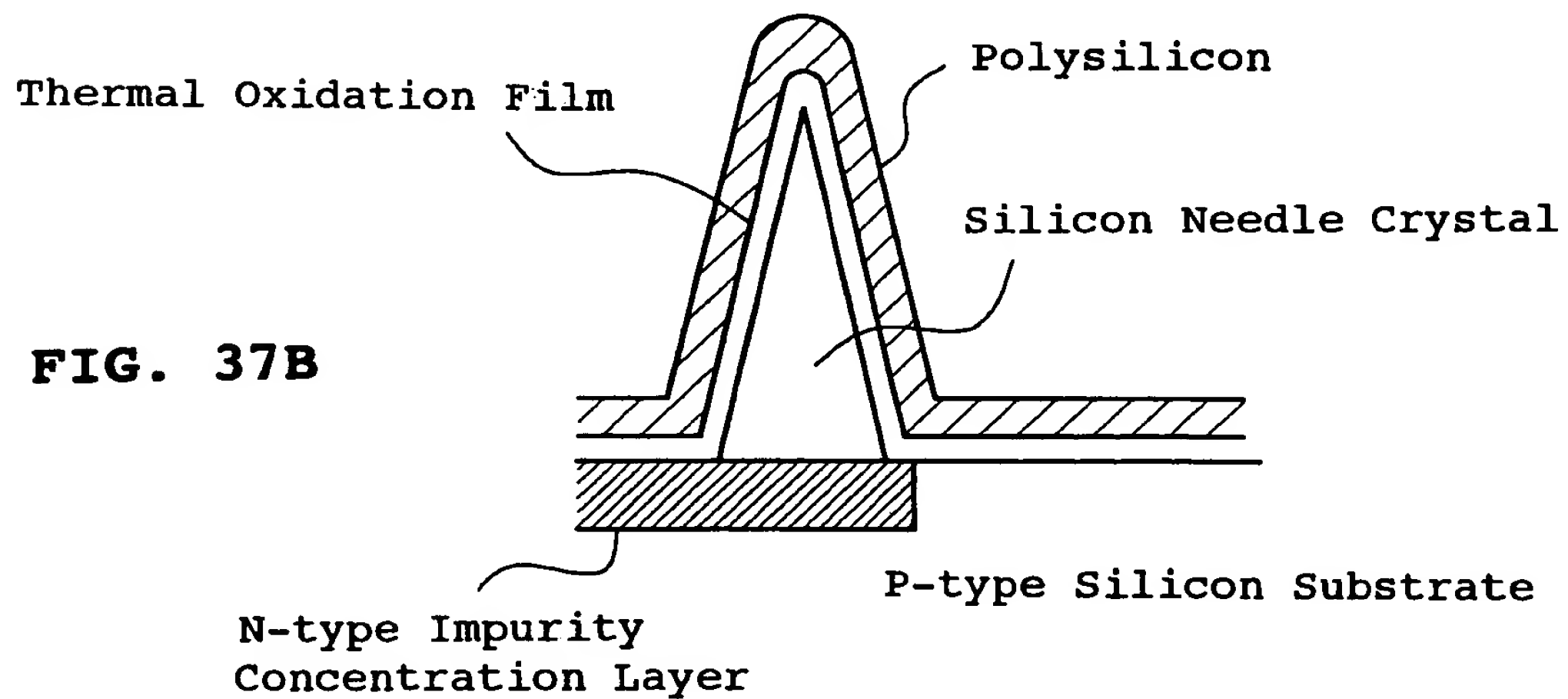
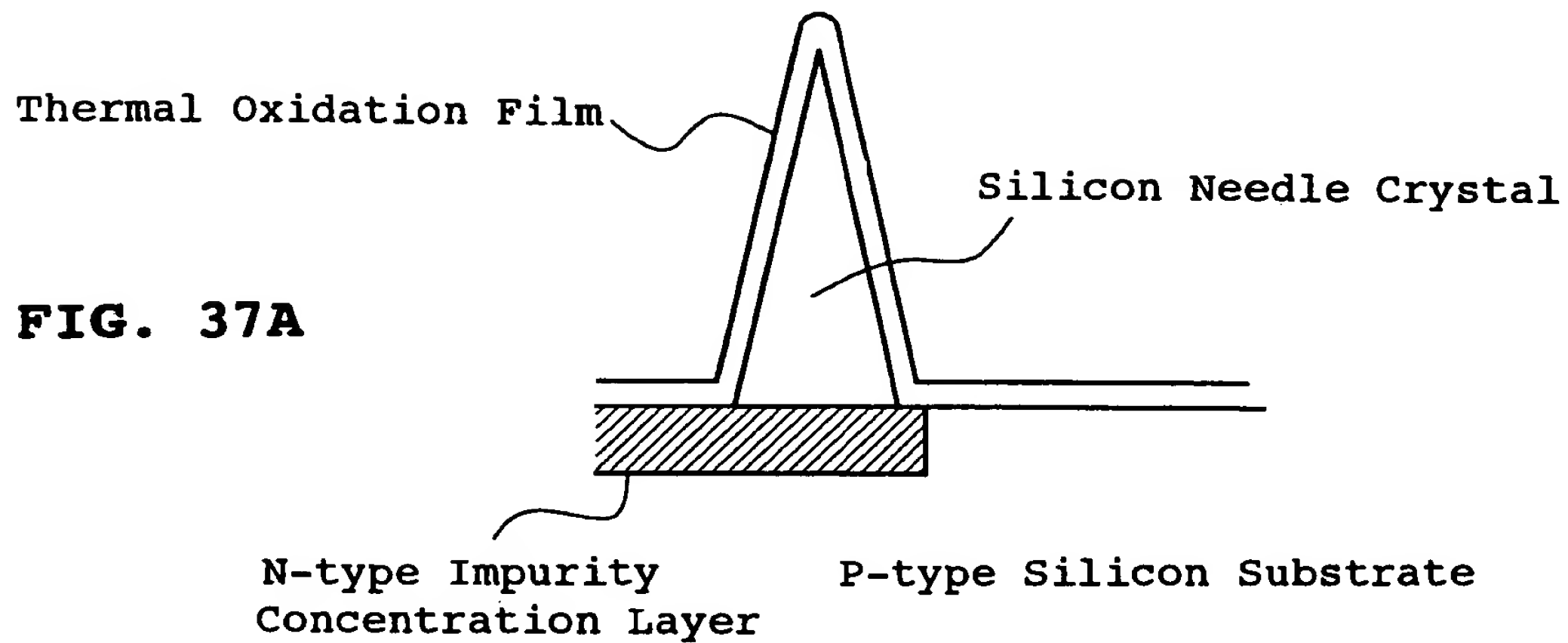
FIG. 34

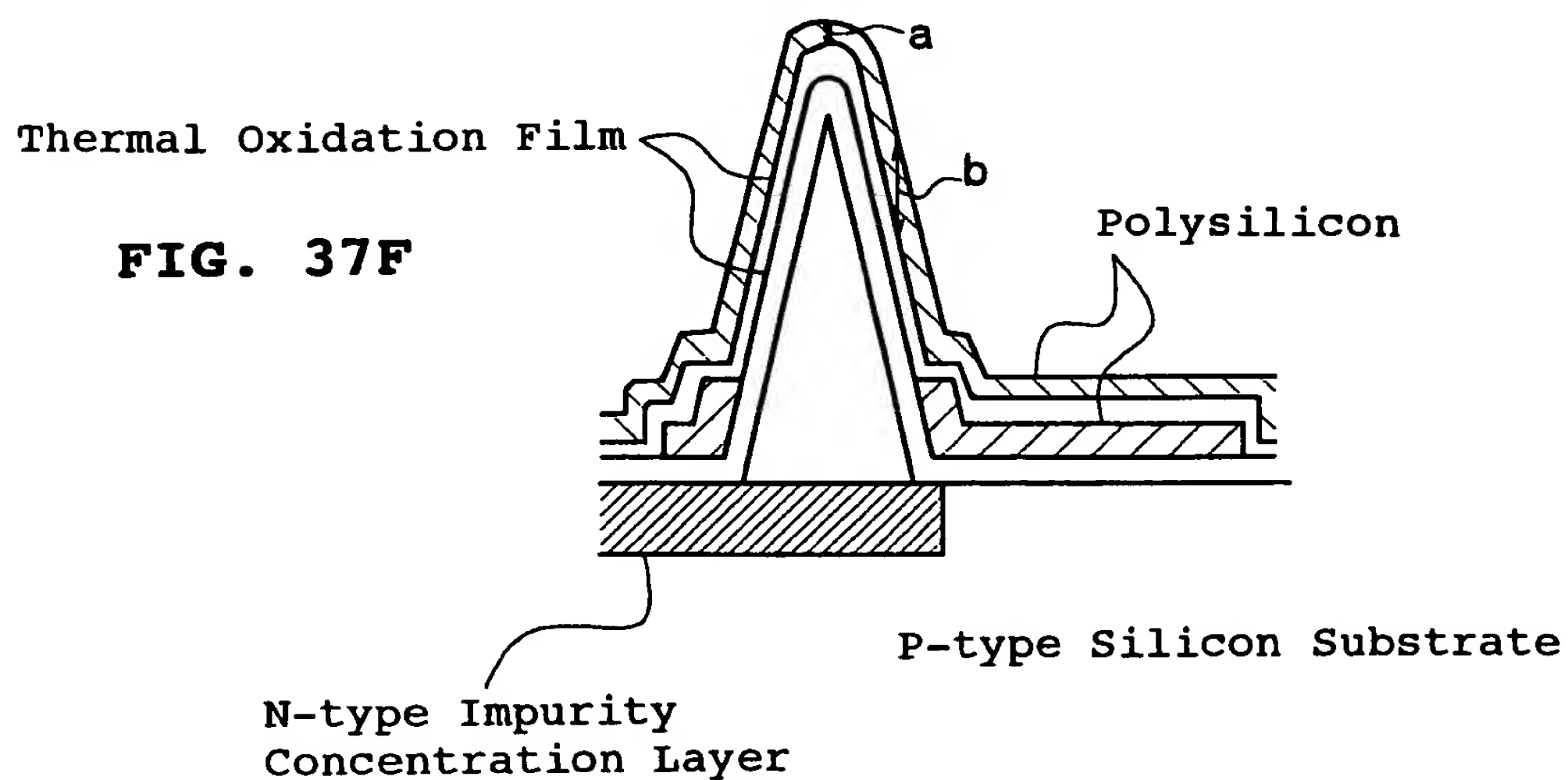
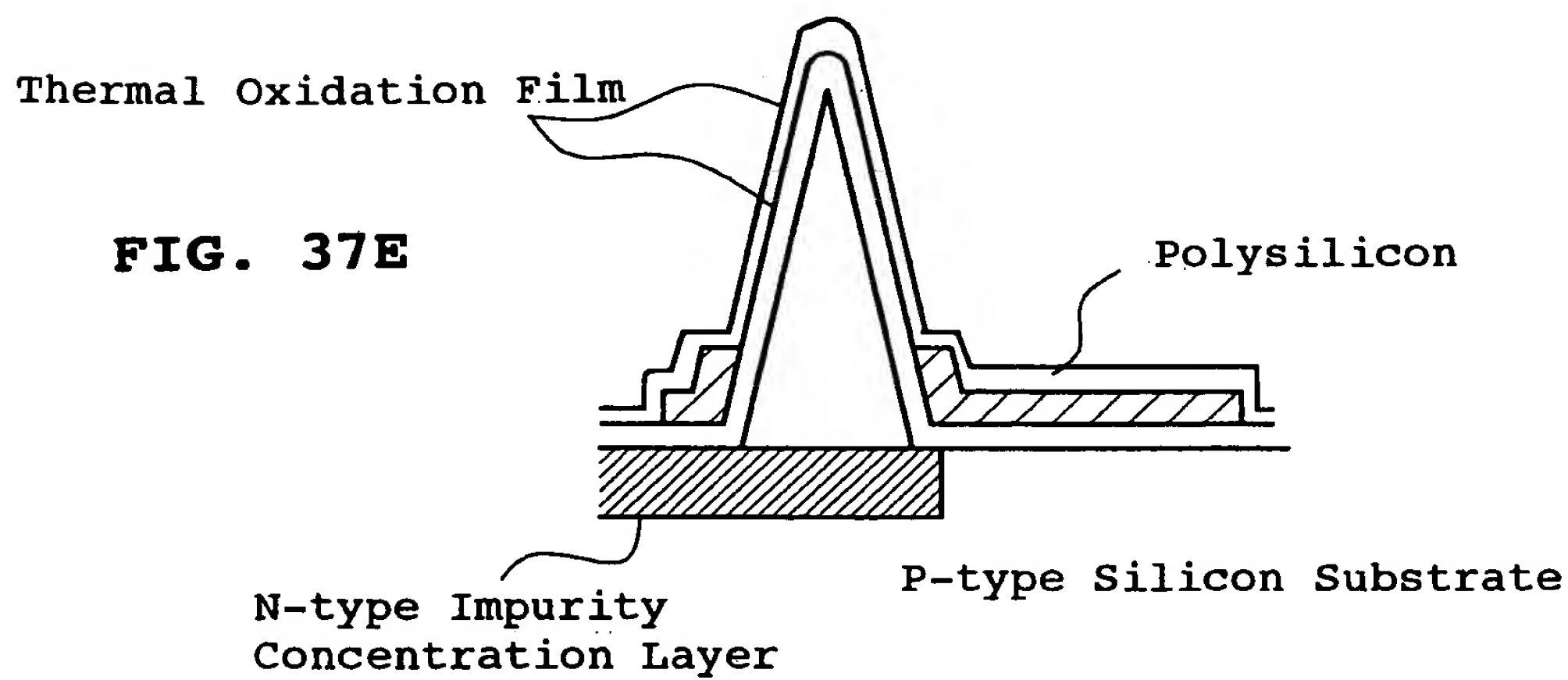
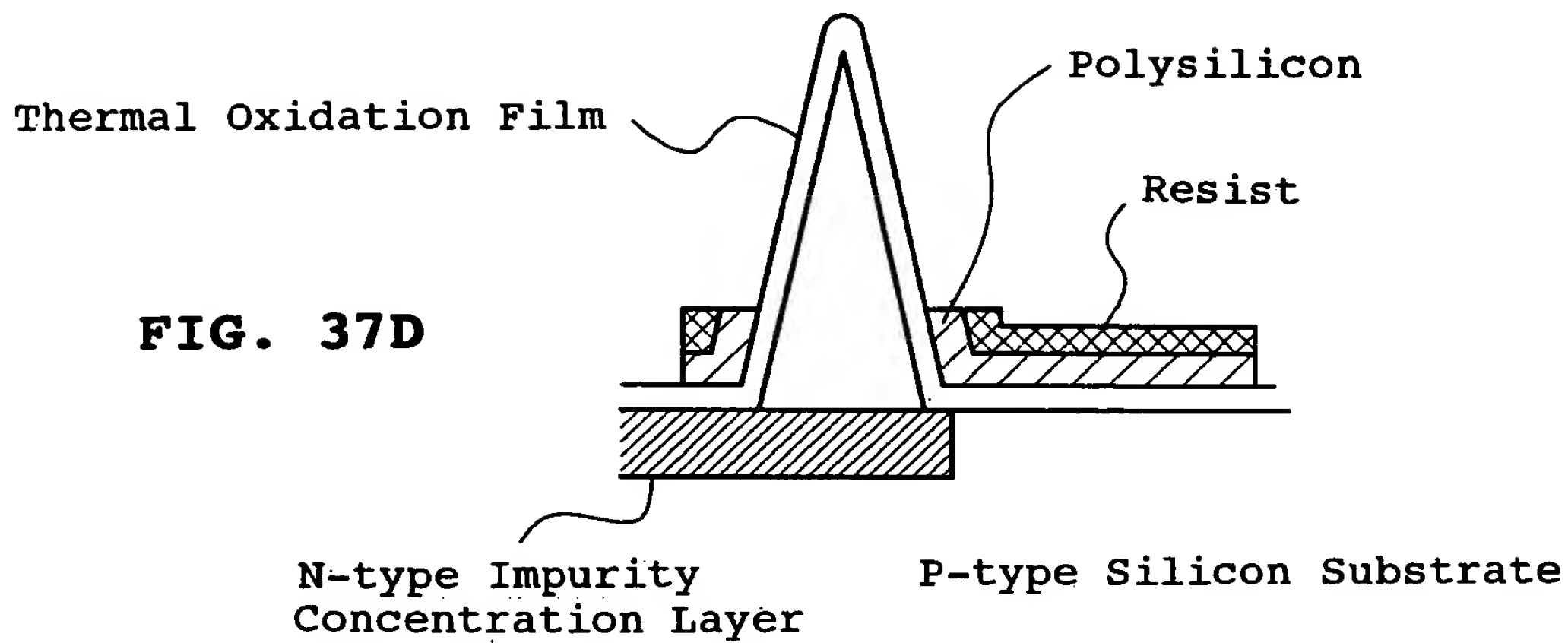


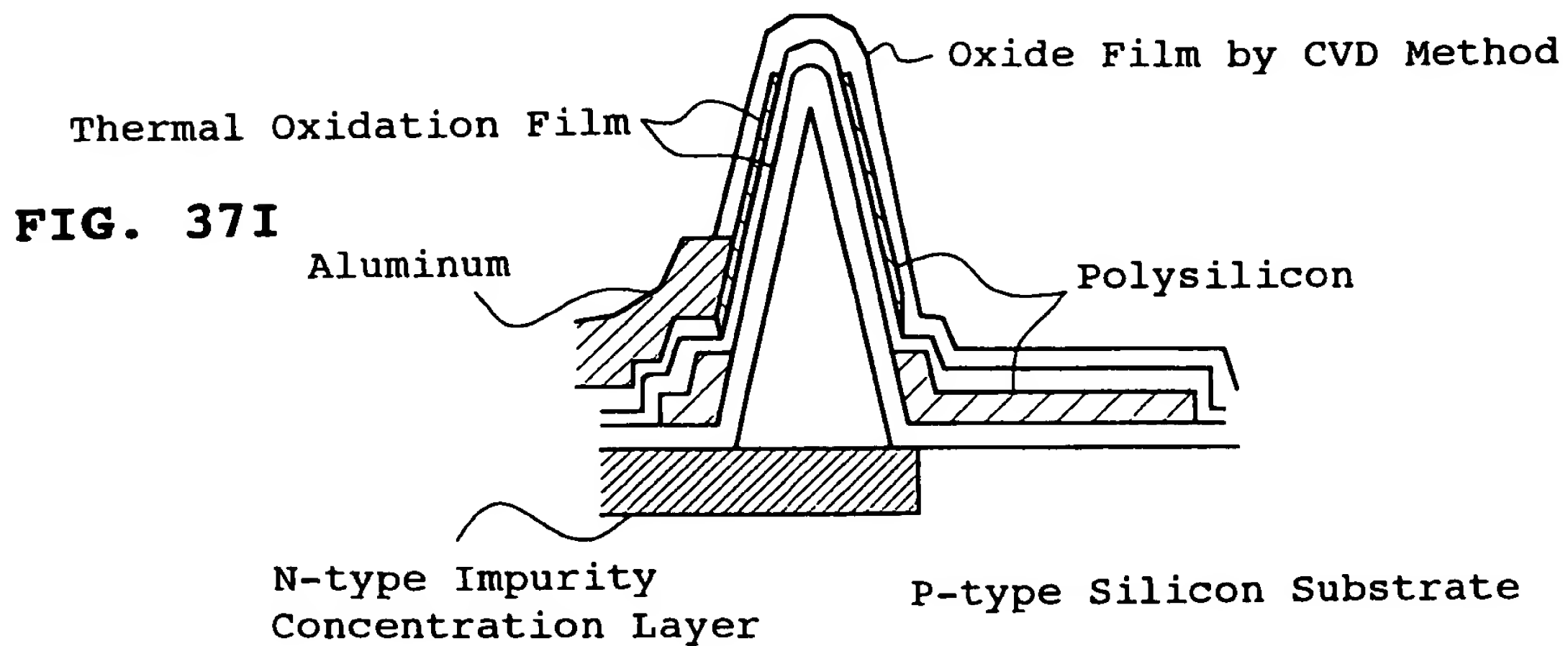
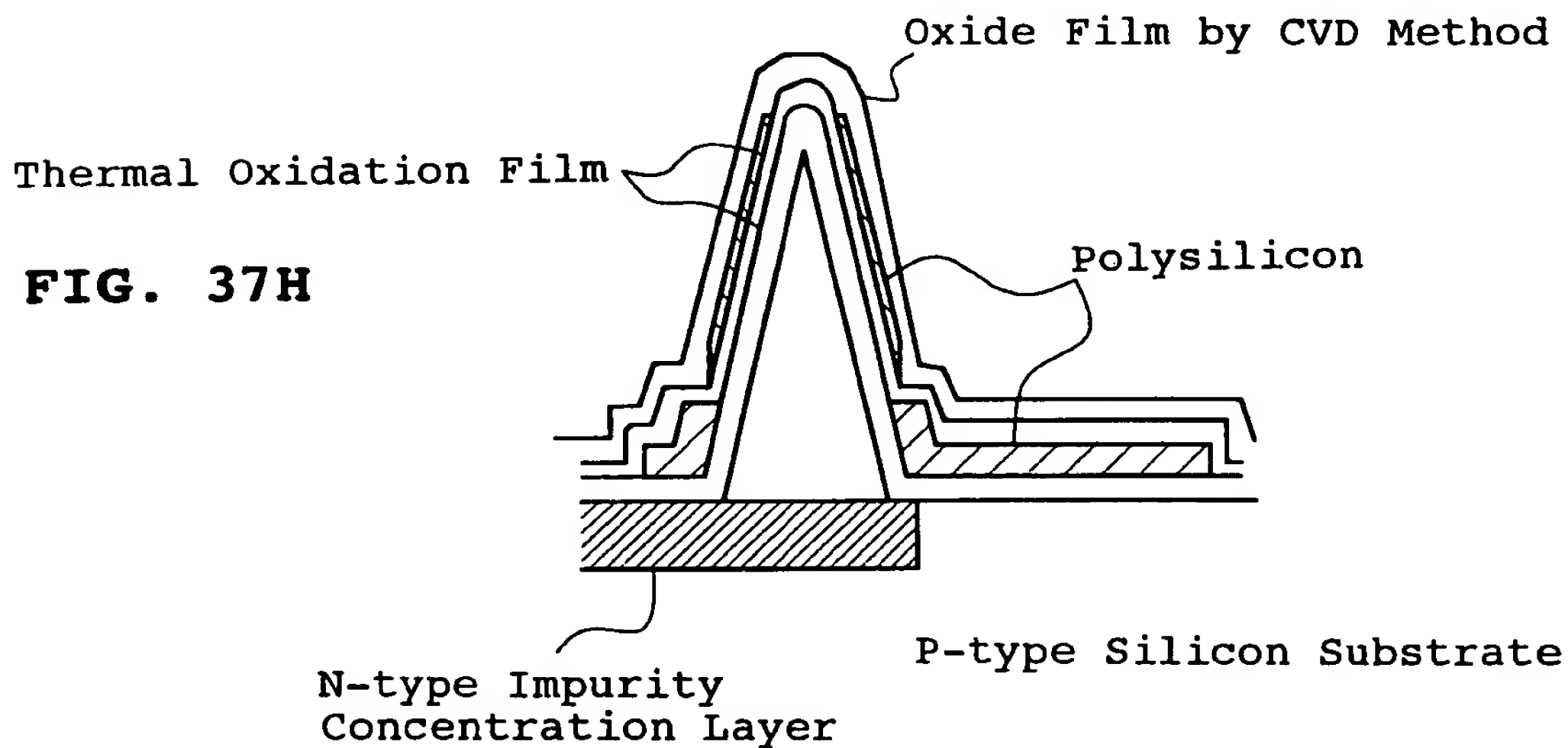
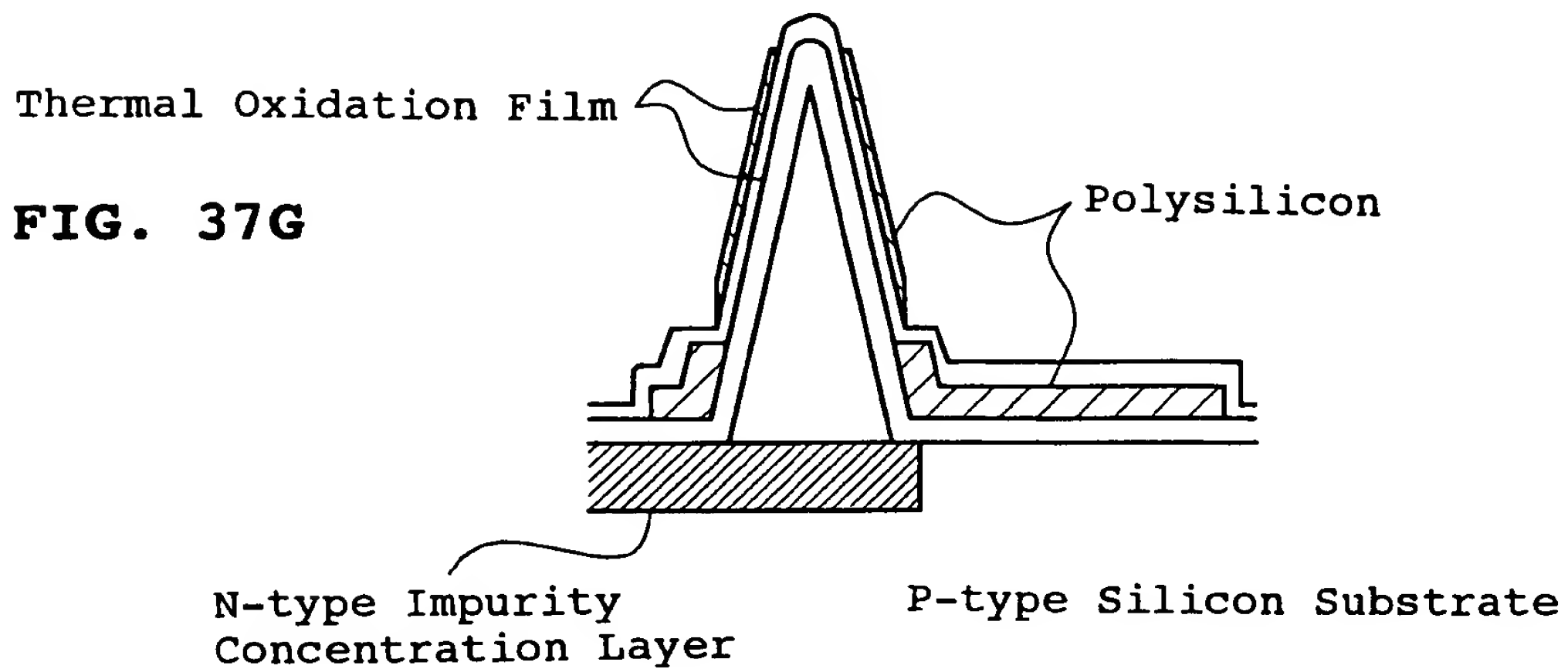












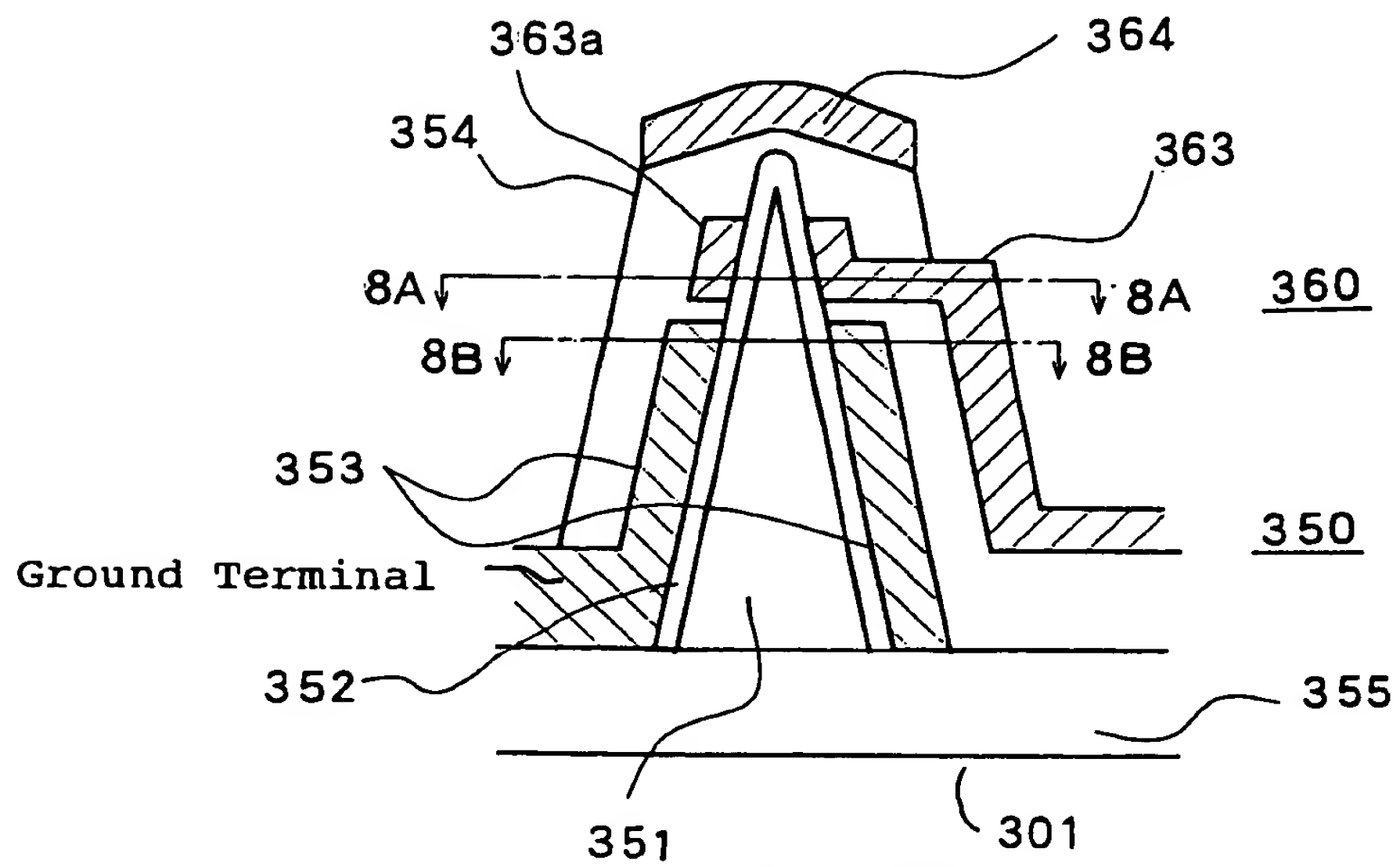


FIG. 38A

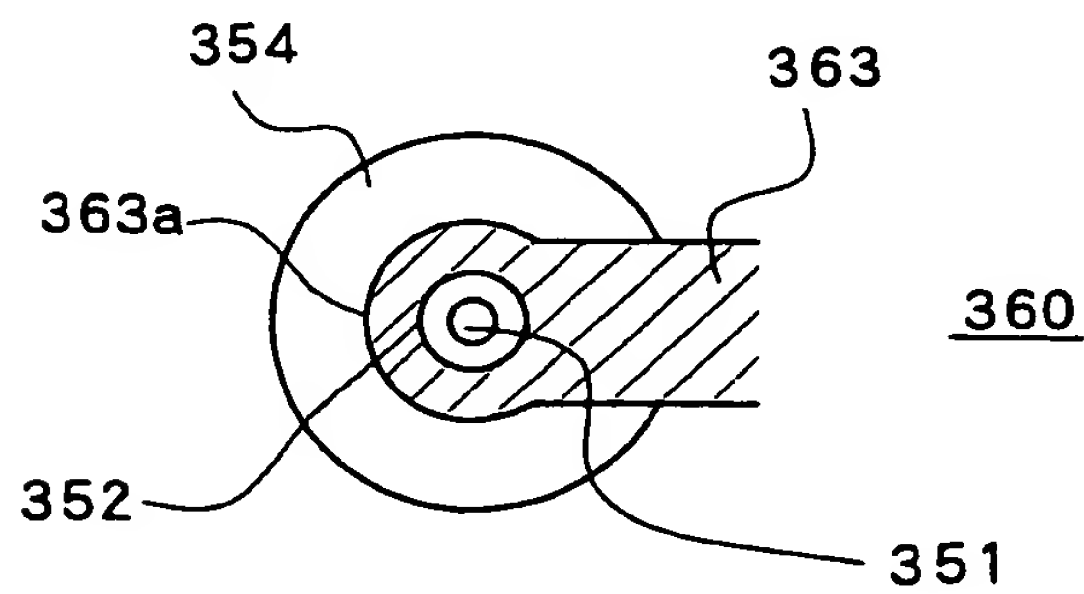


FIG. 38B

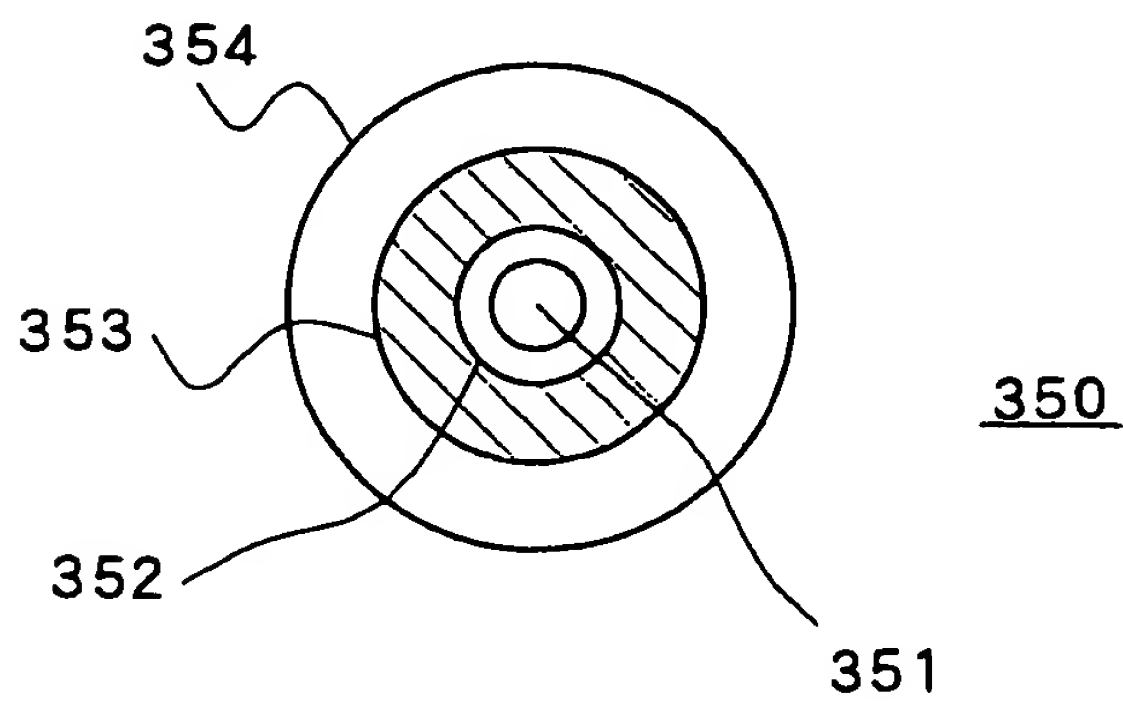
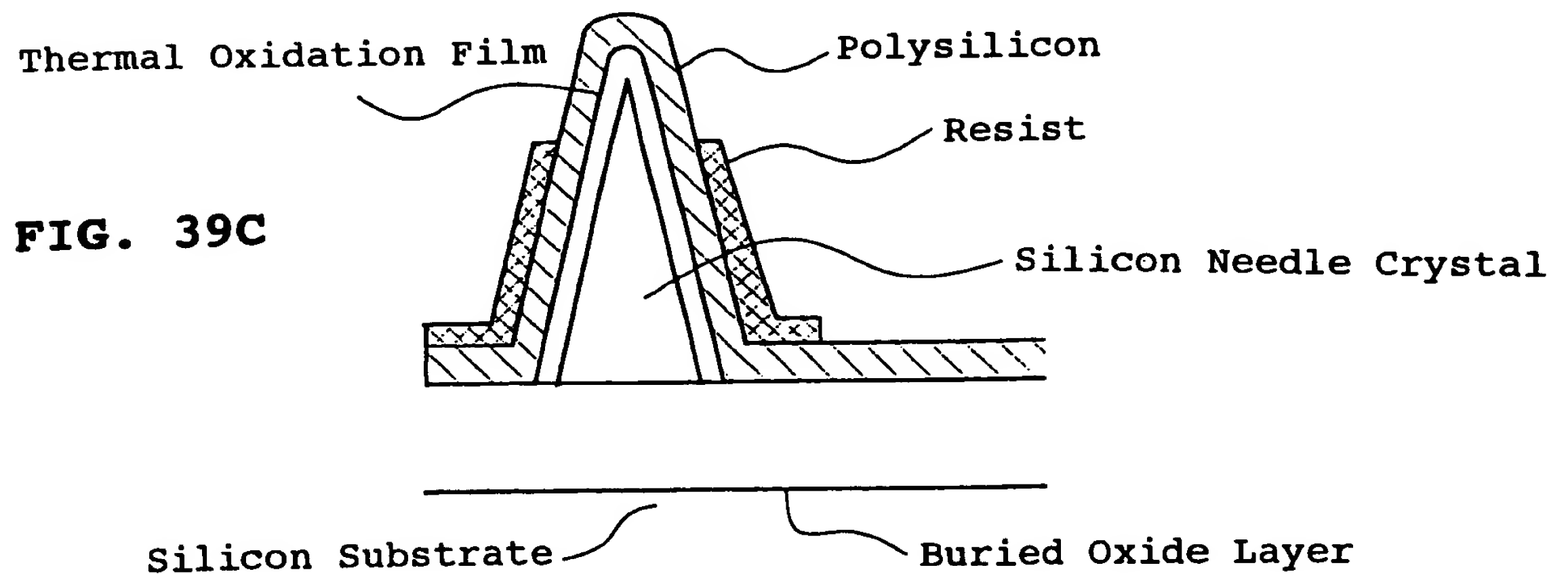
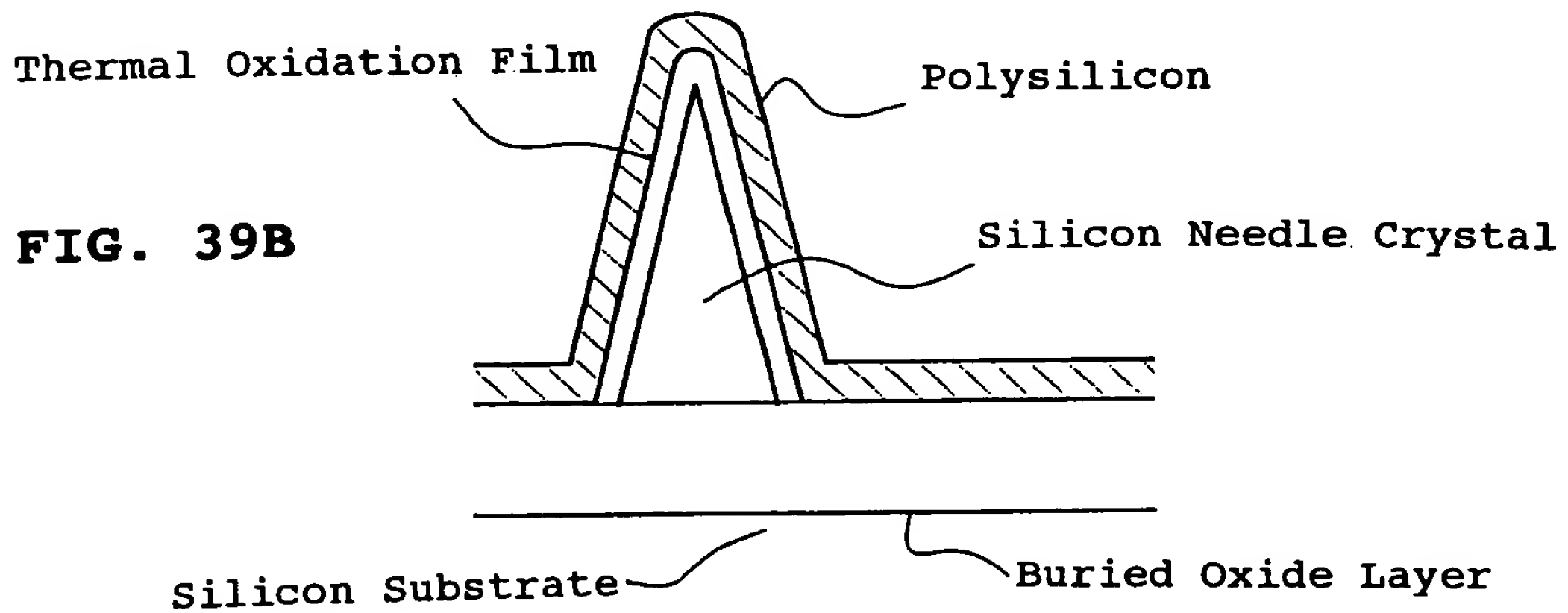
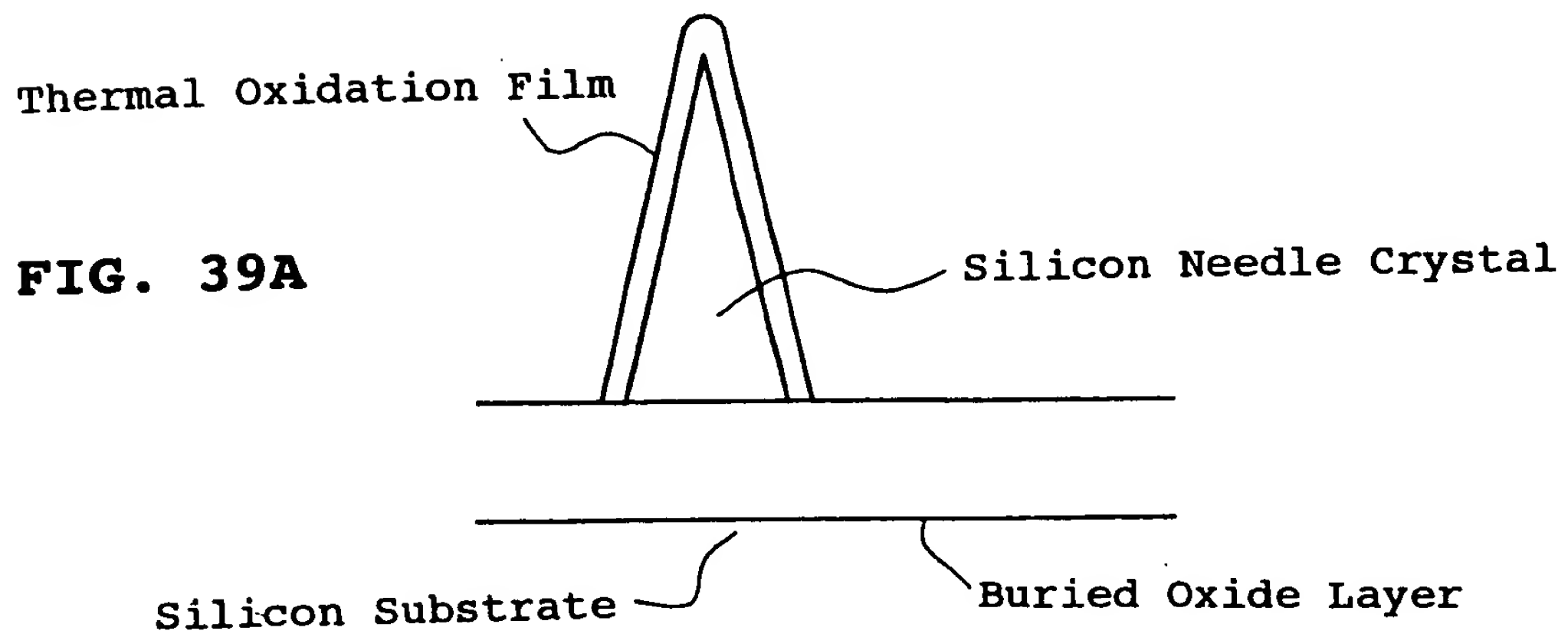
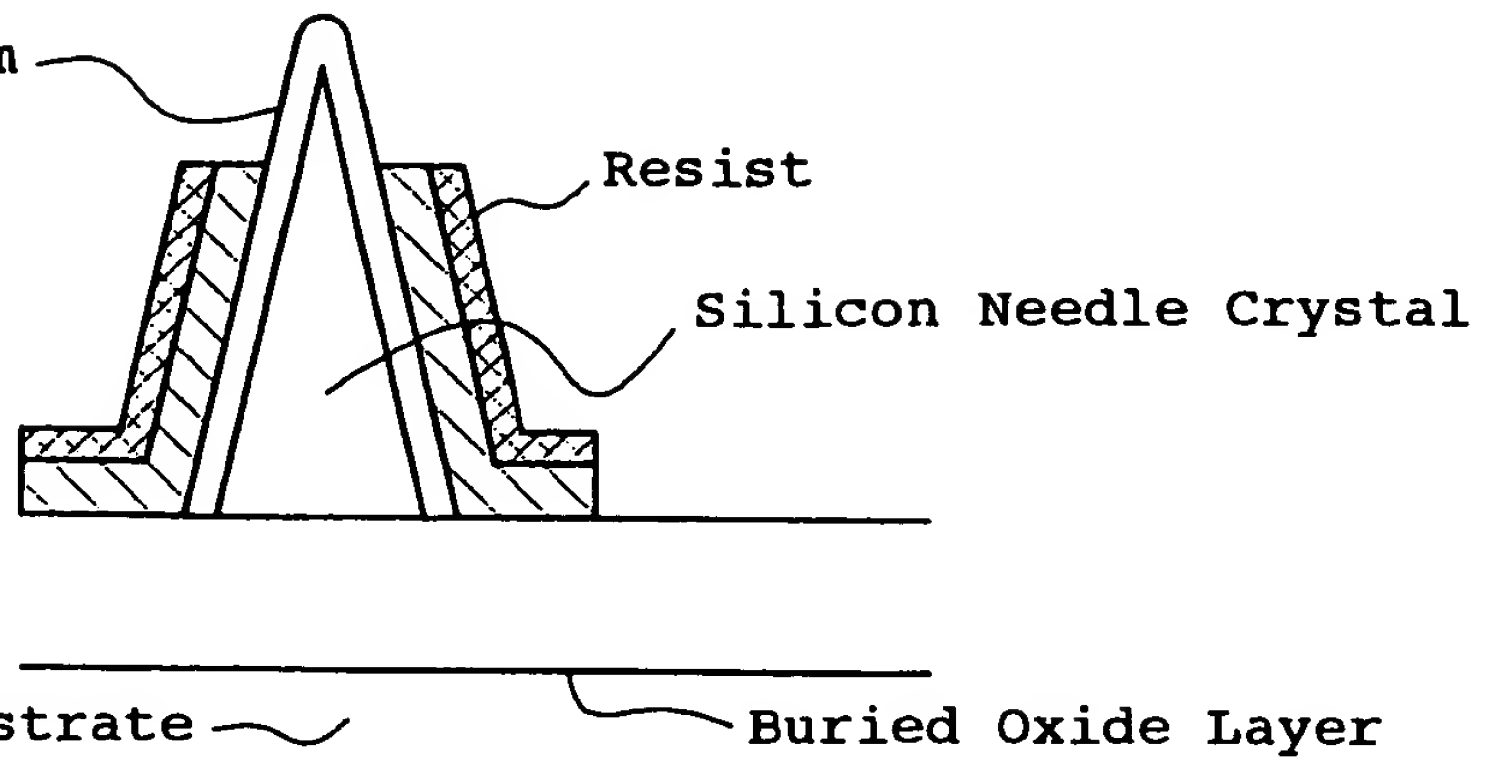


FIG. 38C



Thermal Oxidation Film

FIG. 39D



Thermal Oxidation Film

FIG. 39E

